

TLC EQUIPMENT NON-INVENTORY LIST

The TLC Equipment Group has access to surplus semiconductor manufacturing and test equipment from external suppliers.
 The list below shows equipment that we are aware of on the surplus market.
 If any tool is of interest please contact the sales office for your region, quoting the TLC Item Number and your contact details.

Please note that this list may not be up-to-date and that some tools may now have sold.

This list has been sorted by OEM, Model/Description and then Wafer Size.

| Item No. | OEM | Model/Description | Type | Wafer Size (Inches) |
|----------|--------------|---|-----------------|---------------------|
| 17000111 | ABM | 60 UV Mask Aligner | Mask Aligners | |
| 16000847 | Accent | CDS-200 CD-scat | Metrology | |
| 13001203 | ACCRETCH/TSK | APM 90A Wafer Probe System | Test & Handling | |
| 13001204 | ACCRETCH/TSK | UF 3000 | Test & Handling | |
| 16000729 | ADE | 3046A Non-Contact Constant Current Capacitive Measurement System | Metrology | 4";5";6" |
| 16000583 | ADE | 6034 Thickness Measurement System | Metrology | 4";5";6" |
| 16000694 | ADE | 780 MRT Measurement System | Metrology | 4";5";6" |
| 16000920 | ADE | 9350 wafer thickness measurement system | Metrology | |
| 16000136 | ADE | 9500 Ultra Gage Thickness, Flatness (Global/Site) & Shape (Bow/Warp) Measurement System | Metrology | 4";5";6";8" |
| 16000136 | ADE | 9500 Ultra Gage Thickness, Flatness (Global/Site) & Shape (Bow/Warp) Measurement System | Metrology | 4";5";6";8" |
| 16000664 | ADE | 9600 Ultra Scan Thickness, Flatness (Global/Site) & Shape (Bow/Warp) Measurement System | Metrology | 8" |
| 16000372 | ADE | CR 80 Wafer Surface Inspection System | Metrology | 6" |
| 13000598 | ADVANTEST | M 3841 A Handler | Test & Handling | |
| 13000598 | ADVANTEST | M 3841 A Handler | Test & Handling | |
| 13000598 | ADVANTEST | M 3841 A Handler | Test & Handling | |
| 13001111 | ADVANTEST | M 4541 A Handler | Test & Handling | |
| 13001101 | ADVANTEST | M 4622 A Handler | Test & Handling | |
| 13001110 | ADVANTEST | M 4741 A Handler | Test & Handling | |
| 13001067 | ADVANTEST | M 6541 A Handler | Test & Handling | |
| 13001066 | ADVANTEST | M 6721 A Handler | Test & Handling | |
| 13001232 | ADVANTEST | M 6741 A wafer test | Test & Handling | |
| 13001233 | ADVANTEST | M 6751 A wafer test | Test & Handling | |
| 13000901 | ADVANTEST | M 6761 A Handler | Test & Handling | |
| 13001073 | ADVANTEST | M 6842 D Handler | Test & Handling | |
| 13001274 | ADVANTEST | M6751A handler | Test & Handling | |
| 13000459 | ADVANTEST | T 3323 Digital VLSI Test System | Test & Handling | |
| 13000402 | ADVANTEST | T 3324 Digital VLSI Test System | Test & Handling | |
| 13000402 | ADVANTEST | T 3324 Digital VLSI Test System | Test & Handling | |
| 13001234 | ADVANTEST | T 3324 Digital VLSI Test System | Test & Handling | |
| 13001089 | ADVANTEST | T 3326 A Digital VLSI Test System | Test & Handling | |
| 13000006 | ADVANTEST | T 3333 Digital VLSI Test System | Test & Handling | |
| 13000617 | ADVANTEST | T 3340 Digital VLSI Test System | Test & Handling | |
| 13000753 | ADVANTEST | T 3343 Digital VLSI Test System | Test & Handling | |
| 13000753 | ADVANTEST | T 3343 Digital VLSI Test System | Test & Handling | |
| 13001100 | ADVANTEST | T 3347 A Digital VLSI Test System | Test & Handling | |
| 13001235 | ADVANTEST | T 3347 A wafer test | Test & Handling | |
| 13000727 | ADVANTEST | T 3381 Digital VLSI Test System | Test & Handling | |
| 13000754 | ADVANTEST | T 3412 Digital VLSI Test System | Test & Handling | |
| 13001236 | ADVANTEST | T 5333 P wafer test | Test & Handling | |
| 13001069 | ADVANTEST | T 5334 Memory Test System | Test & Handling | |
| 13001069 | ADVANTEST | T 5335 Memory Test System | Test & Handling | |
| 13000980 | ADVANTEST | T 5335 Memory Test System | Test & Handling | |
| 13001206 | ADVANTEST | T 5335 Memory Test System, single test head | Test & Handling | |
| 13000814 | ADVANTEST | T 5335 P Memory Test System | Test & Handling | |
| 13000814 | ADVANTEST | T 5335 P Memory Test System | Test & Handling | |
| 13001071 | ADVANTEST | T 5343 Memory Test System | Test & Handling | |
| 13000130 | ADVANTEST | T 5361 Memory Test System | Test & Handling | |
| 13000752 | ADVANTEST | T 5362 Memory Test System | Test & Handling | |
| 13000752 | ADVANTEST | T 5362 Memory Test System | Test & Handling | |
| 13000389 | ADVANTEST | T 5363 P Memory Test System | Test & Handling | |
| 13000344 | ADVANTEST | T 5365 Memory Test System | Test & Handling | |
| 13000374 | ADVANTEST | T 5365 P Memory Test System | Test & Handling | |
| 13000374 | ADVANTEST | T 5365 P Memory Test System | Test & Handling | |
| 13000374 | ADVANTEST | T 5365 P Memory Test System | Test & Handling | |
| 13000374 | ADVANTEST | T 5365 P Memory Test System | Test & Handling | |
| 13001078 | ADVANTEST | T 5376 Memory Test System | Test & Handling | |
| 13000306 | ADVANTEST | T 5381 H Memory Test System | Test & Handling | |
| 13000010 | ADVANTEST | T 5381 Memory Test System | Test & Handling | |
| 13000616 | ADVANTEST | T 5382 A Memory Test System | Test & Handling | |
| 13000616 | ADVANTEST | T 5382 A Memory Test System | Test & Handling | |
| 13000616 | ADVANTEST | T 5382 A Memory Test System | Test & Handling | |
| 13001207 | ADVANTEST | T 5571P | Test & Handling | |
| 13001120 | ADVANTEST | T 5581 H Memory Test System | Test & Handling | |
| 13001237 | ADVANTEST | T 5585 wafer test | Test & Handling | |
| 13000401 | ADVANTEST | T 5591 Memory Test System | Test & Handling | |
| 13001087 | ADVANTEST | T 5592 Memory Test System | Test & Handling | |
| 13001238 | ADVANTEST | T 5593 wafer test | Test & Handling | |

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|----------|-------------------|---|--------------------------------|---------------------|
| 13001109 | ADVANTEST | T 6331 LCD Driver Test System | Test & Handling | |
| 13001239 | ADVANTEST | T 6361 LCD driver test | Test & Handling | |
| 13001122 | ADVANTEST | T 6361 T Test System | Test & Handling | |
| 13001048 | ADVANTEST | T 6373 Mixed Signal Test System | Test & Handling | |
| 13000307 | ADVANTEST | T 6671 Mixed Signal Test System | Test & Handling | |
| 13001129 | ADVANTEST | T 6673 Dual Head SOC Test System | Test & Handling | |
| 13001099 | ADVANTEST | T 6682 Mixed Signal Test System | Test & Handling | |
| 13000766 | ADVANTEST | T 6683 Mixed Signal Test System | Test & Handling | |
| 13000766 | ADVANTEST | T 6683 Mixed Signal Test System | Test & Handling | |
| 13000940 | ADVANTEST | T 7164 Memory Test System | Test & Handling | |
| 13001028 | ADVANTEST | T 7315 Mixed Signal Test System | Test & Handling | |
| 13000305 | ADVANTEST | T 7340 SMS2 Mixed Signal Test System | Test & Handling | |
| 13001240 | ADVANTEST | T2000 tester | Test & Handling | |
| 13001208 | ADVANTEST | T5365P memory tester | Test & Handling | |
| 13001241 | ADVANTEST | T5377S memory tester | Test & Handling | |
| 13001225 | ADVANTEST | T5571P Memory tester | Test & Handling | 8" |
| 13001209 | ADVANTEST | T5581P | Test & Handling | |
| 13001242 | ADVANTEST | T5771 memory tester | Test & Handling | |
| 13000703 | ADVANTEST | T 3332 Digital VLSI Test System | Test & Handling | |
| 16000536 | AERONCA/ESTEK | WIS 600 Wafer Inspection System | Metrology | 6" |
| 16000375 | AERONCA/ESTEK | WIS 800 Wafer Inspection System | Metrology | 6" |
| 16000537 | AERONCA/ESTEK | WIS 8000 Wafer Inspection System | Metrology | 6" |
| 16000349 | AERONCA/ESTEK | WIS 850 Wafer Inspection System | Metrology | 6" |
| 16000538 | AERONCA/ESTEK | WIS 8500 Wafer Inspection System | Metrology | 6" |
| 16000350 | AERONCA/ESTEK | WIS 900 Wafer Inspection System | Metrology | 6" |
| 13000257 | AETRIUM | 5050 S Handler | Test & Handling | |
| 13000257 | AETRIUM | 5050 S Handler | Test & Handling | |
| 13000718 | AETRIUM | 5050 S Handler | Test & Handling | |
| 13001097 | AETRIUM | 5600 IC Handler | Test & Handling | |
| 13000755 | AETRIUM | 900 A Handler | Test & Handling | |
| 23000020 | AG ASSOCIATES | 2106 RTA/RTP System | RTA/RTP | 4";5";6" |
| 23000083 | AG ASSOCIATES | 210T RTA/RTP System | RTA/RTP | 2";3";4" |
| 23000052 | AG ASSOCIATES | 2146 RTA/RTP System | RTA/RTP | 4";5";6" |
| 23000084 | AG ASSOCIATES | 610 RTA/RTP System | RTA/RTP | 2";3";4";5";6" |
| 23000105 | AG ASSOCIATES | Heatpulse 610 RTA | Rapid Thermal Processing (RTP) | |
| 23000106 | AG ASSOCIATES | Heatpulse 8108 RT | Rapid Thermal Processing (RTP) | |
| 23000097 | AG ASSOCIATES | Heatpulse 8108 RTP | RTA/RTP | |
| 23000107 | AG ASSOCIATES | Heatpulse 8108 RTP | RTA/RTP | |
| 50000203 | AIRCO TEMESCAL | BJD-1800 Evaporator | PVD Sputter | |
| 30000339 | AIXTRON | AIX 200 LP-MOCVD System | CVD & Epi | 3";4";6" |
| 30000547 | AIXTRON | TRICENT AIX2600G3, MOCVD with liquid delivery injection | CVD & Epi | |
| 27000237 | AKRION | Gamma Wet Nitride Etch Bench w/ Phosphorus & HCl | Wet Etch & Clean SRD | 8" |
| 27000291 | AKRION | MP2000 etch acid sink | Wet Etch & Clean SRD | |
| 27000292 | AKRION | UP V2 MP2000 manual chemical maintenance sink | Wet Etch & Clean SRD | |
| 27000293 | AKRION | UP V2 MP2000 manual solvent maintenance sink | Wet Etch & Clean SRD | |
| 27000006 | AKRION | V2-HL.2000 Wet Chemical Bench (Never Used) | Wet Etch & Clean SRD | 6" |
| 27000008 | AKRION | V2-SA.3200 Wet Chemical Bench (Never Used) | Wet Etch & Clean SRD | 6" |
| 50000173 | ALCATEL | 2441 RF Sputtering-Up System w/ 1 PVD Position | PVD Sputter | 6";8" |
| 24000223 | ALPHASEM | 9022 & 9002 Die Bonding System | Wire Bonders | |
| 24000168 | ALPHASEM | E 8002 Die Attach System | Wire Bonders | |
| 24000113 | ALPHASEM | Swissline 9006 Die Bonding System | Wire Bonders | |
| 24000165 | ALPHASEM | Swissline 9021-M Die Sorting System | Wire Bonders | |
| 24000167 | ALPHASEM | Swissline 9022 Die Attach System | Wire Bonders | |
| 24000166 | ALPHASEM | Swissline 9022-HSL Die Attach System | Wire Bonders | |
| 30000524 | AMAT | Centura 5200 RD Epi System | CVD & Epi | |
| 50000195 | AMAT | P5000 Mark II | PVD Sputter | |
| 20000907 | AMAT | P5000 MKP+ | Etch/Ash/Strip | |
| 13001243 | AMAT | VERA CD SEM | Test & Handling | |
| 27000306 | AMERIMADE | Plastic Cobalt Etch and P-Clean Bench | Wet Processing | |
| 27000307 | AMERIMADE | Plastic KOH Wet Bench | Wet Processing | |
| 90000209 | AMRAY/TENCOR | 2030 C SEM | Microscopes | |
| 90000219 | AMRAY/TENCOR | 3800 C DRT SEM | Microscopes | |
| 30000525 | APPLIED MATERIALS | 5200 Centura HTF/RTO/Poly/Clean | CVD & Epi | 8 |
| 30000483 | APPLIED MATERIALS | 5200 mainframe DPS non-metal | CVD & Epi | |
| 30000484 | APPLIED MATERIALS | 5200 RTCVD MF non-metal | CVD & Epi | |
| 23000093 | APPLIED MATERIALS | 5200 RTP MF metal | RTA/RTP | |
| 30000485 | APPLIED MATERIALS | 5200 TPCC undoped gate cluster TPCC MF | CVD & Epi | |
| 30000486 | APPLIED MATERIALS | 5200 undoped silicates MF | CVD & Epi | |
| 50000187 | APPLIED MATERIALS | 5500 Cobalt metal/copper shared | PVD Sputter | |
| 50000188 | APPLIED MATERIALS | 5500 Copper barrier seed | PVD Sputter | |
| 20000001 | APPLIED MATERIALS | 8000 Series Etch Systems (Metal 8330-5" & 8115-6") | Etch/Ash/Strip | 5";6" |

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| 20000001 | APPLIED MATERIALS | 8000 Series Etch Systems (Metal 8330-5" & 8115-6") | Etch/Ash/Strip | 5",6" |
| 20000001 | APPLIED MATERIALS | 8000 Series Etch Systems (Nitride - 8") | Etch/Ash/Strip | 8" |
| 20000836 | APPLIED MATERIALS | 8330A single chamber dry etch | Etch/Ash/Strip | 6" |
| 14000148 | APPLIED MATERIALS | 9200 High Current Ion Implanter | Ion Implant | 6" |
| 14000154 | APPLIED MATERIALS | 9500 High Current Ion Implanter | Ion Implant | 8" |
| 14000125 | APPLIED MATERIALS | 9500xR High Current Ion Implanter | Ion Implant | |
| 14000125 | APPLIED MATERIALS | 9500xR High Current Ion Implanter | Ion Implant | 8" |
| 16000328 | APPLIED MATERIALS | Boxer BX-10 Implant Dose Measurement System | Metrology | 8" |
| 50000196 | APPLIED MATERIALS | Centura (1995) | PVD Sputter | 8" |
| 30000402 | APPLIED MATERIALS | Centura 300 CVD System w/ 3 X Ultima X HDP Chambers | CVD & Epi | 12" |
| 20000862 | APPLIED MATERIALS | Centura 4 chamber DT etcher | Etch/Ash/Strip | |
| 30000548 | APPLIED MATERIALS | Centura 5200 CVD | CVD & Epi | |
| 30000518 | APPLIED MATERIALS | Centura 5200 CVD Polycide | CVD & Epi | 8" |
| 30000487 | APPLIED MATERIALS | Centura 5200 CVD TEOS | CVD & Epi | |
| 30000464 | APPLIED MATERIALS | Centura 5200 CVD(DPN) | CVD & Epi | 8" |
| 20000822 | APPLIED MATERIALS | Centura 5200 DPS Metal Etch System | Etch/Ash/Strip | 8" |
| 30000526 | APPLIED MATERIALS | Centura 5200 DxZ CVD PECVD | CVD & Epi | |
| 30000549 | APPLIED MATERIALS | Centura 5200 DxZ CVD SACVD | CVD & Epi | |
| 30000550 | APPLIED MATERIALS | Centura 5200 DxZ CVD TEOS | CVD & Epi | |
| 20000837 | APPLIED MATERIALS | Centura 5200 e-Max Oxide Etch System | Etch/Ash/Strip | 8" |
| 20000955 | APPLIED MATERIALS | Centura 5200 eMXP Etch | Etch/Ash/Strip | |
| 30000431 | APPLIED MATERIALS | Centura 5200 EPI System w/ 3 Chambers | CVD & Epi | 8" |
| 20000956 | APPLIED MATERIALS | Centura 5200 Etch | Etch/Ash/Strip | |
| 20000808 | APPLIED MATERIALS | Centura 5200 Etch System w/ 2 X MxP+ Etch & 2 X NB Load Lock Chambers | Etch/Ash/Strip | 8" |
| 20000957 | APPLIED MATERIALS | Centura 5200 Etcher | Etch/Ash/Strip | |
| 30000334 | APPLIED MATERIALS | Centura 5200 HFT EPI System w/ 1xEpi, 1xCool Down, 1x Buffer & 2xLoad Lock Chambers & 300mm Robot | CVD & Epi | 8",12" |
| 30000397 | APPLIED MATERIALS | Centura 5200 High-K Development System w/ 1 X CVD, 1 X PVD, 1 X MAC Anneal, 1 X Degas & 1 X Orientation Chambers | CVD & Epi | 8" |
| 23000108 | APPLIED MATERIALS | Centura 5200 HTF RTO/Poly/Clean | Rapid Thermal Processing (RTP) | |
| 30000527 | APPLIED MATERIALS | Centura 5200 IPS oxide chamber | CVD & Epi | |
| 20000908 | APPLIED MATERIALS | Centura 5200 Metal Etch | Etch/Ash/Strip | |
| 30000528 | APPLIED MATERIALS | Centura 5200 Multipurpose CVD RTCVD MF | CVD & Epi | |
| 20000909 | APPLIED MATERIALS | Centura 5200 Oxide Etch eMax | Etch/Ash/Strip | |
| 20000863 | APPLIED MATERIALS | Centura 5200 Oxide Etch MxP | Etch/Ash/Strip | 8" |
| 20000910 | APPLIED MATERIALS | Centura 5200 Oxide Etch Super E | Etch/Ash/Strip | |
| 20000768 | APPLIED MATERIALS | Centura 5200 Oxide Etch System w/ MxP Oxide Etch Chambers, 2 X NB Tilt-Out LL & Dual Speed HP Robot | Etch/Ash/Strip | 8" |
| 20000719 | APPLIED MATERIALS | Centura 5200 Phase II Poly Etch System w/ 2 X DPS Poly Etch Chambers | Etch/Ash/Strip | 8" |
| 20000781 | APPLIED MATERIALS | Centura 5200 Poly Etch System w/ DPS Chambers | Etch/Ash/Strip | 8" |
| 20000958 | APPLIED MATERIALS | Centura 5200 Poly Etcher | Etch/Ash/Strip | |
| 20000959 | APPLIED MATERIALS | Centura 5200 Polycide | CVD & Epi | |
| 50000197 | APPLIED MATERIALS | Centura 5200 PVD | PVD Sputter | |
| 23000094 | APPLIED MATERIALS | Centura 5200 RTP | RTA/RTP | 8" |
| 23000066 | APPLIED MATERIALS | Centura 5200 RTP HTF TPCC Reduced Pressure System w/ 1 X RTP XE+, 1 X DCSxZ (WSix), 2 X CZ Single Slot Fast Cool Down & 2 X Wide Body Load Lock Chambers | RTA/RTP | 6" |
| 23000081 | APPLIED MATERIALS | Centura 5200 RTP System w/ 2 X Radiance RTP, 1 X Cool Down/Orientation & 2 X NB Tilt-Out Load Lock Chambers & HP Robot | RTA/RTP | 8" |
| 23000089 | APPLIED MATERIALS | Centura 5200 RTP System with 2 MODI Chambers | RTA/RTP | 8" |
| 23000075 | APPLIED MATERIALS | Centura 5200 RTP TPCC Mainframe System w/ 2 X RTP XE+ Chambers | RTA/RTP | 8" |
| 20000792 | APPLIED MATERIALS | Centura 5200 SuperE Etch System w/ 3 Chambers | Etch/Ash/Strip | 8" |
| 30000451 | APPLIED MATERIALS | Centura 5200 TiN CVD System | CVD & Epi | 8" |
| 30000529 | APPLIED MATERIALS | Centura 5200 TiN CVD System | CVD & Epi | |
| 30000449 | APPLIED MATERIALS | Centura 5200 Tungsten CVD System w/ WSix Chambers | CVD & Epi | 8" |
| 30000419 | APPLIED MATERIALS | Centura 5200 Tungsten CVD System w/ WxZ Chambers | CVD & Epi | 8" |
| 30000410 | APPLIED MATERIALS | Centura 5200 Tungsten CVD/Etch System w/ 2 X WxZ Tungsten CVD, 2 X HeWeB Tungsten Etch, 1 X MS Cool Down, 1 X Orientation & 2 X Load Lock Chambers | CVD & Epi | 8" |
| 30000411 | APPLIED MATERIALS | Centura 5200 Tungsten CVD/Etch System w/ 3 X WxZ Tungsten CVD, 1 X HeWeB Tungsten Etch, 1 X MS Cool Down, 1 X Orientation & 2 X NB Tilt-Out Load Lock Chambers | CVD & Epi | 8" |
| 30000488 | APPLIED MATERIALS | Centura 5200 Tungsten CVD/Etch System w/ 3 X WxZ Tungsten CVD, 1 X MS Cool Down, 1 X Orientation & 2 X NB Tilt-Out Load Lock Chambers | CVD & Epi | 8" |

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| 30000489 | APPLIED MATERIALS | Centura 5200 Tungsten CVD/Etch System w/ 4 X WxZ Tungsten CVD, 1 X MS Cool Down, 1 X Orientation & 2 X NB Tilt-Out Load Lock Chambers | CVD & Epi | 8" |
| 30000530 | APPLIED MATERIALS | Centura 5200 W CVD system | CVD & Epi | |
| 30000490 | APPLIED MATERIALS | Centura 5200 Wsi (4 chamber Wsi) | CVD & Epi | 8" |
| 30000551 | APPLIED MATERIALS | Centura AP Enabler Etch module Dielectric | CVD & Epi | |
| 30000466 | APPLIED MATERIALS | Centura DARC DxZ Silane, 3 Silane chamber, 5 Ebara pumps, SiH4, H2, CF4, He | CVD & Epi | 8" |
| 30000520 | APPLIED MATERIALS | Centura DPN Gate Stack CVD | CVD & Epi | 8" |
| 20000960 | APPLIED MATERIALS | Centura DPS Etcher Metal | Etch/Ash/Strip | |
| 20000961 | APPLIED MATERIALS | Centura DPS Etcher Poly | Etch/Ash/Strip | |
| 20000911 | APPLIED MATERIALS | Centura DPS Plus (various configs) | Etch/Ash/Strip | 8" |
| 20000962 | APPLIED MATERIALS | Centura DPS Plus Etcher Poly | Etch/Ash/Strip | |
| 20000912 | APPLIED MATERIALS | Centura DPS Poly Etch | Etch/Ash/Strip | |
| 20000889 | APPLIED MATERIALS | Centura DPS poly etcher | Etch/Ash/Strip | |
| 30000531 | APPLIED MATERIALS | Centura DxZ old body type, TEOS | CVD & Epi | 8" |
| 20000890 | APPLIED MATERIALS | Centura Enabler dielectric etcher | Etch/Ash/Strip | |
| 30000334 | APPLIED MATERIALS | Centura EPI System w/ 1 X EPI, 1 X Cool Down, 1 X Buffer & 2 X Load Lock Chambers & 300mm Robot | CVD & Epi | 12" |
| 30000401 | APPLIED MATERIALS | Centura EPI System w/ 2 Chambers | CVD & Epi | 12" |
| 30000409 | APPLIED MATERIALS | Centura EPI System w/ 3 Chambers | CVD & Epi | 8" |
| 20000898 | APPLIED MATERIALS | Centura HART deep trench etcher | Etch/Ash/Strip | 8" |
| 20000791 | APPLIED MATERIALS | Centura II IPS dielectric Etch System w/ 4 X IPS Chambers | Etch/Ash/Strip | 8" |
| 20000963 | APPLIED MATERIALS | Centura II SUPER-E Etcher Dielectric | Etch/Ash/Strip | |
| 20000913 | APPLIED MATERIALS | Centura IPS Dry Etch | Etch/Ash/Strip | |
| 23000098 | APPLIED MATERIALS | Centura ISSG process | RTA/RTP | 8" |
| 30000552 | APPLIED MATERIALS | Centura Polygen CVD LPCVD | CVD & Epi | |
| 23000099 | APPLIED MATERIALS | Centura RTP XE | RTA/RTP | |
| 20000899 | APPLIED MATERIALS | Centura Super-E Dielectric etch | Etch/Ash/Strip | 8" |
| 30000553 | APPLIED MATERIALS | CENTURA ULTIMA CVD HDP | CVD & Epi | |
| 16000740 | APPLIED MATERIALS | Compass and Compass Pro Defect Inspection System | Metrology | 8" |
| 16000848 | APPLIED MATERIALS | Compass Patterned wafer inspection | Metrology | |
| 16000651 | APPLIED MATERIALS | Compass PRO 200 Defect Inspection System | Metrology | 8";12" |
| 16000849 | APPLIED MATERIALS | Compass PRO 200 Defect Inspection System | Metrology | |
| 16000921 | APPLIED MATERIALS | ComPlus inspection system | Metrology | |
| 16000918 | APPLIED MATERIALS | ComPLUS patterned wafer inspection system | Metrology | |
| 90000236 | APPLIED MATERIALS | DR SEMVision cX In Line Defect Review & Classification | Microscopes | 8" |
| 90000174 | APPLIED MATERIALS | DR SEMVision cX In Line Defect Review & Classification System | Microscopes | 8" |
| 90000266 | APPLIED MATERIALS | DR SEMVision defect analysis inspection | Microscopes | |
| 90000232 | APPLIED MATERIALS | DR SEMVision G2 In Line Defect Review & Classification | Microscopes | 8";12" |
| 50000166 | APPLIED MATERIALS | Endura 5500 HP PVD System | PVD Sputter | 8" |
| 50000159 | APPLIED MATERIALS | Endura 5500 HP PVD System w/ 1 X Wide Body Ti/TiN PVD, 1 X Standard Body Ti PVD, 2 X Standard Body Al PVD & 2 X Load Lock Chambers | PVD Sputter | 8" |
| 50000178 | APPLIED MATERIALS | Endura 5500 HP PVD System w/ 1 X Wide Body Ti/TiN PVD, 1 X Standard Body Ti PVD, 2 X Standard Body Al PVD, 1 X PCII, 1 X Cool Down & 2 X Load Lock Chambers | PVD Sputter | 8" |
| 50000181 | APPLIED MATERIALS | Endura 5500 PVD | PVD Sputter | 6" |
| 50000182 | APPLIED MATERIALS | Endura 5500 PVD | PVD Sputter | 8" |
| 50000183 | APPLIED MATERIALS | Endura 5500 PVD System | PVD Sputter | 8" |
| 50000198 | APPLIED MATERIALS | Endura 5500 PVD System | PVD Sputter | |
| 50000171 | APPLIED MATERIALS | Endura 5500 PVD Systems (Various Configurations) | PVD Sputter | 8" |
| 50000157 | APPLIED MATERIALS | Endura 5500 VHP PVD System w/ 2 X Co, 1 X Ti & 1 X TiN Chambers | PVD Sputter | 8" |
| 50000199 | APPLIED MATERIALS | Endura VHP IMP Cu | PVD Sputter | 8" |
| 16000407 | APPLIED MATERIALS | Excite Integrated Particle Inspection System (Bare or Patterned Wafers) | Metrology | 12" |
| 16000407 | APPLIED MATERIALS | Excite Integrated Particle Inspection System (Bare or Patterned Wafers) | Metrology | 8" |
| 16000646 | APPLIED MATERIALS | Excite IPM 832 Integrated Particle Inspection System (Bare or Patterned Wafers) | Metrology | 8" |
| 11000259 | APPLIED MATERIALS | Expediate server | Miscellaneous | |
| 20000813 | APPLIED MATERIALS | HDP Etch Chamber | Etch/Ash/Strip | 6" |
| 20000914 | APPLIED MATERIALS | IPS Centura II (Cu Oxide PE) | Etch/Ash/Strip | 8" |
| 28000146 | APPLIED MATERIALS | Mira Copper polish | CMP | |
| 28000147 | APPLIED MATERIALS | Mira ILD polishing system | CMP | |
| 28000148 | APPLIED MATERIALS | Mira Mesa Copper polish | CMP | |
| 28000111 | APPLIED MATERIALS | Mirra 3400 Stand Alone (oxide) | CMP | 8" |
| 28000103 | APPLIED MATERIALS | Mirra 3400 w/ Ontrak/Synergy Integra (Copper) (1 oxide and 1 Copper) | CMP | 8" |

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This list has been sorted by OEM, Model/Description and then Wafer Size.

| Item No. | OEM | Model/Description | Type | Wafer Size (Inches) |
|----------|-------------------|---|----------------|---------------------|
| 28000129 | APPLIED MATERIALS | Mirra Copper Polish | CMP | |
| 28000149 | APPLIED MATERIALS | Mirra Integra CMP | CMP | |
| 28000130 | APPLIED MATERIALS | Mirra Mesa CMP | CMP | |
| 28000112 | APPLIED MATERIALS | Mirra Mesa CMP System (Oxide) | CMP | 8" |
| 28000131 | APPLIED MATERIALS | Mirra Mesa CMP System Copper polish | CMP | |
| 28000132 | APPLIED MATERIALS | Mirra Metal Polish | CMP | |
| 28000133 | APPLIED MATERIALS | Mirra non-metal STI polish | CMP | |
| 16000978 | APPLIED MATERIALS | NANOSEM 3D SEM CD | Metrology | |
| 90000039 | APPLIED MATERIALS | Opal 7830 i Automated CD/SEM | Microscopes | 5" |
| 90000039 | APPLIED MATERIALS | Opal 7830 i Automated CD/SEM | Microscopes | 6" |
| 90000039 | APPLIED MATERIALS | Opal 7830 i Automated CD/SEM | Microscopes | 8" |
| 90000199 | APPLIED MATERIALS | Opal 7830 si Automated CD/SEM | Microscopes | 4";5";6";8" |
| 90000199 | APPLIED MATERIALS | Opal 7830 si Automated CD/SEM | Microscopes | 4";5";6";8" |
| 16000922 | APPLIED MATERIALS | Orbot WF-720 Darkfield Wafer Inspection System | Metrology | 6" |
| 16000455 | APPLIED MATERIALS | Orbot WF-736 Duo Darkfield Wafer Inspection System | Metrology | 8" |
| 30000492 | APPLIED MATERIALS | P-5000 CVD Mark II CVD | CVD & Epi | |
| 20000864 | APPLIED MATERIALS | P-5000 CVD Mark II etchers | Etch/Ash/Strip | |
| 30000554 | APPLIED MATERIALS | P-5000 CVD TEOS | CVD & Epi | |
| 30000555 | APPLIED MATERIALS | P5000 MARK-II CVD Reactor | CVD & Epi | |
| 20000443 | APPLIED MATERIALS | P-5000 MK-I Etch System w/ 1 X Si Trench Etch, 1 X Resist Strip & 1 X Oxide Etch Chambers | Etch/Ash/Strip | 4" |
| 30000439 | APPLIED MATERIALS | P-5000 MK-II CVD System w/ 2 X TEOS PECVD Chambers | CVD & Epi | 6" |
| 30000363 | APPLIED MATERIALS | P-5000 MK-II CVD System w/ 4 X PECVD Nitride Chambers | CVD & Epi | 8" |
| 30000308 | APPLIED MATERIALS | P-5000 MK-II CVD TEOS System w/ 4 X CVD Oxide Chambers | CVD & Epi | 8" |
| 30000385 | APPLIED MATERIALS | P-5000 MK-II CVD/Etch System w/ 2 X TEOS PECVD & 1 X HeWeB Etch Chambers | CVD & Epi | 6" |
| 20000490 | APPLIED MATERIALS | P-5000 MK-II Dielectric Etch System w/ 3 X MxP Chambers | Etch/Ash/Strip | 8" |
| 20000838 | APPLIED MATERIALS | P-5000 MK-II Metal Etch System w/ 2 X MxP Metal Etch, 1 X ASP & 1 X Orientation Chambers | Etch/Ash/Strip | 6" |
| 20000766 | APPLIED MATERIALS | P-5000 MK-II Oxide Etch System w/ 3 X MK-II Oxide Etch Chambers | Etch/Ash/Strip | 8" |
| 30000399 | APPLIED MATERIALS | P-5000 MK-II PECVD System w/ 4 X CVD Chambers | CVD & Epi | 8" |
| 30000440 | APPLIED MATERIALS | P-5000 MK-II Tungsten CVD/Etch System w/ 1 X WxZ Tungsten PECVD, 1 X HeWeB Tungsten Etch & 1 X Orientation Chambers | CVD & Epi | 8" |
| 20000839 | APPLIED MATERIALS | P-5000 MxP 3 chambers | Etch/Ash/Strip | 8" |
| 20000964 | APPLIED MATERIALS | P-5000 MxP Etcher - Dry | Etch/Ash/Strip | |
| 20000965 | APPLIED MATERIALS | P-5000 MxP Etcher - Oxide | Etch/Ash/Strip | |
| 20000865 | APPLIED MATERIALS | P-5000 MxP etchers | Etch/Ash/Strip | |
| 20000767 | APPLIED MATERIALS | P-5000 Poly Etch System w/ 3 X Poly Etch Chambers | Etch/Ash/Strip | 8" |
| 50000200 | APPLIED MATERIALS | P-5000 SiN process | CVD & Epi | 8" |
| 14000161 | APPLIED MATERIALS | Precision Implant xR120S and R200S | Implant | |
| 50000189 | APPLIED MATERIALS | Producer SiC dep Metal copper shared | PVD Sputter | |
| 30000556 | APPLIED MATERIALS | PRODUCER BLOK CVD PECVD | CVD & Epi | |
| 30000557 | APPLIED MATERIALS | PRODUCER CVD | CVD & Epi | |
| 30000558 | APPLIED MATERIALS | PRODUCER cvd PECVD | CVD & Epi | |
| 30000448 | APPLIED MATERIALS | Producer CVD System w/ 3 X Twin Chambers | CVD & Epi | 8" |
| 30000468 | APPLIED MATERIALS | Producer CVD with 2 chambers | CVD & Epi | 8" |
| 50000190 | APPLIED MATERIALS | Producer metal PMD liner | PVD Sputter | |
| 50000191 | APPLIED MATERIALS | Producer metal PMDL/HARP/PEPSG | PVD Sputter | |
| 30000469 | APPLIED MATERIALS | Producer PECVD (Standard) System w/ 3 X Twin Chambers | CVD & Epi | 8" |
| 30000404 | APPLIED MATERIALS | Producer PECVD System | CVD & Epi | 8" |
| 30000470 | APPLIED MATERIALS | Producer PECVD TEOS (Shrink) System w/ 3 X Twin Chambers | CVD & Epi | 8" |
| 30000403 | APPLIED MATERIALS | Producer S | CVD & Epi | 8" |
| 30000429 | APPLIED MATERIALS | Producer Systems w/ 3 Twin Chamber Systems Available & Various Processes (Standard Frame) | CVD & Epi | 8" |
| 30000559 | APPLIED MATERIALS | Producer TEOS FSG CVD TEOS | CVD & Epi | |
| 14000189 | APPLIED MATERIALS | Quantum LEAP High current ultra low energy Implant | Ion Implant | |
| 14000179 | APPLIED MATERIALS | Quantum Leap Ion Implanter | Ion Implant | |
| 16000850 | APPLIED MATERIALS | SEM Vision cX | Metrology | |
| 90000230 | APPLIED MATERIALS | SEMvision CX | Microscopes | 8" |
| 16000979 | APPLIED MATERIALS | SEMVISION CX defect analysis | Metrology | |
| 16000980 | APPLIED MATERIALS | SEMvision Defect analysis | Metrology | |
| 16000981 | APPLIED MATERIALS | SEMVISION G2 - DEFECT REVIEW STATION (MODULE ONLY) | Metrology | |
| 16000982 | APPLIED MATERIALS | VeraSEM 3D CD SEM | Metrology | |
| 90000261 | APPLIED MATERIALS | VeraSEM cX CD/SEM Measurement System | Microscopes | 8" |
| 16000851 | APPLIED MATERIALS | Verity CD SEM | Metrology | |

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|----------|-------------------|---|------------------------|---------------------|
| 14000135 | APPLIED MATERIALS | xR 200S High Current Ion Implanter | Ion Implant | 6" |
| 14000143 | APPLIED MATERIALS | xR 80 Leap Low Energy (80 KeV) Ion Implanter | Ion Implant | 8" |
| 14000163 | APPLIED MATERIALS | XRLEAP Hi current Implant non-metal | Ion Implant | |
| 27000177 | APT | 3145 Spray Etch System | Wet Etch & Clean SRD | 5" |
| 13000424 | ASECO | S 130 Handler | Test & Handling | |
| 13000424 | ASECO | S 130 Handler | Test & Handling | |
| 13000623 | ASECO | S 150 Handler | Test & Handling | |
| 13000422 | ASECO | S 170 Handler (7mm FPBGA Elevated Ambient) | Test & Handling | |
| 13000423 | ASECO | S 170D Handler (173 mil TSSOP Elevated Ambient) | Test & Handling | |
| 24000233 | ASM | 559 wire bonders | Wire Bonders | |
| 24000234 | ASM | 559A wire bonders | Wire Bonders | |
| 10000588 | ASM | A300 Vertical Furnace | Diffusion | |
| 10000561 | ASM | A400 Vertical Furnace | Diffusion | |
| 24000171 | ASM | AB 509 Aluminum Wire Bonder | Wire Bonders | |
| 23000100 | ASM | Advance 400 Anneal | RTA/RTP | |
| 23000101 | ASM | Advance 400 XT Oxide | RTA/RTP | |
| 23000102 | ASM | Advance 412 Oxide | RTA/RTP | |
| 10000615 | ASM | DFS250 Diffusion Furnaces / LPCVD Systems, 6" | Diffusion | |
| 30000450 | ASM | E 3000 EPI System | CVD & Epi | 12" |
| 30000333 | ASM | E 3000 EPI System (Beta Tool) | CVD & Epi | 12" |
| 30000515 | ASM | Epsilon E-2000 Epi System | CVD & Epi | 8" |
| 30000532 | ASM | Epsilon E-2000 Epi System | CVD & Epi | |
| 20000892 | ASM | Flexitest Strip Handler | Etch/Ash/Strip | |
| 30000421 | ASM | Polygon 8200 Atomic Layer Deposition (ALD) Dual Chamber | CVD & Epi | 12" |
| 30000322 | ASM | Polygon 8200 Atomic Layer Deposition (ALD) System | CVD & Epi | 8" |
| 10000548 | ASM | VMP-100 LPCVD Oxide Furnace w/ TEOS | Diffusion | 6" |
| 19000261 | ASML | 1200 B ARF 193um scanner | Steppers | |
| 19000262 | ASML | 5500/250C i-line stepper, TEL Act 8 attached | Steppers | |
| 19000199 | ASML | AT 400B Twin Step & Scan System | Steppers | 12" |
| 10000595 | ASML | AVP 8000 Oxide | Diffusion | |
| 10000596 | ASML | AVP/RPV Oxide | Diffusion | |
| 19000263 | ASML | PAS 5500 i-Line Stepper | Steppers | |
| 19000228 | ASML | PAS 5500/200B i-Line Stepper - 6" reticles | Steppers | 8" |
| 19000319 | ASML | PAS 5500/300 DUV Stepper | Steppers | |
| 19000288 | ASML | PAS 5500/300c | Steppers | |
| 19000289 | ASML | PAS 5500/400D | Steppers | |
| 19000290 | ASML | PAS 5500/700C | Steppers | |
| 10000597 | ASML | RVP 300 LPCVD | Diffusion | |
| 19000291 | ASML | Twinscan XT 870 | Steppers | |
| 23000095 | AST | SHS 2800E RTP | RTA/RTP | |
| 11000260 | ASYST | DP 4200 SI wafer sorter | Miscellaneous | |
| 11000261 | ASYST | DP 4200 SI wafer sorter Copper | Miscellaneous | |
| 11000158 | ASYST | SMIF 300 Wafer Management System (WMS) | Miscellaneous | 8" |
| 10000587 | AVIZA/SVG | AVP 8000 and 8200 vertical furnaces | Diffusion | 8" |
| 10000598 | AVIZA/SVG | Planar fxP 3 chambers | Diffusion | |
| 10000616 | AVIZA/SVG | RVP-9200 Vertical furnace | Diffusion | |
| 18000038 | AXCELIS/FUSION | 150 PC UV stabilizer | Photoresist Cure/Prime | 6" |
| 20000769 | AXCELIS/FUSION | 200 ACU Asher | Etch/Ash/Strip | 6" |
| 20000020 | AXCELIS/FUSION | 200 ACU Ozone Asher | Etch/Ash/Strip | 4";5";6";8" |
| 20000020 | AXCELIS/FUSION | 200 ACU Ozone Asher | Etch/Ash/Strip | 8" |
| 20000903 | AXCELIS/FUSION | 200 MCU microwave asher | Etch/Ash/Strip | |
| 18000039 | AXCELIS/FUSION | 200 PC photostabilizer | Photoresist Cure/Prime | 8" |
| 18000015 | AXCELIS/FUSION | 200 PC UV Photostabilizer System | Photoresist Cure/Prime | 4";5";6";8" |
| 18000033 | AXCELIS/FUSION | 200 PC UV Photostabilizer System | Photoresist Cure/Prime | 6" |
| 18000015 | AXCELIS/FUSION | 200 PC UV Photostabilizer System | Photoresist Cure/Prime | 8" |
| 18000043 | AXCELIS/FUSION | 200 PCU photostabilizer | Photoresist Cure/Prime | |
| 20000904 | AXCELIS/FUSION | 202 ACU dual chamber asher | Etch/Ash/Strip | |
| 20000905 | AXCELIS/FUSION | 202 MCU dual chamber asher | Etch/Ash/Strip | |
| 14000176 | AXCELIS/FUSION | 6200 A Ion Implant system | Ion Implant | |
| 18000034 | AXCELIS/FUSION | Fusion Gemini photostabilizer | Photoresist Cure/Prime | |
| 20000764 | AXCELIS/FUSION | G03 Ozone Asher | Etch/Ash/Strip | 8" |
| 18000041 | AXCELIS/FUSION | Gemini ACU | Photoresist Cure/Prime | |
| 20000840 | AXCELIS/FUSION | Gemini Dual Chamber Asher | Etch/Ash/Strip | 8" |
| 18000029 | AXCELIS/FUSION | Gemini Dual Chamber Photostabilizer System | Photoresist Cure/Prime | 8" |
| 18000042 | AXCELIS/FUSION | Gemini GPS | Photoresist Cure/Prime | |
| 20000867 | AXCELIS/FUSION | Gemini non-metal ash | Etch/Ash/Strip | |
| 14000180 | AXCELIS/FUSION | GSD 200 E | Ion Implant | |
| 14000181 | AXCELIS/FUSION | GSD 200 E2 | Ion Implant | |
| 14000190 | AXCELIS/FUSION | GSD 200E2 high current implant | Ion Implant | |
| 14000182 | AXCELIS/FUSION | GSD HE | Ion Implant | |
| 14000191 | AXCELIS/FUSION | GSD/200E2 | Ion Implant | |

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|----------|------------------|--|------------------------|---------------------|
| 14000192 | AXCELIS/FUSION | GSD/HE | Ion Implant | |
| 20000916 | AXCELIS/FUSION | Jaguar 300 SQ asher | Etch/Ash/Strip | |
| 18000004 | AXCELIS/FUSION | M 150 PC UV Photostabilizer System | Photoresist Cure/Prime | 3";4";5";6" |
| 18000004 | AXCELIS/FUSION | M 150 PC UV Photostabilizer System | Photoresist Cure/Prime | 3";4";5";6" |
| 18000004 | AXCELIS/FUSION | M 150 PC UV Photostabilizer System | Photoresist Cure/Prime | 5";6" |
| 18000004 | AXCELIS/FUSION | M 150 PC UV Photostabilizer System | Photoresist Cure/Prime | 5";6" |
| 18000004 | AXCELIS/FUSION | M 150 PC UV Photostabilizer System | Photoresist Cure/Prime | 6" |
| 18000004 | AXCELIS/FUSION | M 150 PC UV Photostabilizer System | Photoresist Cure/Prime | 6" |
| 18000004 | AXCELIS/FUSION | M 150 PC UV Photostabilizer System | Photoresist Cure/Prime | 6" |
| 18000002 | AXCELIS/FUSION | M 200 PC UV Photostabilizer System | Photoresist Cure/Prime | 6" |
| 18000012 | AXCELIS/FUSION | M 200 PC UV Photostabilizer System | Photoresist Cure/Prime | 8" |
| 18000012 | AXCELIS/FUSION | M 200 PC UV Photostabilizer System | Photoresist Cure/Prime | 8" |
| 18000012 | AXCELIS/FUSION | M 200 PC UV Photostabilizer System | Photoresist Cure/Prime | 8" |
| 18000012 | AXCELIS/FUSION | M 200 PC UV Photostabilizer System | Photoresist Cure/Prime | 8" |
| 18000012 | AXCELIS/FUSION | M 200 PC UV Photostabilizer System | Photoresist Cure/Prime | 8" |
| 18000044 | AXCELIS/FUSION | M200PC UV Cure Photostabilizer | Photoresist Cure/Prime | |
| 14000193 | AXCELIS/FUSION | NV-GSD-80 | Ion Implant | |
| 18000022 | AXCELIS/FUSION | PS3 Dual Chamber UV Harden System | Photoresist Cure/Prime | 12" |
| 18000022 | AXCELIS/FUSION | PS3 Dual Chamber UV Harden System | Photoresist Cure/Prime | 12" |
| 50000137 | BALZERS | BA 510 Sputtering System | PVD Sputter | 2";3";4";5";6" |
| 50000134 | BALZERS | BAK 600 DC Magnetron Sputtering System | PVD Sputter | 6" |
| 40000056 | BALZERS/UNAXIS | BAK 1131 Inductive Evaporation Box Coater System | Evaporators | 8" |
| 40000049 | BALZERS/UNAXIS | BAK 510 Filament Evaporator | Evaporators | 3";4";5";6" |
| 40000055 | BALZERS/UNAXIS | BAK 760 Induction Evaporation System | Evaporators | 6";8" |
| 40000060 | BALZERS/UNAXIS | BAK EVO (760) Thermal Evaporation System | Evaporators | 6";8" |
| 16000983 | BIORAD | Quaestor Q7 Overlay Metrology System | Metrology | |
| 19000264 | BIO-RAD | Accent Q7/Q8 overlay system | Steppers | |
| 16000923 | BIO-RAD | CDS 200 | Metrology | |
| 16000815 | BIO-RAD | Q5 Wafer Overlay Inspection | Metrology | |
| 16000502 | BIO-RAD | Q5/Q6 Overlay Measurement System | Metrology | 6" |
| 16000502 | BIO-RAD | Q5/Q6 Overlay Measurement System | Metrology | 8" |
| 16000816 | BIO-RAD | Q7 Wafer Overlay Inspection | Metrology | |
| 16000611 | BIO-RAD | Q7/Q8 Overlay Measurement System | Metrology | 8" |
| 16000984 | BIO-RAD | Q7/Q8 Overlay metrology tool for up to 200 mm wafers | Metrology | |
| 16000907 | BIO-RAD | QS 2200 FTIR | Metrology | |
| 16000985 | BIO-RAD | QS 300 FTIR spectrometer | Metrology | |
| 16000986 | BIO-RAD | QS 312 FTIR spectrometer for up to 300mm wafers | Metrology | |
| 16000067 | BIO-RAD | QS-300 FTIR EPI Thickness Measurement System | Metrology | 6" |
| 16000067 | BIO-RAD | QS-300 FTIR EPI Thickness Measurement System | Metrology | 6";8" |
| 16000987 | Bio-Rad | QS-312 FTIR spectrometer | Metrology | |
| 18000035 | BIO-RAD | QS-408M FTIR Spectrometer | Metrology | |
| 16000812 | BIO-RAD | QS-500 FTIR EPI Thickness Measurement System | Metrology | 6";8" |
| 16000478 | BIO-RAD | QS-DTM FTIR Thickness Measurement System | Metrology | 8" |
| 16000797 | BIO-RAD | S-300 FTIR EPI Thickness Measurement System | Metrology | 6" |
| 27000308 | BOC EDWARDS | TCS 1 | Wet Processing | |
| 20000786 | BRANSON | 4055/2 Ashing System | Etch/Ash/Strip | 4";5";6" |
| 20000153 | BRANSON | IPC 2000 Barrel Ashing System | Etch/Ash/Strip | 5";6" |
| 20000153 | BRANSON | IPC 2000 Barrel Ashing System | Etch/Ash/Strip | 5";6" |
| 20000530 | BRANSON | IPC 3000 Plasma Ashing System | Etch/Ash/Strip | 4";5";6";8" |
| 20000530 | BRANSON | IPC 3000 Plasma Ashing System | Etch/Ash/Strip | 4";5";6";8" |
| 20000472 | BRANSON | L 3100 Plasma Barrel Ashing System | Etch/Ash/Strip | 6" |
| 20000472 | BRANSON | L 3100 Plasma Barrel Ashing System | Etch/Ash/Strip | 6" |
| 20000472 | BRANSON | L 3100 Plasma Barrel Ashing System | Etch/Ash/Strip | 6" |
| 20000893 | BRANSON | L 3200 Asher | Etch/Ash/Strip | |
| 20000815 | BRANSON | L 3200 Plasma Barrel Ashing System | Etch/Ash/Strip | 6" |
| 20000375 | BRANSON | P 2100 Barrell Ashing System | Etch/Ash/Strip | 6" |
| 20000375 | BRANSON | P 2100 Barrell Ashing System | Etch/Ash/Strip | 6" |
| 20000440 | BRANSON | P 2100 Plasma Barrel Etcher/Asher | Etch/Ash/Strip | 4";6" |
| 20000575 | BRANSON | S 2005 Ashing System | Etch/Ash/Strip | 4";5";6" |
| 20000154 | BRANSON | S 2100 Ashing System | Etch/Ash/Strip | 6" |
| 20000154 | BRANSON | S 2100 Ashing System | Etch/Ash/Strip | 6" |
| 27000309 | BREWER SCIENCE | CEE 100CB Hotplate/Spinner | Wet Processing | |
| 27000310 | BREWER SCIENCE | CEE 4000 Wafer Track | Wet Processing | |
| 10000562 | BRUCE TECHNOLOGY | BDF 200 horizontal furnace | Diffusion | |
| 10000025 | BTI | BDF 4-Stack Horizontal Furnace w/ 7351C Controller | Diffusion | 4" |
| 10000617 | BTI | BDF-4 Oxidation Furnace | Diffusion | |
| 14000164 | CAMECA | Lexes non-metal implant dose monitor | Ion Implant | |
| 30000533 | CANON | APT 6000HP BPSG | CVD & Epi | |
| 19000292 | CANON | Europa NV 193nm Scanner DUV stepper | Steppers | |
| 19000293 | CANON | FPA 1500 MK4W Fine Pattern aligner G-line stepper | Steppers | |
| 19000123 | CANON | FPA 1550 MK-II g-Line Stepper | Steppers | 5" |

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|----------|-----------------------------|---|-----------------|---------------------|
| 19000294 | CANON | FPA 2000 i1 stepper | Steppers | |
| 19000295 | CANON | FPA 2500 i2 | Steppers | 8" |
| 19000010 | CANON | FPA 3000 EX3 DUV Stepper | Steppers | 6" |
| 19000010 | CANON | FPA 3000 EX3 DUV Stepper | Steppers | 6";8" |
| 19000010 | CANON | FPA 3000 EX3 DUV Stepper | Steppers | 8" |
| 19000012 | CANON | FPA 3000 EX4 DUV Stepper | Steppers | 8" |
| 19000254 | CANON | FPA 3000 i4 i-Line Stepper | Steppers | 8" |
| 19000297 | CANON | FPA 3000 i4 stepper | Steppers | |
| 19000298 | CANON | FPA 3000 i4 stepper | Steppers | |
| 19000255 | CANON | FPA 3000 i5 i-Line Stepper | Steppers | 8" |
| 19000285 | CANON | FPA 3000 i5 i-Line Stepper | Steppers | |
| 19000220 | CANON | FPA 3000 iW Stepper | Steppers | 8" |
| 19000265 | CANON | FPA 6000 AS4 193nm scanner | Steppers | 8" |
| 19000296 | CANON | FPA-3000 EX4 deep UV stepper | Steppers | |
| 19000320 | CANON | FPA-3000 EX5 | Steppers | |
| 19000321 | CANON | FPA-3000 EX6 | Steppers | |
| 19000286 | CANON | FPA-3000 i5+ i-line stepper | Steppers | 8" |
| 19000322 | CANON | FPA-3000 iW Stepper i-line | Steppers | |
| 19000299 | CANON | FPA-5000 AS2 scanner | Steppers | |
| 19000323 | CANON | FPA-5000 ES2 Scanner KrF | Steppers | |
| 19000324 | CANON | FPA-5000 ES3 Scanner KrF | Steppers | |
| 19000300 | CANON | FPA-6000 AS4 Scanner ArF | Steppers | |
| 20000868 | CANON | MAS 8000 Plasma Photoresist Asher | Etch/Ash/Strip | 8" |
| 20000803 | CANON | MAS 8000 Plasma Photoresist Stripping System | Etch/Ash/Strip | 8" |
| 20000917 | CANON | MAS-8000 single wafer asher | Etch/Ash/Strip | |
| 17000078 | CANON | MPA 500 FAb Projection Mask Aligner System | Mask Aligners | 6" |
| 17000109 | CANON | PLA 501 F Proximity Mask Aligner System | Mask Aligners | 2";3";4" |
| 17000098 | CANON | PLA 501 FA Proximity Mask Aligner System | Mask Aligners | 5";6" |
| 30000416 | CANON/QUESTER | APT-5850 APCVD TEOS System | CVD & Epi | 8" |
| 13001275 | CASCADE | PS21 Parametric Autoprober | Test & Handling | |
| 13000518 | CASCADE | Summit 11000 Manual Probe Station (Hot/Cold) | Test & Handling | 8" |
| 16000988 | CDE | 463-FOUP resistivity mapper | Metrology | |
| 16000989 | CDE | ResMap 168 Four Point Probe Resistivity Mapping | Metrology | |
| 27000311 | CFM | Full-Flow 8050 Wet bench | | |
| 27000312 | CFM | Full-Flow 8100 Wet bench | | |
| 40000014 | CHA | Mark 50 E-Beam Evaporator | Evaporators | 4";5";6" |
| 40000014 | CHA | Mark 50 E-Beam Evaporator | Evaporators | 4";5";6" |
| 40000029 | CHA | Model SE 1000 RAP Large Bell Jar E-Beam Evaporator | Evaporators | 4";5";6" |
| 40000029 | CHA | Model SE 1000 RAP Large Bell Jar E-Beam Evaporator | Evaporators | 4";5";6" |
| 40000024 | CHA | Model SE 600 RAP Filament Evaporator | Evaporators | 4";5";6" |
| 40000024 | CHA | Model SE 600 RAP Filament Evaporator | Evaporators | 4";5";6" |
| 40000024 | CHA | Model SE 600 RAP Filament Evaporator | Evaporators | 4";5";6" |
| 40000050 | CHA | Model SEC 1000 E-Beam Evaporator | Evaporators | 4";5";6" |
| 50000174 | CHA | MPS-4 Horizontal Sputtering System w/ 3 X 4" Magnetron Cathodes | PVD Sputter | 2";3";4" |
| 17000071 | COBILT | CA-400 Mask Aligner (1X3" & 1X4") | Mask Aligners | 3";4" |
| 22000465 | CONVAC | Model 6000 2 developer Module, 3 robote handling | Tracks | 4";6" |
| 22000422 | CONVAC | Model 6000 Coat Track | Tracks | 4";6" |
| 22000421 | CONVAC | Model 6000 Develop Track | Tracks | 4";6" |
| 16000771 | CREATIVE DESIGN ENGINEERING | ResMap 168 Resistivity Mapping & Measurement System | Metrology | 6" |
| 16000642 | CREATIVE DESIGN ENGINEERING | ResMap 463-OC Resistivity Mapping & Measurement System | Metrology | 6";8";12" |
| 16000642 | CREATIVE DESIGN ENGINEERING | ResMap 463-OC Resistivity Mapping & Measurement System | Metrology | 6";8";12" |
| 13000990 | CREDENCE | ACS Calibration Station (Vista Systems) | Test & Handling | |
| 13000925 | CREDENCE | ASL-3000 Mixed Signal Test System | Test & Handling | |
| 13000925 | CREDENCE | ASL-3000 Mixed Signal Test System | Test & Handling | |
| 13000989 | CREDENCE | Calibration Station (Duo & Quartet Systems) | Test & Handling | |
| 13000987 | CREDENCE | DUO Mixed Signal Test System | Test & Handling | |
| 13000987 | CREDENCE | DUO Mixed Signal Test System | Test & Handling | |
| 13000988 | CREDENCE | DUO/SX Mixed Signal Test System | Test & Handling | |
| 13000311 | CREDENCE | DUO/XP Mixed Signal Test System | Test & Handling | |
| 13000978 | CREDENCE | IMS Electra Design Verification System | Test & Handling | |
| 13001051 | CREDENCE | Kalos II Memory Test System | Test & Handling | |
| 13000943 | CREDENCE | Kalos Memory Test System | Test & Handling | |
| 13001052 | CREDENCE | Kalos Personal Memory Test System | Test & Handling | |
| 13001244 | CREDENCE | KALOS2 HEX | Test & Handling | |
| 13000977 | CREDENCE | LT 1000 Test System | Test & Handling | |
| 13000620 | CREDENCE | LT 1001 Test System | Test & Handling | |
| 13000620 | CREDENCE | LT 1001 Test System | Test & Handling | |
| 13000621 | CREDENCE | LT 1101 Test System | Test & Handling | |

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| Item No. | OEM | Model/Description | Type | Wafer Size (Inches) |
|----------|---------------------|--|-------------------------|---------------------|
| 13001220 | CREDENCE | Octet SoC tester | Test & Handling | |
| 13000923 | CREDENCE | Quartet Mixed Signal Test System | Test & Handling | |
| 13001226 | CREDENCE | Quartet Mixed Signal Test System | Test & Handling | |
| 13000923 | CREDENCE | Quartet Mixed Signal Test System | Test & Handling | |
| 10000563 | CREDENCE | SC 212 logic tester | Test & Handling | |
| 13000571 | CREDENCE | SC 212 Mixed Signal Test System | Test & Handling | |
| 13000571 | CREDENCE | SC 212 Mixed Signal Test System | Test & Handling | |
| 13000928 | CREDENCE | SC 312 Mixed Signal Test System | Test & Handling | |
| 13001140 | CREDENCE | SC 312 Test System | Test & Handling | |
| 13000963 | CREDENCE | STS-6120 Digital Test System | Test & Handling | |
| 13000909 | CREDENCE | ValStar 2000 Test System | Test & Handling | |
| 10000589 | CREDENCE | Vanguard tester | Test & Handling | |
| 10000564 | CREDENCE | Vista Logic LT 1001 logic tester | Test & Handling | |
| 10000618 | CREDENCE | Vista Vision 1001 tester | Test & Handling | |
| 13000710 | CREDENCE | Vista Vision XP Test System | Test & Handling | |
| 10000590 | CREDENCE | Vista Vision XP Test System | Test & Handling | |
| 50000150 | CVC | 601 RF Sputtering System | PVD Sputter | 4";5";6" |
| 40000040 | CVC | E-Beam Evaporator w/ 18" X 30" Pyrex Bell Jar | Evaporators | 4";5";6" |
| 40000034 | CVC | Filiment Evapoator w/ 18"x30" Stainless Steel Bell Jar | Evaporators | 3";4";5";6" |
| 16000990 | DEKTAK | 3030 Surface Profiler | Metrology | |
| 13000757 | DELTA | 1688 Test Handler | Test & Handling | |
| 13000757 | DELTA | 1688 Test Handler | Test & Handling | |
| 13000757 | DELTA | 1688 Test Handler | Test & Handling | |
| 13000757 | DELTA | 1688 Test Handler | Test & Handling | |
| 13001141 | DELTA | Castle LX | Test & Handling | |
| 13000624 | DELTA | Daymarc 3087 Handler | Test & Handling | |
| 13000425 | DELTA | Daymarc 3287 Handler | Test & Handling | |
| 13000993 | DELTA | Daymarc 3287 Handler | Test & Handling | |
| 13000516 | DELTA | Daymarc 717 Handler | Test & Handling | |
| 13000994 | DELTA | Daymarc 717 Handler | Test & Handling | |
| 13000764 | DELTA | Daymarc 797 Handler | Test & Handling | |
| 13001142 | DELTA | Delta Castle LX handler | Test & Handling | |
| 13001143 | DELTA | Nitto Test Handler | Test & Handling | |
| 13000751 | DELTA | Turbo Flex 1210 Test Handler | Test & Handling | |
| 24000066 | DELVOTEC | 6310 Automatic Wire Bonding System | Wire Bonders | |
| 24000068 | DELVOTEC | 6320 Automatic Wire Bonding System | Wire Bonders | |
| 24000150 | DELVOTEC | 6400 Automatic Wire Bonding System | Wire Bonders | |
| 24000151 | DELVOTEC | 6400 DA Deep Access Automatic Wire Bonding System | Wire Bonders | |
| 40000062 | DENTON | 26SJ E-Beam Evaporation System | Evaporators | 8" |
| 50000204 | DENTON | Evaporator (Model DV-502C) | PVD Sputter | |
| 11000213 | DESPATCH | LAD2-11-3 Bake Oven | Miscellaneous | |
| 27000313 | DEXON PLASTICS | Au Etch Wet Bench | Wet Processing | |
| 27000314 | DEXON PLASTICS | Developer Wet Bench | Wet Processing | |
| 27000315 | DEXON PLASTICS | Dilute HF Filtered Etch Baths Wet Bench | Wet Processing | |
| 27000316 | DEXON PLASTICS | Wet Bench | Wet Processing | |
| 90000275 | DIGITAL INSTRUMENTS | Nanoscope III Scanning Probe Microscope | Microscopes | |
| 90000276 | DIGITAL INSTRUMENTS | Nanoscope III Scanning Probe Microscope | Microscopes | |
| 20000449 | DIONEX | 2000 Low Temperature Plasma Ashing System | Etch/Ash/Strip | 4";5";6";8" |
| 60000084 | DISCO | DAC 2SP/86 Automated Dicing Saw | Dicing, Marking, Taping | 6" |
| 60000200 | DISCO | DAC 552 Automated Dicing Saw | Dicing, Marking, Taping | 6" |
| 60000152 | DISCO | DAD 2H5 Dicing Saw | Dicing, Marking, Taping | 3";4";5" |
| 60000130 | DISCO | DAD 2H6 Dicing Saw | Dicing, Marking, Taping | 6" |
| 60000237 | DISCO | DAD 3350 | Dicing, Marking, Taping | |
| 60000238 | DISCO | DFD 6361 | Dicing, Marking, Taping | |
| 60000239 | DISCO | DFD 641 | Dicing, Marking, Taping | |
| 60000235 | DISCO | DFD650 dicing saw | Dicing, Marking, Taping | |
| 60000118 | DISCO | DFG 841 Back Grinder | Dicing, Marking, Taping | 4";5";6";8" |
| 22000466 | DNS | D-Spin 200W Photoresist Coat/Develop Track | Tracks | |
| 27000317 | DNS | FC 821L | Wet Processing | |
| 27000253 | DNS | FC-821L Metal/Copper shared wet hood | Wet Etch & Clean SRD | |
| 27000294 | DNS | FL 820L light etch system | Wet Etch & Clean SRD | 8" |
| 22000483 | DNS | FS 820L Wafer cleaner | Tracks | |
| 23000103 | DNS | LA 820 RTA, DNS | RTA/RTP | 8" |
| 16000632 | DNS | Lambda Ace STM-603 Plus Thickness Measurement System | Metrology | 6" |
| 22000479 | DNS | MP 2000 spin processor | Tracks | |
| 22000484 | DNS | SC 200W AV track system (coater) | Tracks | 8" |
| 22000498 | DNS | SC W60A photoresist coater | Tracks | |
| 22000433 | DNS | SCW-60A-AV Coat Track | Tracks | 6" |
| 22000445 | DNS | SCW-60A-AVP Coat Track | Tracks | 6" |
| 22000453 | DNS | SCW-623-B SOG Coat(2) Track | Tracks | 6" |

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|----------|-------------------------------|--|----------------------|---------------------|
| 22000499 | DNS | SC-W623-BVG | Tracks | |
| 22000395 | DNS | SCW-80A Silica Coat Track | Tracks | 8" |
| 22000344 | DNS | SCW-80A-AVFG SOG Curing Furnace w/ Interface | Tracks | 8" |
| 22000485 | DNS | SCW-80A-AVFGLP SOG furnace for 80A | Tracks | |
| 22000384 | DNS | SCW-80A-AVG SOG Coat Track | Tracks | 8" |
| 22000242 | DNS | SCW-80A-AVGLP SOG Coat (2) Track | Tracks | 8" |
| 22000419 | DNS | SCW-80A-AVQ Polyimide Coat Track | Tracks | 8" |
| 22000500 | DNS | SD W60A photoresist developer | Tracks | |
| 22000362 | DNS | SDW-636-BVP Developing System w/ 2 Tracks | Tracks | 6" |
| 22000480 | DNS | SK 2000 coat develop track | Tracks | |
| 22000486 | DNS | SK 2000 I line coat / development | Tracks | |
| 22000467 | DNS | SK2000 DUV coat develop | Tracks | |
| 22000468 | DNS | SK2000 i-line coat develop | Tracks | |
| 22000431 | DNS | SK-200W Coat/Develop Track | Tracks | 8" |
| 22000487 | DNS | SKW 629 BV track | Tracks | |
| 22000222 | DNS | SKW-80A-BVPE DUV Coat(1)/Develop(2) Track | Tracks | 8" |
| 27000254 | DNS | SS W80A AR Copper scrub | Wet Etch & Clean SRD | |
| 28000027 | DNS | SSW-629-B Wafer Scrubbing System | CMP | 4";6" |
| 28000027 | DNS | SSW-629-B Wafer Scrubbing System | CMP | 4";6" |
| 28000087 | DNS | SSW-80A-AR Wafer Scrubber | CMP | 8" |
| 22000501 | DNS | VP-C811 and 812 wet benches | Tracks | |
| 27000155 | DNS | WS-620C Spin Clean System | Wet Etch & Clean SRD | 6" |
| 27000255 | DNS | WS-820C doped BHF/4.9% HF hood | Wet Etch & Clean SRD | |
| 27000256 | DNS | WS-820C doped phos pre-furnace | Wet Etch & Clean SRD | |
| 27000257 | DNS | WS-820C Metal Clean Hood | Wet Etch & Clean SRD | |
| 27000258 | DNS | WS-820C metal/copper shared solvent hood | Wet Etch & Clean SRD | |
| 27000259 | DNS | WS-820C non Metal Pilot rework hood | Wet Etch & Clean SRD | |
| 27000260 | DNS | WS-820C undoped initial clean | Wet Etch & Clean SRD | |
| 27000261 | DNS | WS-820C undoped nitride ET hood | Wet Etch & Clean SRD | |
| 27000262 | DNS | WS-820C undoped nitride etch hood | Wet Etch & Clean SRD | |
| 27000263 | DNS | WS-820C undoped non phos pre-furnace | Wet Etch & Clean SRD | |
| 27000264 | DNS | WS-820C undoped split gate hood | Wet Etch & Clean SRD | |
| 27000017 | DNS | WS-820C Wet Station | Wet Etch & Clean SRD | 8" |
| 27000017 | DNS | WS-820C Wet Station | Wet Etch & Clean SRD | 8" |
| 27000265 | DNS | WS-820L 2DHF | Wet Etch & Clean SRD | 8" |
| 27000266 | DNS | WS-820L split gate hood | Wet Etch & Clean SRD | |
| 27000266 | DNS | WS-820L split gate hood | Wet Etch & Clean SRD | |
| 22000454 | DNS/DAI Nippon Screen | D-Spin 200W Photoresist Coat/Develop Track | Tracks | 8" |
| 13000543 | DYMATIX | Model 680E Manual Probe Station | Test & Handling | 6" |
| 13000838 | EAGLE | UTH/M-128 Test System | Test & Handling | |
| 14000175 | EATON | NV GSD 80 high current implanter | Ion Implant | 6" |
| 14000194 | EATON | NV-8250 medium current ion implanter | Ion Implant | |
| 14000195 | EATON | NV-GSD/200E high current Implanter | Ion Implant | |
| 14000101 | EATON / AXCELIS | GSD 200 Process Disk (Disk Only) | Ion Implant | 5" |
| 14000129 | EATON / AXCELIS | HC3 Ultra High Current Ion Implanter | Ion Implant | 12" |
| 14000183 | EATON / AXCELIS | NV 6200 A | Ion Implant | |
| 14000158 | EATON / AXCELIS | NV GSD 80 Ion Implanter | Ion Implant | 6" |
| 14000142 | EATON / AXCELIS | NV GSD Ultra 7 High Current (90 KeV) Ion Implanter | Ion Implant | 12" |
| 14000184 | EATON / AXCELIS | NV10 160 Implant System | Ion Implant | |
| 14000196 | EATON/AXCELIS | NV-GSD/200E2 High current Ion Implant | Ion Implant | |
| 28000139 | EBARA | ECP 200 Electrochemical deposition | CMP | |
| 28000150 | EBARA | EPO 113 CMP metal | CMP | |
| 28000166 | EBARA | EPO-222 CMP Tungsten | CMP | |
| 28000061 | EBARA | EPO2228 Integrated Metal or Oxide CMP/Clean System | CMP | 8" |
| 28000167 | EBARA | FREX200 CMP Oxide | CMP | |
| 28000168 | EBARA | FREX200 CMP Tungsten | CMP | |
| 11000262 | ECI | QLC-7000 ECD analysis tool copper | Metrology | |
| 12000029 | ELECTRO SCIENTIFIC INDUSTRIES | ESI 9800 Nd-YAG 1340nm | Laser Repair | |
| 13001245 | ELECTROGLAS | 3001 X Test prober | Test & Handling | |
| 13000732 | ELECTROGLAS | EG 1034 Wafer Prober | Test & Handling | 4";6" |
| 13000435 | ELECTROGLAS | EG 1034 X Wafer Probe System | Test & Handling | 5";6" |
| 13000017 | ELECTROGLAS | EG 1034 X-A6 Wafer Probe System | Test & Handling | 4";5";6" |
| 13000017 | ELECTROGLAS | EG 1034 X-A6 Wafer Probe System | Test & Handling | 4";5";6" |
| 13000017 | ELECTROGLAS | EG 1034 X-A6 Wafer Probe System | Test & Handling | 4";5";6" |
| 13000018 | ELECTROGLAS | EG 2001 Automatic Wafer Probing System | Test & Handling | 3";4";5";6" |
| 13000966 | ELECTROGLAS | EG 2001 CX Automatic Wafer Probe System | Test & Handling | 3";4";5";6" |
| 13000019 | ELECTROGLAS | EG 2001 X Automatic Wafer Probe System | Test & Handling | 3";4";5";6" |
| 13000019 | ELECTROGLAS | EG 2001 X Automatic Wafer Probe System | Test & Handling | 3";4";5";6" |
| 13000019 | ELECTROGLAS | EG 2001 X Automatic Wafer Probe System | Test & Handling | 3";4";5";6" |
| 13001246 | ELECTROGLAS | EG 2001 X Automatic Wafer Probe System | Test & Handling | |
| 13000386 | ELECTROGLAS | EG 2010 CX Automatic Wafer Probing System | Test & Handling | 3";4";5";6" |

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|----------|--------------------|---|-----------------|---------------------|
| 13000386 | ELECTROGLAS | EG 2010 CX Automatic Wafer Probing System | Test & Handling | 3";4";5";6" |
| 13000386 | ELECTROGLAS | EG 2010 CX Automatic Wafer Probing System | Test & Handling | 3";4";5";6" |
| 13000544 | ELECTROGLAS | EG 2080 Automatic Wafer Probing System | Test & Handling | 6";8" |
| 13000544 | ELECTROGLAS | EG 2080 Automatic Wafer Probing System | Test & Handling | 6";8" |
| 13000544 | ELECTROGLAS | EG 2080 Automatic Wafer Probing System | Test & Handling | 8" |
| 13000802 | ELECTROGLAS | EG 3001 X Wafer Prober | Test & Handling | 8" |
| 13001145 | ELECTROGLAS | EG 4060 XPSM Wafer Prober | Test & Handling | 8" |
| 13000803 | ELECTROGLAS | EG 4080 Wafer Prober | Test & Handling | 6" |
| 13000056 | ELECTROGLAS | EG 4080 X Automatic Wafer Probe System | Test & Handling | 8" |
| 13000056 | ELECTROGLAS | EG 4080 X Automatic Wafer Probe System | Test & Handling | 8" |
| 13001247 | ELECTROGLAS | EG 4080 X Automatic Wafer Probe System | Test & Handling | |
| 13000021 | ELECTROGLAS | EG 4080 X Automatic Wafer Probing System | Test & Handling | 8" |
| 13000731 | ELECTROGLAS | EG 4085 Wafer Prober | Test & Handling | 6";8" |
| 13000731 | ELECTROGLAS | EG 4085 Wafer Prober | Test & Handling | 6";8" |
| 13000731 | ELECTROGLAS | EG 4085 Wafer Prober | Test & Handling | 6";8" |
| 13000089 | ELECTROGLAS | EG 4085 X Automatic Wafer Prober | Test & Handling | 6";8" |
| 13000089 | ELECTROGLAS | EG 4085 X Automatic Wafer Prober | Test & Handling | 6";8" |
| 13000089 | ELECTROGLAS | EG 4085 X Automatic Wafer Prober | Test & Handling | 6";8" |
| 13000089 | ELECTROGLAS | EG 4085 X Automatic Wafer Prober | Test & Handling | 6";8" |
| 13000089 | ELECTROGLAS | EG 4085 X Automatic Wafer Prober | Test & Handling | 6";8" |
| 13000981 | ELECTROGLAS | EG 4090 Wafer Prober | Test & Handling | 8" |
| 13001227 | ELECTROGLAS | EG 4090 X wafer prober | Test & Handling | |
| 13001102 | ELECTROGLAS | EG 4090µ Wafer Prober | Test & Handling | 8" |
| 13001102 | ELECTROGLAS | EG 4090µ Wafer Prober | Test & Handling | 8" |
| 13001102 | ELECTROGLAS | EG 4090µ Wafer Prober | Test & Handling | 8" |
| 13001154 | ELECTROGLAS | EG 4090µ Wafer Prober | Test & Handling | |
| 13000859 | ELECTROGLAS | EG 5300e Wafer Prober | Test & Handling | 12" |
| 13000859 | ELECTROGLAS | EG 5300e Wafer Prober | Test & Handling | 8" |
| 13001248 | ELECTROGLAS | Pathfinder prober | Test & Handling | |
| 16000924 | ELECTROGLAS | Quicksilver lie wafer inspection | Metrology | |
| 50000192 | ELECTROTECH/TRIKON | MS 6210 Horizontal Sputter System | PVD Sputter | 4";5";6" |
| 50000096 | ELECTROTECH/TRIKON | MS 6210 Horizontal Sputter System | PVD Sputter | 4";5";6" |
| 50000096 | ELECTROTECH/TRIKON | MS 6210 Horizontal Sputter System | PVD Sputter | 5" |
| 13000927 | EPRO | 142 A Test System | Test & Handling | |
| 13000632 | EPRO | 142 AX Test System | Test & Handling | |
| 13000632 | EPRO | 142 AX Test System | Test & Handling | |
| 13000632 | EPRO | 142 AX Test System | Test & Handling | |
| 24000228 | ESEC | 2008HS3 Die Bonding System | Wire Bonders | |
| 13001276 | ESEC | 3001 Wire Bonders | Test & Handling | |
| 24000063 | ESEC | 3006 F/X Wire Bonding System | Wire Bonders | |
| 24000235 | ESEC | 3008 wire bonder | Wire Bonders | |
| 24000236 | ESEC | 3088 wire bonders | Wire Bonders | |
| 24000237 | ESEC | 3100 wire bonders | Wire Bonders | |
| 24000238 | ESEC | KNS 1488 wire bonders | Wire Bonders | |
| 24000239 | ESEC | KNS 8020 wire bonders | Wire Bonders | |
| 24000240 | ESEC | KNS 8028 wire bonders | Wire Bonders | |
| 12000002 | ESI | 1225 laser repair tool | Laser Repair | 5" |
| 12000024 | ESI | 4370 Laser Cut System | Laser Repair | |
| 12000032 | ESI | 9000 laser repair | Laser Repair | |
| 12000012 | ESI | 9250A Laser Repair System | Laser Repair | 4";5";6";8" |
| 12000008 | ESI | 9250B Laser Repair System | Laser Repair | 4";5";6";8" |
| 12000033 | ESI | 9300 Laser processing system | Laser Repair | |
| 12000034 | ESI | 9350 Laser Processing system | Laser Repair | |
| 12000028 | ESI | 9350 laser repair tool | Laser Repair | |
| 12000035 | ESI | 9820 Laser processing system | Laser Repair | |
| 12000027 | ESI | 9820 Laser Repair System | Laser Repair | 8";12" |
| 12000027 | ESI | 9820 Laser Repair System | Laser Repair | 8";12" |
| 25000057 | ETEC | ARIS-1 Defect Inspection System | Photomasks | |
| 25000064 | ETEC | Mebes 4700 E-Beam Photomask Pattern Generator | Photomasks | |
| 25000056 | ETEC | Mebes 5000 E-Beam Photomask Pattern Generator | Photomasks | |
| 22000502 | FAIRCHILD | Falcon DUJ Cluster, 2 Coaters and 1 Developer, 8" | Tracks | |
| 27000318 | FAS | MicroE-200 Extrusion Coater | Wet Processing | |
| 22000307 | FAS TECHNOLOGIES | Micro E 200 C-to-C Extrusion Coating System | Tracks | 4" |
| 22000306 | FAS TECHNOLOGIES | Micro E 200 Extrusion Coating System | Tracks | 4" |
| 25000059 | FEI | Accura 800 FIB Mask Repair System | Photomasks | |
| 90000183 | FEI | XL 810 SFEG System | Microscopes | 6";8" |
| 90000210 | FEI | XL 830 SFEG Dual Bean FIB System | Microscopes | 8" |
| 11000172 | FLUOROWARE | HTC 4000 Box Washer | Miscellaneous | 6" |
| 11000075 | FLUOROWARE | HTC 8000 Box Washer | Miscellaneous | 6" |
| 11000254 | FLUOROWARE | HTC 8010 Box Washer | Miscellaneous | 6" |
| 16000784 | FOUR DIMENSIONS | 280C Automated 4-Point Probe System | Metrology | 4";5";6" |

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|----------|--------------|---|-------------------------|---------------------|
| 27000222 | FSI | Antaries Cryo Clean Hood | Wet Etch & Clean SRD | 8" |
| 27000223 | FSI | Aries Cryokinetic Surface Conditioning System | Wet Etch & Clean SRD | 8" |
| 27000267 | FSI | Excalibur dual excalibur | Wet Etch & Clean SRD | 8" |
| 27000001 | FSI | Excalibur HF Etcher | Wet Etch & Clean SRD | 8" |
| 27000001 | FSI | Excalibur HF Etcher | Wet Etch & Clean SRD | 8" |
| 27000001 | FSI | Excalibur HF Etcher | Wet Etch & Clean SRD | 8" |
| 27000268 | FSI | Magellan universal hood | Wet Etch & Clean SRD | |
| 27000295 | FSI | Mercury | Wet Etch & Clean SRD | |
| 27000269 | FSI | Mercury MP Metal spray acid TIST | Wet Etch & Clean SRD | |
| 27000270 | FSI | Mercury MP metal/copper shared dummy hood | Wet Etch & Clean SRD | |
| 27000271 | FSI | Mercury MP non metal spray acid hood | Wet Etch & Clean SRD | |
| 27000212 | FSI | Model 8221 SRD | Wet Etch & Clean SRD | 6" |
| 18000036 | FSI | Polaris 2000 coater develop cluster tool | Photoresist Cure/Prime | |
| 22000503 | FSI | POLARIS 2000, 2 Coaters, 2 Deveopers, 8" | Tracks | |
| 18000037 | FSI | Polaris 2500 coat develop cluster tool | Photoresist Cure/Prime | |
| 27000296 | FSI | Zeta 200 FE | Wet Etch & Clean SRD | |
| 27000272 | FSI | Zeta 200 Metal | Wet Etch & Clean SRD | |
| 16000596 | FSM | 128 Stress Measurement System | Metrology | 6" |
| 16000597 | FSM | 8800 Stress Measurement System | Metrology | 6" |
| 20000869 | FUSION | 200 MCU metal copper shared metal ash | Etch/Ash/Strip | |
| 20000870 | FUSION | 200 MCU non-metal ash metal | Etch/Ash/Strip | |
| 18000045 | FUSION | 200PCU | Photoresist Cure/Prime | |
| 16000817 | FUSION | Microlite M200 DUV | Metrology | 6" |
| 16000533 | GAERTNER | L 115 Ellipsometer | Metrology | 4";5";6" |
| 16000534 | GAERTNER | L 116 Ellipsometer | Metrology | 6" |
| 16000535 | GAERTNER | L 117 Ellipsometer | Metrology | 6" |
| 16000706 | GAERTNER | Stokes LSE Manual Ellipsometer | Metrology | 6";8";12" |
| 20000966 | GASONICS | 9104 Etcher | Etch/Ash/Strip | |
| 20000842 | GASONICS | A3010 Dry Asher with single chamber | Etch/Ash/Strip | 6";8" |
| 20000287 | GASONICS | Aura 1000 Ashing System | Etch/Ash/Strip | 6" |
| 20000633 | GASONICS | Aura 2000 Etch System | Etch/Ash/Strip | 8" |
| 20000023 | GASONICS | Aura 2000-LL Photoresist Ashing System | Etch/Ash/Strip | 6";8" |
| 20000918 | GASONICS | L3200 ashing system | Etch/Ash/Strip | |
| 14000197 | GASONICS | L3510 Asher | Etch/Ash/Strip | |
| 14000198 | GASONICS | PEP 3510A Asher | Etch/Ash/Strip | |
| 20000919 | GASONICS | PEP 4800 DL Iridia etch | Etch/Ash/Strip | 8" |
| 20000967 | GASONICS | PEP 4800DL Iridia | Etch/Ash/Strip | |
| 20000745 | GASONICS | PEP Iridia 4800 DL Ashing System w/ 2 X Iridia DL Process Chambers & 2 X Cool Down Stations | Etch/Ash/Strip | 8" |
| 20000820 | GASONICS | PEP Iridia Ashing System | Etch/Ash/Strip | 8" |
| 19000203 | GCA | 6300 Stepper | Steppers | 6" |
| 19000204 | GCA | 8000 Stepper | Steppers | 6" |
| 19000205 | GCA | 8500 g-Line Stepper | Steppers | 6" |
| 19000266 | GCA | ALS 200 Superstep, i-line wafersteppers | Steppers | 8" |
| 19000325 | GCA | XLS 7800 DUV Stepper | Steppers | |
| 16000585 | GCA/TROPEL | Model 9000 Surface Flatness Measurement System | Metrology | 8" |
| 30000340 | GEMINI | Gemini 3 Dual Chamber EPI Reactor | CVD & Epi | 6";8" |
| 13000995 | GENRAD | AccelerATE Board Tester | Test & Handling | |
| 13000664 | GENRAD | GR 2283i Board Tester | Test & Handling | |
| 13000665 | GENRAD | GR 2286E Board Tester | Test & Handling | |
| 13000667 | GENRAD | GR 2287E Board Tester | Test & Handling | |
| 30000405 | GENUS | 8700 Tungsten CVD System | CVD & Epi | 5";6" |
| 30000494 | GENUS | 8710 CVD | CVD & Epi | |
| 30000495 | GENUS | 8720 CVD | CVD & Epi | |
| 30000337 | GENUS | Lynx 2 ALD System | CVD & Epi | 8" |
| 30000337 | GENUS | Lynx 2 ALD System | CVD & Epi | 8" |
| 14000144 | GENUS/VARIAN | 1510 High Energy Implant System | Ion Implant | 6";8" |
| 14000146 | GENUS/VARIAN | 1520 High Energy Implant System | Ion Implant | 8" |
| 60000136 | GSI LUMONICS | HM 1400 L Laser Marking System | Dicing, Marking, Taping | 4";5";6" |
| 60000240 | GSI LUMONICS | M435 | Dicing, Marking, Taping | |
| 60000236 | GSI LUMONICS | Sigma clean diode laser marking system 100 - 200nm wfrs | Dicing, Marking, Taping | 4";5";6";8" |
| 60000046 | GSI LUMONICS | WaferMark 345-1 Laser Scribe System | Dicing, Marking, Taping | 5";6" |
| 60000047 | GSI LUMONICS | WaferMark 345-2 Laser Scribe System | Dicing, Marking, Taping | 2";3";4";5";6" |
| 60000039 | GSI LUMONICS | WaferMark II Laser Scribe System | Dicing, Marking, Taping | 4";5";6" |
| 60000241 | GSI LUMONICS | WaferMark Sigma DSC | Dicing, Marking, Taping | |
| 60000242 | GSI LUMONICS | WaferMark SigmaClean | Dicing, Marking, Taping | |
| 60000228 | GSI LUMONICS | WaferMark SigmaClean Laser Scribe System (Available April 2008) | Dicing, Marking, Taping | 4";5";6";8" |
| 60000138 | GSI LUMONICS | WH 4100 Backside Die Marking System | Dicing, Marking, Taping | 8" |
| 13000404 | HILEVEL | ETS 300 IC Test System | Test & Handling | |
| 16000925 | HITACHI | 8840 CD SEM | Metrology | 6" |

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| Item No. | OEM | Model/Description | Type | Wafer Size (Inches) |
|----------|-------------------|--|-----------------|---------------------|
| 9000249 | HITACHI | HM2000 Electron Microscope | Microscopes | 6 |
| 16000926 | HITACHI | IS 100 | Metrology | |
| 16000927 | HITACHI | IS 2600 | Metrology | |
| 90000273 | HITACHI | IS-3270 patterned wafer inspection system | Microscopes | |
| 16000928 | HITACHI | LM 100 | Metrology | |
| 90000250 | HITACHI | LS-6000 CD/SEM | Microscopes | 6" |
| 16000819 | HITACHI | LS6500 Particle Counter | Metrology | 8 |
| 20000520 | HITACHI | M 206 A Poly Etch System | Etch/Ash/Strip | 5" |
| 20000920 | HITACHI | M 531A W Interconnect etcher | Etch/Ash/Strip | 8" |
| 20000921 | HITACHI | M 612 Poly stilicon etcher | Etch/Ash/Strip | 8" |
| 16000929 | HITACHI | M208 Metal | Metrology | |
| 16000930 | HITACHI | M511 | Metrology | |
| 90000277 | HITACHI | PD-3000 particle detection system | | |
| 90000274 | HITACHI | S 4500 SEM | Microscopes | |
| 90000275 | HITACHI | S 4700 SEM | Microscopes | |
| 90000246 | HITACHI | S-4500 SEM Type 1 | Microscopes | 6" |
| 90000262 | HITACHI | S-4700 SEM Field Emission Gun, 1.5nm resolution | Microscopes | |
| 90000228 | HITACHI | S-4700 SEM Type 1 | Microscopes | 4" |
| 90000149 | HITACHI | S-5000 SEM | Microscopes | 8" |
| 90000276 | HITACHI | S-5000 SEM | Microscopes | 8" |
| 90000149 | HITACHI | S-5000 SEM | Microscopes | 8" |
| 90000006 | HITACHI | S-6000 CD/SEM | Microscopes | 5",6" |
| 90000006 | HITACHI | S-6000 CD/SEM | Microscopes | 5",6" |
| 90000251 | HITACHI | S-6000 CD/SEM | Microscopes | 6" |
| 90000007 | HITACHI | S-6100 CD/SEM | Microscopes | 6" |
| 90000007 | HITACHI | S-6100 CD/SEM | Microscopes | 6" |
| 90000007 | HITACHI | S-6100 CD/SEM | Microscopes | 6" |
| 90000252 | HITACHI | S-6180 CD/SEM | Microscopes | 6" |
| 90000202 | HITACHI | S-6280 CD/SEM | Microscopes | 6" |
| 90000081 | HITACHI | S-6700 CD/SEM | Microscopes | 6" |
| 90000253 | HITACHI | S-6700 CD/SEM | Microscopes | 6" |
| 90000081 | HITACHI | S-6700 CD/SEM | Microscopes | 6" |
| 90000009 | HITACHI | S-7000 CD/SEM | Microscopes | 5",6" |
| 90000009 | HITACHI | S-7000 CD/SEM | Microscopes | 5",6" |
| 90000009 | HITACHI | S-7000 CD/SEM | Microscopes | 5",6" |
| 90000254 | HITACHI | S-7000 CD/SEM | Microscopes | 6" |
| 90000255 | HITACHI | S-7280 CD/SEM | Microscopes | 6" |
| 90000220 | HITACHI | S-7280H CD/SEM | Microscopes | 6" |
| 90000150 | HITACHI | S-7800 CD/SEM | Microscopes | 8" |
| 90000237 | HITACHI | S-7840 CD/SEM | Microscopes | 8" |
| 90000048 | HITACHI | S-806 C Wafer Inspection Field Emission (FE) SEM | Microscopes | 6" |
| 90000048 | HITACHI | S-806 C Wafer Inspection Field Emission (FE) SEM | Microscopes | 6" |
| 90000144 | HITACHI | S-806 E Wafer Inspection Field Emission (FE) SEM | Microscopes | 6" |
| 90000277 | HITACHI | S-808 wafer inspection SEM | Microscopes | |
| 90000200 | HITACHI | S-8620 CD/SEM | Microscopes | 6" |
| 90000200 | HITACHI | S-8620 CD/SEM | Microscopes | 6" |
| 90000256 | HITACHI | S-8800 CD/SEM | Microscopes | 8" |
| 90000012 | HITACHI | S-8820 CD/SEM | Microscopes | 6" |
| 90000012 | HITACHI | S-8820 CD/SEM | Microscopes | 8" |
| 90000012 | HITACHI | S-8820 CD/SEM | Microscopes | 8" |
| 90000278 | HITACHI | S-8820 CD/SEM | Microscopes | |
| 90000279 | HITACHI | S-8840 | Microscopes | |
| 90000278 | HITACHI | S-8840 CD SEM critical dimension | Metrology | |
| 90000257 | HITACHI | S-8840 CD/SEM | Microscopes | 8" |
| 90000279 | HITACHI | S-9200 CD SEM critical dimension | Metrology | |
| 90000280 | HITACHI | S-9220 CD SEM | Microscopes | |
| 90000280 | HITACHI | S-9220 CD SEM critical dimension | Metrology | |
| 90000281 | HITACHI | S-9260 CD SEM critical dimension | Metrology | |
| 90000281 | HITACHI | S-9360 | Microscopes | |
| 90000282 | HITACHI | S-9380 II | Microscopes | |
| 27000319 | HITACHI | Super Catalytic Decomposition System | Wet Processing | |
| 90000283 | HITACHI | UA-7200 | Microscopes | |
| 16000991 | HITACHI | Z-8270 Spectrometer - polarized Zeeman Atomic absorption | Metrology | |
| 10000485 | HITACHI / KOKUSAI | Quixace Furnace | Diffusion | 12" |
| 20000901 | HITACHI/KOKUSAI | Lambda asher dual chamber | Etch/Ash/Strip | 8" |
| 13001277 | HP | 4145A/B parametric analyzer | Test & Handling | |
| 13000914 | HP/AGILENT | 4062 UX Parametric Test System | Test & Handling | 8" |
| 13001212 | HP/AGILENT | 4062UX parametric tester | Test & Handling | 8" |
| 13001249 | HP/AGILENT | 4071 parametric tester | Test & Handling | |
| 13001278 | HP/AGILENT | 4071A Parametric Tester | Test & Handling | |

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|----------|-------------------|---|-----------------|---------------------|
| 13001279 | HP/AGILENT | 4072A Parametric Tester | Test & Handling | |
| 13001250 | HP/AGILENT | 4145 parametric tester | Test & Handling | |
| 13001213 | HP/AGILENT | 5156B parametric tester | Test & Handling | 8" |
| 13000025 | HP/AGILENT | 82000 Digital VLSI Test System (D-100 & D-200 Models available) | Test & Handling | |
| 13001114 | HP/AGILENT | 83000 F120t Digital VLSI Test System | Test & Handling | |
| 13000387 | HP/AGILENT | 83000 F330t Digital VLSI Test System | Test & Handling | |
| 13000387 | HP/AGILENT | 83000 F330t Digital VLSI Test System | Test & Handling | |
| 13000387 | HP/AGILENT | 83000 F330t Digital VLSI Test System | Test & Handling | |
| 13000813 | HP/AGILENT | 83000 F50t Digital VLSI Test System | Test & Handling | |
| 13000314 | HP/AGILENT | 83000 F660i Digital VLSI Test System (96 Pins) | Test & Handling | |
| 13001116 | HP/AGILENT | 84000 RFI Test System | Test & Handling | |
| 13001228 | HP/AGILENT | 9300 test system | Test & Handling | |
| 13001117 | HP/AGILENT | 93000 C200e Mixed Signal Test System | Test & Handling | |
| 13001084 | HP/AGILENT | 93000 C400 Mixed Signal Test System | Test & Handling | |
| 13001086 | HP/AGILENT | 93000 P1000 Mixed Signal Test System | Test & Handling | |
| 13001085 | HP/AGILENT | 93000 P600 Mixed Signal Test System | Test & Handling | |
| 13001221 | HP/AGILENT | 93000 tester - SoC | Test & Handling | |
| 13000982 | HP/AGILENT | 94000 Mixed Signal Test System | Test & Handling | |
| 13000982 | HP/AGILENT | 94000 Mixed Signal Test System | Test & Handling | |
| 13000774 | HP/AGILENT | 95000 High Speed Memory Test System | Test & Handling | |
| 13001146 | HP/AGILENT | HP93K test system | Test & Handling | |
| 13001251 | HP/AGILENT | V3308 memory tester | Test & Handling | |
| 13001252 | HP/AGILENT | V4400 memory tester | Test & Handling | |
| 13001147 | HP/AGILENT | VersaTest V1004 & 1316 Test Systems | Test & Handling | |
| 13001031 | HP/AGILENT | VersaTest V1004 Test System | Test & Handling | |
| 13001032 | HP/AGILENT | VersaTest V1008 Test System | Test & Handling | |
| 13001017 | HP/AGILENT | VersaTest V4400 Memory Test System | Test & Handling | |
| 13000979 | HP/AGILENT | VersaTest V4436 Memory Test System | Test & Handling | |
| 13001280 | HSEB Dresden GMBH | Axiospect wafer inspection system | Test & Handling | |
| 28000134 | IPEC | 372 CMP | CMP | |
| 28000135 | IPEC | 676 CMP | CMP | |
| 28000136 | IPEC | 676 mainframe tungsten polish | CMP | |
| 28000169 | IPEC | AvantGaard 776 CMP Oxide | CMP | |
| 28000170 | IPEC WESTEC | AVANTI 472 Chemical Mechanical Polisher | CMP | |
| 11000255 | IRVINE OPTICAL | Ultrasort 208 Wafer Sorting System | Miscellaneous | 8" |
| 16000691 | IVS | 200 Wafer Inspection System | Metrology | 8" |
| 13001281 | IVS | ACV4 Overlay measurement system | Test & Handling | |
| 90000282 | JEOL | JFS-9855S SEM FIB | Microscopes | |
| 90000197 | JEOL | JSM 6400 Digital SEM | Microscopes | |
| 90000227 | JEOL | JSM 6600F Digital SEM | Microscopes | 6",8" |
| 90000108 | JEOL | JWS 7500E CD/SEM | Microscopes | 6" |
| 90000108 | JEOL | JWS 7500E CD/SEM | Microscopes | 6",8" |
| 90000108 | JEOL | JWS 7500E CD/SEM | Microscopes | 8" |
| 90000108 | JEOL | JWS 7500E CD/SEM | Microscopes | 8" |
| 90000015 | JEOL | JWS 7505 CD/SEM | Microscopes | 6",8" |
| 90000015 | JEOL | JWS 7505 CD/SEM | Microscopes | 8" |
| 90000185 | JEOL | JWS 7505-ZH CD/SEM | Microscopes | 8" |
| 90000185 | JEOL | JWS 7505-ZH CD/SEM | Microscopes | 8" |
| 90000129 | JEOL | JWS 7515 CD/SEM | Microscopes | 6",8" |
| 90000129 | JEOL | JWS 7515 CD/SEM | Microscopes | 8" |
| 90000129 | JEOL | JWS 7515 CD/SEM | Microscopes | 8" |
| 90000129 | JEOL | JWS 7515 CD/SEM | Microscopes | 8" |
| 90000238 | JEOL | JWS 7550 CD/SEM | Microscopes | 8" |
| 90000108 | JEOL | JWS 7700 CD/SEM | Microscopes | 6" |
| 90000148 | JEOL | JWS 7700 CD/SEM | Microscopes | 8" |
| 90000148 | JEOL | JWS 7700 CD/SEM | Microscopes | 8" |
| 90000284 | JEOL | JWS 7700 CD/SEM | Microscopes | |
| 90000283 | JEOL | Scanning Electron Microscope JWS-7500E | Microscopes | |
| 11000264 | JOEL | 7555 SEM | Metrology | |
| 27000320 | JST | Stainless Steel Wet Bench | Wet Processing | |
| 24000072 | K & S | 1470-4 Aluminum/Gold Wedge Bonder | Wire Bonders | |
| 24000005 | K & S | 1471 Automatic Wire Bonder | Wire Bonders | |
| 24000005 | K & S | 1471 Automatic Wire Bonder | Wire Bonders | |
| 24000022 | K & S | 1482 Automatic Wire Bonder | Wire Bonders | |
| 24000017 | K & S | 1488L Turbo Wire Bonder | Wire Bonders | |
| 24000017 | K & S | 1488L Turbo Wire Bonder | Wire Bonders | |
| 24000040 | K & S | 4123 Manual Aluminum/Gold 45 Degree Wedge Bonder | Wire Bonders | |
| 24000122 | K & S | 4124 Gold Wire Bonder | Wire Bonders | |
| 24000143 | K & S | 4129 Deep Access Manual Wedge Bonder | Wire Bonders | |

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|----------|-----------------|---|-------------------------|---------------------|
| 24000023 | K & S | 5408-15 EM Die Attach System | Wire Bonders | 5";6";8" |
| 24000230 | K & S | 6496 semi-automatic die attacher | Wire Bonders | |
| 24000178 | K & S | 6497 Semi-Automatic Flip Chip Die Bonding System | Wire Bonders | |
| 60000186 | K & S | 7100 Dicing Saw for Hard Materials | Dicing, Marking, Taping | 8" |
| 60000087 | K & S | 775 Dicing Saw | Dicing, Marking, Taping | 2";3";4";5";6" |
| 60000069 | K & S | 780 Dicing Saw | Dicing, Marking, Taping | 2";3";4";5";6" |
| 24000231 | K & S | 8020 automatic ball bonder | Wire Bonders | |
| 24000220 | K & S | 8028 PPS Wire Bonder | Wire Bonders | |
| 24000032 | K & S | 8060 Automatic Gold Wedge Bonding System | Wire Bonders | |
| 24000032 | K & S | 8060 Automatic Gold Wedge Bonding System | Wire Bonders | |
| 24000232 | K & S | 8060 automatic wedge bonder | Wire Bonders | |
| 24000229 | K & S | 8060 wire bonder | Wire Bonders | |
| 24000219 | K & S | 9388 BGA/CSP Ball Attach System | Wire Bonders | |
| 60000233 | K & S | 982-10 Dicing saw | Dicing, Marking, Taping | |
| 24000218 | KAJO | FB 118A Wire Bonder | Wire Bonders | |
| 24000225 | KAJO | FB131 wire bonder | Wire Bonders | |
| 24000019 | KARL SUSS | FC 250 Flip Chip Bonding System | Wire Bonders | |
| 17000037 | KARL SUSS | MA 150 Mask Aligner | Mask Aligners | 4";5";6" |
| 17000037 | KARL SUSS | MA 150 Mask Aligner | Mask Aligners | 4";5";6" |
| 17000037 | KARL SUSS | MA 150 Mask Aligner | Mask Aligners | 4";5";6" |
| 17000101 | KARL SUSS | MA 24 Mask Aligner | Mask Aligners | 4";5";6" |
| 17000102 | KARL SUSS | MA 25 Mask Aligner | Mask Aligners | 4";5";6" |
| 17000108 | KARL SUSS | MA 4 Mask Aligner | Mask Aligners | 4";5";6" |
| 17000087 | KARL SUSS | MA 46 Mask Aligner | Mask Aligners | 4";5";6" |
| 17000028 | KARL SUSS | MA 56 Mask Aligner | Mask Aligners | 3";5";6" |
| 17000112 | KARL SUSS | MA150 Mask Aligner | Mask Aligners | |
| 17000106 | KARL SUSS | MA8/BSA Double Sided Mask Aligner | Mask Aligners | 2";3";4";5";6";8" |
| 17000106 | KARL SUSS | MA8/BSA Double Sided Mask Aligner | Mask Aligners | 2";3";4";5";6";8" |
| 17000036 | KARL SUSS | MJB 21 Double Sided Mask Aligner | Mask Aligners | 2";3";4";5";6" |
| 17000068 | KARL SUSS | MJB 3 Mask Aligner | Mask Aligners | 2";3";4" |
| 17000029 | KARL SUSS | MJB 55 Proximity Mask Aligner | Mask Aligners | 4";5";6" |
| 60000189 | KARL SUSS | RA 120M Wafer Scribing System | Dicing, Marking, Taping | 6" |
| 16000992 | KEITHLEY | Quantox 64000 Silicon and Oxide Monitoring System | Metrology | |
| 11000265 | KENSINGTON | CSMT-4 Wafer Sorting System | Miscellaneous | |
| 11000253 | KENSINGTON LABS | CSMT-393-355-06 Wafer Sorting System | Miscellaneous | 8" |
| 11000252 | KENSINGTON LABS | CSMT-4 Wafer Sorting System (4 Cassettes) | Miscellaneous | 6" |
| 14000165 | Kestrel | 650 Implanter | Ion Implant | |
| 14000166 | Kestrel | 750 Implanter | Ion Implant | |
| 16000334 | KEVEX | Boron/Phosphorus X-Ray Measurement System | Metrology | 8" |
| 90000284 | KLA | 8100 CD-SEM | Microscopes | |
| 16000931 | KLA | Viper 2401 | Metrology | |
| 16000245 | KLA/KEITHLEY | 4-Point Probe Resistivity Measurement System | Metrology | 4";5";6";8" |
| 13000855 | KLA/KEITHLEY | S-350 Parametric Tester | Test & Handling | |
| 13001133 | KLA/KEITHLEY | S-630 Parametric Tester | Test & Handling | |
| 16000908 | KLA/PROMETRIX | FT 750 film thickness measurement | Metrology | |
| 16000607 | KLA/PROMETRIX | FT-500 Thickness Measurement System | Metrology | 3";4";5";6";8" |
| 16000039 | KLA/PROMETRIX | FT-530 Thickness Measurement System | Metrology | 3";4";5";6";8" |
| 16000039 | KLA/PROMETRIX | FT-530 Thickness Measurement System | Metrology | 3";4";5";6";8" |
| 16000040 | KLA/PROMETRIX | FT-600 Thickness Measurement System | Metrology | 4";5";6";8" |
| 16000041 | KLA/PROMETRIX | FT-650 Thickness Measurement System | Metrology | 5";6";8" |
| 16000041 | KLA/PROMETRIX | FT-650 Thickness Measurement System | Metrology | 5";6";8" |
| 16000041 | KLA/PROMETRIX | FT-650 Thickness Measurement System | Metrology | 8" |
| 16000602 | KLA/PROMETRIX | FT-700 Thickness Measurement System | Metrology | 6";8" |
| 16000602 | KLA/PROMETRIX | FT-700 Thickness Measurement System | Metrology | 8" |
| 16000148 | KLA/PROMETRIX | FT-750 Thickness Measurement System | Metrology | 8" |
| 16000148 | KLA/PROMETRIX | FT-750 Thickness Measurement System | Metrology | 8" |
| 16000148 | KLA/PROMETRIX | FT-750 Thickness Measurement System | Metrology | 8" |
| 16000029 | KLA/PROMETRIX | NC-110 Non-Contact Resistivity Measurement System | Metrology | 2";3";4";5";6";8" |
| 16000029 | KLA/PROMETRIX | NC-110 Non-Contact Resistivity Measurement System | Metrology | 2";3";4";5";6";8" |
| 16000029 | KLA/PROMETRIX | NC-110 Non-Contact Resistivity Measurement System | Metrology | 2";3";4";5";6";8" |
| 16000747 | KLA/PROMETRIX | OmniMap RS 100 Resistivity Measurement System | Metrology | 8" |
| 16000820 | KLA/PROMETRIX | OmniMap RS 100 Resistivity Measurement System | Metrology | 8" |
| 16000262 | KLA/PROMETRIX | OmniMap RS 35c Resistivity Measurement System | Metrology | 2";3";4";5";6";8" |
| 16000262 | KLA/PROMETRIX | OmniMap RS 35c Resistivity Measurement System | Metrology | 2";3";4";5";6";8" |
| 16000598 | KLA/PROMETRIX | OmniMap RS 50 Resistivity Measurement System | Metrology | 6";8" |
| 16000601 | KLA/PROMETRIX | OmniMap RS 50/e Resistivity Measurement System | Metrology | 4";5";6";8" |
| 16000601 | KLA/PROMETRIX | OmniMap RS 50/e Resistivity Measurement System | Metrology | 4";5";6";8" |
| 16000030 | KLA/PROMETRIX | OmniMap RS 55/tc Resistivity Measurement System | Metrology | 6";8" |
| 16000030 | KLA/PROMETRIX | OmniMap RS 55/tc Resistivity Measurement System | Metrology | 6";8" |
| 16000030 | KLA/PROMETRIX | OmniMap RS 55/tc Resistivity Measurement System | Metrology | 6";8" |
| 16000030 | KLA/PROMETRIX | OmniMap RS 55/tc Resistivity Measurement System | Metrology | 6";8" |

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| 16000030 | KLA/PROMETRIX | OmniMap RS 55/tc Resistivity Measurement System - used in Copper Process | Metrology | 6",8" |
| 16000794 | KLA/PROMETRIX | OmniMap RS 75/tc Resistivity Measurement System | Metrology | 6",8" |
| 16000932 | KLA/PROMETRIX | RS 35c resistivity mapping tool | Metrology | 6" |
| 16000205 | KLA/PROMETRIX | UV 1050 Film Thickness Measurement System | Metrology | 6" |
| 16000205 | KLA/PROMETRIX | UV 1050 Film Thickness Measurement System | Metrology | 6",8" |
| 16000205 | KLA/PROMETRIX | UV 1050 Film Thickness Measurement System | Metrology | 6",8" |
| 16000781 | KLA/PROMETRIX | UV 1250SE Film Thickness Measurement System | Metrology | 6",8" |
| 13000028 | KLA/TENCOR | 1007 Wafer Probe System | Test & Handling | 3",4",5",6" |
| 13000028 | KLA/TENCOR | 1007 Wafer Probe System | Test & Handling | 6" |
| 13000614 | KLA/TENCOR | 1011 Ace Wafer Probe System | Test & Handling | 6" |
| 13001253 | KLA/TENCOR | 1201 wafer prober | Test & Handling | 6" |
| 13000763 | KLA/TENCOR | 1220 Wafer Probe System | Test & Handling | 6" |
| 25000029 | KLA/TENCOR | 209 Defect Inspection System | Photomasks | |
| 16000821 | KLA/TENCOR | 2111 Wafer Inspection System | Metrology | 8" |
| 16000822 | KLA/TENCOR | 2130 Wafer Inspection System | Metrology | 8" |
| 16000652 | KLA/TENCOR | 2131 Pattern Defect Inspection System | Metrology | 8" |
| 16000823 | KLA/TENCOR | 2131E Wafer Inspection System | Metrology | 8" |
| 16000824 | KLA/TENCOR | 2132 Wafer Inspection System | Metrology | 8" |
| 16000933 | KLA/TENCOR | 2132 Wafer Inspection System | Metrology | |
| 16000446 | KLA/TENCOR | 2135 Pattern Defect Inspection System | Metrology | 8" |
| 16000909 | KLA/TENCOR | 2135 wafer inspection system | Metrology | |
| 16000825 | KLA/TENCOR | 2138 Pattern Defect Inspection System | Metrology | 8" |
| 16000854 | KLA/TENCOR | 2138 Patterned defect inspection system | Metrology | |
| 16000855 | KLA/TENCOR | 2138 wafer inspect | Metrology | |
| 16000934 | KLA/TENCOR | 2138 wafer inspection | Metrology | |
| 16000910 | KLA/TENCOR | 2138 wafer inspection system | Metrology | |
| 16000715 | KLA/TENCOR | 2138 XP Pattern Defect Inspection System | Metrology | 8" |
| 16000715 | KLA/TENCOR | 2138 XP Pattern Defect Inspection System | Metrology | 8" |
| 16000753 | KLA/TENCOR | 2139 Pattern Defect Inspection System | Metrology | 8" |
| 16000856 | KLA/TENCOR | 2360 wafer inspect | Metrology | |
| 16000744 | KLA/TENCOR | 2401 Viper Macro Defect Inspection System | Metrology | 8" |
| 16000911 | KLA/TENCOR | 2410 Viper Automated Macro defect inspection | Metrology | |
| 16000775 | KLA/TENCOR | 2551X Data Analysis Station | Metrology | 8" |
| 16000776 | KLA/TENCOR | 2552 Data Analysis Station | Metrology | 8" |
| 16000935 | KLA/TENCOR | 2552 Data Analysis Station | Metrology | |
| 16000936 | KLA/TENCOR | 2552 wafer inspection | Metrology | |
| 16000777 | KLA/TENCOR | 2552X Data Analysis Station | Metrology | 8" |
| 16000799 | KLA/TENCOR | 2608 Data Analysis Station | Metrology | |
| 16000826 | KLA/TENCOR | 2608 Wafer Review Station | Metrology | |
| 16000993 | KLA/TENCOR | 301 Wafer inspection | Metrology | |
| 16000857 | KLA/TENCOR | 353 reticle inspect | Metrology | |
| 16000214 | KLA/TENCOR | 4000 Surfscan Defect Measurement System | Metrology | 4",5",6",8" |
| 16000160 | KLA/TENCOR | 4500 Surfscan Defect Measurement System | Metrology | 4",5",6" |
| 16000160 | KLA/TENCOR | 4500 Surfscan Defect Measurement System | Metrology | 4",5",6" |
| 16000160 | KLA/TENCOR | 4500 Surfscan Defect Measurement System | Metrology | 4",5",6" |
| 16000160 | KLA/TENCOR | 4500 Surfscan Defect Measurement System | Metrology | 6" |
| 16000798 | KLA/TENCOR | 5011 Overlay Inspection System | Metrology | 6" |
| 16000827 | KLA/TENCOR | 5011 Wafer Overlay Inspection | Metrology | 8" |
| 16000828 | KLA/TENCOR | 5012 Wafer Overlay Inspection | Metrology | 8" |
| 16000641 | KLA/TENCOR | 5015 Overlay Inspection System | Metrology | 4",5",6",8" |
| 16000129 | KLA/TENCOR | 5100 Overlay Inspection System | Metrology | 6" |
| 16000129 | KLA/TENCOR | 5100 Overlay Inspection System | Metrology | 8" |
| 16000937 | KLA/TENCOR | 5100 Overlay Inspection System | Metrology | |
| 16000154 | KLA/TENCOR | 5100 XP Overlay Measurement System | Metrology | 6",8" |
| 16000829 | KLA/TENCOR | 5100XP Overlay Inspection System | Metrology | 6" |
| 16000830 | KLA/TENCOR | 5100XP Overlay Inspection System | Metrology | 8" |
| 16000858 | KLA/TENCOR | 5200 XP Overlay Measurement system | Metrology | 8" |
| 16000938 | KLA/TENCOR | 5200 XP Overlay Measurement system | Metrology | |
| 16000182 | KLA/TENCOR | 5500 Surfscan Defect Measurement System | Metrology | 4",5",6",8" |
| 16000182 | KLA/TENCOR | 5500 Surfscan Defect Measurement System | Metrology | 4",5",6",8" |
| 16000206 | KLA/TENCOR | 6100 Surfscan Defect Measurement System | Metrology | 4",5",6",8" |
| 16000206 | KLA/TENCOR | 6100 Surfscan Defect Measurement System | Metrology | 4",5",6",8" |
| 16000206 | KLA/TENCOR | 6100 Surfscan Defect Measurement System | Metrology | 4",5",6",8" |
| 16000206 | KLA/TENCOR | 6100 Surfscan Defect Measurement System | Metrology | 4",5",6",8" |
| 16000099 | KLA/TENCOR | 6200 Surfscan Defect Measurement System | Metrology | 6" |
| 16000099 | KLA/TENCOR | 6200 Surfscan Defect Measurement System | Metrology | 6",8" |
| 16000099 | KLA/TENCOR | 6200 Surfscan Defect Measurement System | Metrology | 6",8" |
| 16000099 | KLA/TENCOR | 6200 Surfscan Defect Measurement System | Metrology | 8" |
| 16000099 | KLA/TENCOR | 6200 Surfscan Defect Measurement System | Metrology | 8" |
| 16000099 | KLA/TENCOR | 6200 Surfscan Defect Measurement System | Metrology | 8" |

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| Item No. | OEM | Model/Description | Type | Wafer Size (Inches) |
|----------|------------|---|-------------|---------------------|
| 1600095 | KLA/TENCOR | 6220 Surfscan Defect Measurement System | Metrology | 6",8" |
| 1600095 | KLA/TENCOR | 6220 Surfscan Defect Measurement System | Metrology | 8" |
| 16000939 | KLA/TENCOR | 6220 Surfscan Defect Measurement System | Metrology | |
| 16000940 | KLA/TENCOR | 6220 Surfscan Defect Measurement System | Metrology | |
| 16000859 | KLA/TENCOR | 6400 critical non-metal Quantox | Metrology | |
| 16000487 | KLA/TENCOR | 6400 Surfscan Defect Measurement System | Metrology | 8" |
| 16000487 | KLA/TENCOR | 6400 Surfscan Defect Measurement System | Metrology | 8" |
| 16000860 | KLA/TENCOR | 6420 copper particle meas | Metrology | |
| 16000861 | KLA/TENCOR | 6420 critical non-metal particle meas | Metrology | |
| 16000862 | KLA/TENCOR | 6420 metal particle meas | Metrology | |
| 16000941 | KLA/TENCOR | 6420 Surfscan defect measurement system | Metrology | |
| 16000863 | KLA/TENCOR | 6420 Surfscan unpatterned wafer inspection system | Metrology | |
| 16000469 | KLA/TENCOR | 7000 Surfscan Defect Measurement System | Metrology | 4";5";6";8" |
| 16000143 | KLA/TENCOR | 7600 Surfscan Defect Measurement System | Metrology | 6";8" |
| 16000143 | KLA/TENCOR | 7600 Surfscan Defect Measurement System | Metrology | 6";8" |
| 16000942 | KLA/TENCOR | 7600 Surfscan Defect Measurement System | Metrology | |
| 16000864 | KLA/TENCOR | 7700 M Surfscan Defect Measurement System | Metrology | |
| 16000047 | KLA/TENCOR | 7700 M Surfscan Defect Measurement System w/ Microscope | Metrology | 4";5";6";8" |
| 16000142 | KLA/TENCOR | 7700 Surfscan Defect Measurement System | Metrology | 8" |
| 16000142 | KLA/TENCOR | 7700 Surfscan Defect Measurement System | Metrology | 8" |
| 16000142 | KLA/TENCOR | 7700 Surfscan Defect Measurement System | Metrology | 8" |
| 16000142 | KLA/TENCOR | 7700 Surfscan Defect Measurement System | Metrology | 8" |
| 16000943 | KLA/TENCOR | 7700 Surfscan Defect Measurement System | Metrology | |
| 16000944 | KLA/TENCOR | 7700 Surfscan Patterned Wafer Measurement System | Metrology | |
| 90000141 | KLA/TENCOR | 8100 Automated CD/SEM | Microscopes | 8" |
| 90000141 | KLA/TENCOR | 8100 Automated CD/SEM | Microscopes | 8" |
| 90000141 | KLA/TENCOR | 8100 Automated CD/SEM | Microscopes | 8" |
| 16000865 | KLA/TENCOR | 8100 CD SEM all wafers | Metrology | |
| 16000945 | KLA/TENCOR | 8100 Surfscan defect measurement system | Metrology | |
| 90000177 | KLA/TENCOR | 8100 XP Automated CD/SEM | Microscopes | 8" |
| 90000239 | KLA/TENCOR | 8100 XP Automated CD/SEM | Microscopes | 8" |
| 90000177 | KLA/TENCOR | 8100 XP Automated CD/SEM (SMIF) | Microscopes | 8" |
| 25000049 | KLA/TENCOR | 8100 XP-R Automated CD/SEM | Photomasks | 8" |
| 90000187 | KLA/TENCOR | 8100 XP-R Automated CD/SEM | Microscopes | 8" |
| 90000142 | KLA/TENCOR | 8250 Automated CD/SEM | Microscopes | 8" |
| 90000267 | KLA/TENCOR | 8250 S CD SEM | Microscopes | |
| 16000866 | KLA/TENCOR | AIT 2 Copper | Metrology | |
| 16000867 | KLA/TENCOR | AIT 2 Fusion all wafers | Metrology | |
| 16000716 | KLA/TENCOR | AIT 8000 Patterned Wafer Inspection System | Metrology | 8" |
| 16000726 | KLA/TENCOR | AIT 8020 Patterned Wafer Inspection System | Metrology | 8" |
| 16000868 | KLA/TENCOR | AIT Fusion | Metrology | |
| 16000946 | KLA/TENCOR | AIT II patterned wafer inspection system | Metrology | |
| 16000994 | KLA/TENCOR | AIT III Patterned wafer inspection system | Metrology | |
| 16000869 | KLA/TENCOR | AIT XP | Metrology | |
| 16000947 | KLA/TENCOR | AIT XP patterned wafer inspection system | Metrology | |
| 16000017 | KLA/TENCOR | AIT-1 (8010) Patterned Wafer Inspection System | Metrology | 6" |
| 16000017 | KLA/TENCOR | AIT-1 (8010) Patterned Wafer Inspection System | Metrology | 8" |
| 16000017 | KLA/TENCOR | AIT-1 (8010) Patterned Wafer Inspection System | Metrology | 8" |
| 16000017 | KLA/TENCOR | AIT-1 (8010) Patterned Wafer Inspection System | Metrology | 8" |
| 16000017 | KLA/TENCOR | AIT-1 (8010) Patterned Wafer Inspection System | Metrology | 8" |
| 16000017 | KLA/TENCOR | AIT-1 (8010) Patterned Wafer Inspection System | Metrology | 8" |
| 16000870 | KLA/TENCOR | AIT-1 Patterned Wafer Inspection System | Metrology | |
| 16000751 | KLA/TENCOR | AIT-XP Patterned Wafer Inspection System | Metrology | 8" |
| 16000752 | KLA/TENCOR | AIT-XP+ Patterned Wafer Inspection System | Metrology | 8" |
| 16000532 | KLA/TENCOR | Alpha Step 100 Profilometer | Metrology | 6" |
| 16000532 | KLA/TENCOR | Alpha Step 100 Profilometer | Metrology | 6" |
| 16000204 | KLA/TENCOR | Alpha Step 200 Profilometer | Metrology | 6";8" |
| 16000204 | KLA/TENCOR | Alpha Step 200 Profilometer | Metrology | 6";8" |
| 16000204 | KLA/TENCOR | Alpha Step 200 Profilometer | Metrology | 6";8" |
| 16000204 | KLA/TENCOR | Alpha Step 200 Profilometer | Metrology | 6";8" |
| 16000916 | KLA/TENCOR | Alpha Step 200 Profilometer | M | |
| 16000625 | KLA/TENCOR | Alpha Step 300 Profilometer | Metrology | 6";8" |
| 16000995 | KLA/TENCOR | ARCHER 10 overlay measurement system | Metrology | |
| 16000996 | KLA/TENCOR | ARCHER AIM overlay measurement system | Metrology | |
| 16000948 | KLA/TENCOR | Archer AIM with MPX option | Metrology | |
| 16000871 | KLA/TENCOR | Archer all wafers | Metrology | |
| 16000872 | KLA/TENCOR | Aset F5 and F5x thin film measurement system | Metrology | |
| 16000997 | KLA/TENCOR | ASET-F5X / Spectra CD 100 thin film measurement | | |
| 16000772 | KLA/TENCOR | CRS 1010 Confocal Review Station | Metrology | 8" |
| 16000659 | KLA/TENCOR | CRS 3000 Optical Review/Inspection System | Metrology | 8";12" |

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|----------|------------|--|-------------|---------------------|
| 16000659 | KLA/TENCOR | CRS 3000 Optical Review/Inspection System | Metrology | 8";12" |
| 16000949 | KLA/TENCOR | CRS 3100 laser imaging scope | Metrology | |
| 16000998 | KLA/TENCOR | CRS-1200-S Inspection defect analysis | Metrology | |
| 90000268 | KLA/TENCOR | eCD 2 Critical Dimension SEM | Microscopes | |
| 16000999 | KLA/TENCOR | eCD-1 CD SEM | Microscopes | |
| 90000240 | KLA/TENCOR | eCD1XP CD/SEM | Microscopes | 8" |
| 90000272 | KLA/TENCOR | eCD2 CD/SEM | Microscopes | |
| 16000714 | KLA/TENCOR | eS20XP e-Beam Wafer Inspection System | Metrology | 8" |
| 16000714 | KLA/TENCOR | eS20XP e-Beam Wafer Inspection System | Metrology | 8" |
| 16001000 | KLA/TENCOR | ES25 wafer inspection system - E Beam | Metrology | |
| 16000873 | KLA/TENCOR | eS30e e-Beam Wafer Inspection System | Metrology | |
| 16000634 | KLA/TENCOR | eV 300 Defect Review System | Metrology | 8";12" |
| 16000874 | KLA/TENCOR | F5 Copper | Metrology | |
| 16000875 | KLA/TENCOR | F5X Copper | Metrology | |
| 16000876 | KLA/TENCOR | F5X Metal | Metrology | |
| 16000877 | KLA/TENCOR | F5X Non-metal | Metrology | |
| 16000950 | KLA/TENCOR | Flexus 2320 thin film measurement system | Metrology | 8" |
| 16000951 | KLA/TENCOR | FLX 2908 auto scan | Metrology | |
| 16001001 | KLA/TENCOR | FLX 5400 stress measurement | Metrology | |
| 16000693 | KLA/TENCOR | FLX-2418 Film Stress Measurement System | Metrology | 8" |
| 16000782 | KLA/TENCOR | FLX-2908 Film Stress Measurement System | Metrology | 5";6";8" |
| 16001002 | KLA/TENCOR | FLX-2908 Stress Measurement system | Metrology | |
| 16000724 | KLA/TENCOR | FLX-5200h Film Stress Measurement System | Metrology | 4";5";6";8" |
| 16000724 | KLA/TENCOR | FLX-5200h Film Stress Measurement System | Metrology | 4";5";6";8" |
| 16000789 | KLA/TENCOR | FLX-5400 Dual Wavelength Stress Measurement System | Metrology | 8" |
| 16000754 | KLA/TENCOR | FLX-5500 Dual Wavelength Stress Measurement System | Metrology | 8" |
| 16000833 | KLA/TENCOR | FT-750 film thickness measurement | Metrology | |
| 16000475 | KLA/TENCOR | HRP 100 Surface Profiler | Metrology | 8" |
| 16000474 | KLA/TENCOR | HRP 220 Surface Profiler | Metrology | 8" |
| 16000755 | KLA/TENCOR | HRP 220 Surface Profiler | Metrology | 8" |
| 16000756 | KLA/TENCOR | HRP 240 Surface Profiler | Metrology | 8" |
| 16000952 | KLA/TENCOR | KLA 365 UV HR reticle inspection | Metrology | |
| 16000710 | KLA/TENCOR | NC 110 Non-Contact Resistivity Measurement System | Metrology | 8" |
| 16000953 | KLA/TENCOR | OmniMap RS 55/tc | Metrology | 8" |
| 16001003 | KLA/TENCOR | OMNIMAP RS75 Resistivity measurement | Metrology | |
| 16000700 | KLA/TENCOR | P-1 Surface Profilometer | Metrology | 8" |
| 16000954 | KLA/TENCOR | P-10 Profilometer | Metrology | |
| 16000512 | KLA/TENCOR | P-11 Surface Profilometer | Metrology | 8" |
| 16000512 | KLA/TENCOR | P-11 Surface Profilometer | Metrology | 8" |
| 16000196 | KLA/TENCOR | P-2 Long Scan Surface Profilometer | Metrology | 6";8" |
| 16000196 | KLA/TENCOR | P-2 Long Scan Surface Profilometer | Metrology | 6";8" |
| 16000203 | KLA/TENCOR | P-20H Long Scan Profilometer | Metrology | 3";4";5";6";8" |
| 16001004 | KLA/TENCOR | P-22 surface profiler | Metrology | |
| 16000512 | KLA/TENCOR | P-22 Surface Profilometer | Metrology | |
| 16000554 | KLA/TENCOR | P-22 Surface Profilometer | Metrology | 6" |
| 16000878 | KLA/TENCOR | P22-H profilometer | Metrology | |
| 16000622 | KLA/TENCOR | P-2H Long Scan Surface Profilometer | Metrology | 6";8" |
| 16000622 | KLA/TENCOR | P-2H Long Scan Surface Profilometer | Metrology | 6";8" |
| 16001005 | KLA/TENCOR | P-30 surface profiler | Metrology | |
| 16000955 | KLA/TENCOR | Prometrix R75A 4 point probe | Metrology | |
| 16000956 | KLA/TENCOR | Prometrix RS55T/C | Metrology | |
| 16000957 | KLA/TENCOR | Prometrix SM300 | Metrology | |
| 16000912 | KLA/TENCOR | Prometrix UV 1050 | Metrology | |
| 16001006 | KLA/TENCOR | PROMETRIX UV-1070 thin film measurement system | Metrology | |
| 16000743 | KLA/TENCOR | Quantox Oxide Charge Measurement System | Metrology | 6";8" |
| 16000489 | KLA/TENCOR | Quantox Oxide Charge Measurement System | Metrology | 8" |
| 16000489 | KLA/TENCOR | Quantox Oxide Charge Measurement System | Metrology | 8" |
| 16001007 | KLA/TENCOR | RS-100 resistivity measurement system | Metrology | |
| 16000834 | KLA/TENCOR | RS35 resistivity probe | Metrology | 6" |
| 16001008 | KLA/TENCOR | RS-55 OMNIMAP resistivity measurement system | Metrology | |
| 16000879 | KLA/TENCOR | RS75 Copper | Metrology | |
| 16000880 | KLA/TENCOR | RS75 Critical non-metal | Metrology | |
| 16000580 | KLA/TENCOR | Sigmascan Surface Profilometer | Metrology | 6";8" |
| 16000958 | KLA/TENCOR | SP1 | Metrology | |
| 16000736 | KLA/TENCOR | SP1 Classic Surfscan Non-Patterned Particle Measurement | Metrology | 8";12" |
| 16000736 | KLA/TENCOR | SP1 Classic Surfscan Non-Patterned Particle Measurement System | Metrology | 8" |
| 16000959 | KLA/TENCOR | SP1 DLS | Metrology | |
| 16000881 | KLA/TENCOR | SP1 Metal | Metrology | |
| 16000882 | KLA/TENCOR | SP1 Non-metal | Metrology | |
| 16000960 | KLA/TENCOR | SP1 TBI | Metrology | |

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|----------|----------------------|---|-----------------|---------------------|
| 16000748 | KLA/TENCOR | SP1 Tbi Surfscan Non-Patterned Particle Measurement | Metrology | 8" |
| 13001254 | KLA/TENCOR | Spectra FX 200 | Test & Handling | |
| 16000883 | KLA/TENCOR | Spectra FX 200 optical thin film metrology to 45nm | Metrology | |
| 16000671 | KLA/TENCOR | Spectra FX100 Film Thickness Measurement System | Metrology | 8" |
| 16000961 | KLA/TENCOR | Starlight SLF 17 | Metrology | |
| 16000962 | KLA/TENCOR | Starlight SLF 27 | Metrology | |
| 16000099 | KLA/TENCOR | Surfscan 6200 Defect Measurement System | Metrology | 8" |
| 16001009 | KLA/TENCOR | SURFSCAN 6220 unpatterned wafer inspection | Metrology | |
| 16001010 | KLA/TENCOR | SURFSCAN 6420 unpatterned wafer inspection | Metrology | |
| 16001011 | KLA/TENCOR | SURFSCAN 7700 patterned wafer inspection | Metrology | |
| 16001012 | KLA/TENCOR | SURFSCAN AIT patterned wafer inspection | Metrology | |
| 16001013 | KLA/TENCOR | SURFSCAN SP1 TBI unpatterned wafer inspection | Metrology | |
| 16001014 | KLA/TENCOR | SURFSCAN SP1 unpatterned wafer inspection | Metrology | |
| 16000963 | KLA/TENCOR | Tencor P11 | Metrology | |
| 16000964 | KLA/TENCOR | Tencor RS75/TC | Metrology | |
| 16000185 | KLA/TENCOR | TF 1 Film Thickness Measurement System | Metrology | 8" |
| 16000186 | KLA/TENCOR | TF 2 Film Thickness Measurement System | Metrology | 6" |
| 16000186 | KLA/TENCOR | TF 2 Film Thickness Measurement System | Metrology | 6" |
| 16000479 | KLA/TENCOR | UltraPoint 1010 A Wafer/Mask Inspection System | Metrology | 6" |
| 16000479 | KLA/TENCOR | UltraPoint 1010 A Wafer/Mask Inspection System | Metrology | 8" |
| 16000479 | KLA/TENCOR | UltraPoint 1010 A Wafer/Mask Inspection System | Metrology | 8" |
| 16000965 | KLA/TENCOR | UV 1080 | Metrology | |
| 16000966 | KLA/TENCOR | UV 1250SE | Metrology | |
| 16000967 | KLA/TENCOR | UV 1280 SE | Metrology | |
| 16000835 | KLA/TENCOR | UV-1050 film thickness measurement | Metrology | |
| 16000550 | KLA/TENCOR | VARS 500 Digital Image Management System | Metrology | 8" |
| 16000968 | KLA/TENCOR | Viper 2401 | Metrology | |
| 16001015 | KLA/TENCOR | VIPER 2401 automated macro-defect inspection | Metrology | |
| 16001016 | KLA/TENCOR | VIPER 2410 automated macro-defect inspection | Metrology | |
| 10000430 | KOKUSAI | Apogee 1+ Oxidation Furnace | Diffusion | 8" |
| 10000527 | KOKUSAI | DD-802-V (Ventron II) Vertical Diffusion Furnace | Diffusion | 6" |
| 10000450 | KOKUSAI | DD-815-V/DJ-815V 8L Vertical Furnace | Diffusion | 8" |
| 10000449 | KOKUSAI | DD-825-V/DJ-825V Vertical Furnace | Diffusion | 8" |
| 10000448 | KOKUSAI | DD-853-V/DJ-853V Vertical Furnace (various configs) | Diffusion | 8" |
| 10000498 | KOKUSAI | DJ-815-V D-Poly LPCVD Vertical Furnace | Diffusion | 8" |
| 10000499 | KOKUSAI | DJ-815-V Nitride LPCVD Vertical Furnace | Diffusion | 8" |
| 10000209 | KOKUSAI | DJ-815-V Poly LPCVD Vertical Furnace | Diffusion | 8" |
| 10000329 | KOKUSAI | DJ-815-V-8L LPCVD Vertical Furnace | Diffusion | 8" |
| 10000329 | KOKUSAI | DJ-815-V-8L LPCVD Vertical Furnace | Diffusion | 8" |
| 10000528 | KOKUSAI | DJ-825-V (Ventron V) Vertical LPCVD Furnace | Diffusion | 6" |
| 10000599 | KOKUSAI | Vertron III VDF ATM gate | Diffusion | 8" |
| 10000600 | KOKUSAI | Vertron III VDF ATM Metal Ox | Diffusion | 8" |
| 10000601 | KOKUSAI | Vertron III VDF CVD Poly | Diffusion | 8" |
| 10000502 | KOYO LINDBERG | VF 5100B Vertical Alloy Furnace | Diffusion | 8" |
| 10000619 | KOYO THERMAL SYSTEMS | VF-5300 vertical furnace | Diffusion | |
| 40000044 | LADD RESEARCH | Filament Evaporator w/ 10" X 10" Pyrex Bell Jar | Evaporators | 3";4";5";6" |
| 20000922 | LAM | 2300 etcher transfer module | Etch/Ash/Strip | |
| 20000894 | LAM | 2300 Exelan Flex LEAP oxide etcher | Etch/Ash/Strip | |
| 20000737 | LAM | 2300 Versys Poly Etch System w/ 1 X Poly Etch Chamber | Etch/Ash/Strip | 12" |
| 20000809 | LAM | 4408 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 8" |
| 20000809 | LAM | 4408 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 8" |
| 20000283 | LAM | 4420 Rainbow Poly and Nitride Etch Systems (various) | Etch/Ash/Strip | 6";8" |
| 20000085 | LAM | 4426 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 6" |
| 20000283 | LAM | 4428 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 8" |
| 20000283 | LAM | 4428 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 8" |
| 20000283 | LAM | 4428 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 8" |
| 20000283 | LAM | 4428 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 8" |
| 20000283 | LAM | 4428 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 8" |
| 20000283 | LAM | 4428 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 8" |
| 20000283 | LAM | 4428 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 8" |
| 20000283 | LAM | 4428 Rainbow Poly/Nitride Etch System | Etch/Ash/Strip | 8" |
| 20000872 | LAM | 4500 B Rainbow Oxide etch system | Etch/Ash/Strip | 6";8" |
| 20000923 | LAM | 4500 isotropic series etcher | Etch/Ash/Strip | |
| 20000871 | LAM | 4500 Rainbow Oxide etch system | Etch/Ash/Strip | 6";8" |
| 20000968 | LAM | 4500B Rainbow Oxide etcher | Etch/Ash/Strip | |
| 20000906 | LAM | 4520 Alliance (A4) oxide etch | Etch/Ash/Strip | |
| 20000969 | LAM | 4520 Alliance (A6) Oxide etcher | Etch/Ash/Strip | |
| 20000896 | LAM | 4520 oxide etcher | Etch/Ash/Strip | 4" |
| 20000087 | LAM | 4520 Rainbow Oxide Etch Systems | Etch/Ash/Strip | 6";8" |
| 20000873 | LAM | 4520 XL Rainbow Oxide Etch system | Etch/Ash/Strip | 6";8" |
| 20000924 | LAM | 4520 XLE | Etch/Ash/Strip | |

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| Item No. | OEM | Model/Description | Type | Wafer Size (Inches) |
|----------|-----|---|----------------------|---------------------|
| 20000925 | LAM | 4520 Xi oxide etcher | Etch/Ash/Strip | |
| 20000087 | LAM | 4526 Rainbow Oxide Etch System | Etch/Ash/Strip | 6" |
| 20000087 | LAM | 4526 Rainbow Oxide Etch System | Etch/Ash/Strip | 6" |
| 20000844 | LAM | 4526 Rainbow Oxide Etch System | Etch/Ash/Strip | 8" |
| 20000311 | LAM | 4528 Rainbow Oxide Etch System | Etch/Ash/Strip | 8" |
| 20000311 | LAM | 4528 Rainbow Oxide Etch System | Etch/Ash/Strip | 8" |
| 20000796 | LAM | 4528XL Alliance (A6) Oxide Etch System w/ 3 Chambers | Etch/Ash/Strip | 8" |
| 20000926 | LAM | 4600 series etcher | Etch/Ash/Strip | |
| 20000029 | LAM | 4608 B Rainbow Metal Etch System | Etch/Ash/Strip | 8" |
| 20000927 | LAM | 4700 series etcher | Etch/Ash/Strip | |
| 20000845 | LAM | 4720 Rainbow Tungsten Etch System | Etch/Ash/Strip | 6";8" |
| 20000876 | LAM | 4728XL Alliance (A4) etcher Tungsten | Etch/Ash/Strip | |
| 20000031 | LAM | 480 Poly/Nitride Auto Etcher | Etch/Ash/Strip | 4";5";6" |
| 20000032 | LAM | 490 Poly/Nitride Auto Etcher | Etch/Ash/Strip | 4";5";6" |
| 20000032 | LAM | 490 Poly/Nitride Auto Etcher | Etch/Ash/Strip | 4";5";6" |
| 20000032 | LAM | 490 Poly/Nitride Auto Etcher | Etch/Ash/Strip | 6" |
| 20000970 | LAM | 490 Polysilicon/Nitride etcer | Etch/Ash/Strip | |
| 20000560 | LAM | 580 Oxide Auto Etcher | Etch/Ash/Strip | 4";5";6" |
| 20000034 | LAM | 590 Oxide Auto Etcher | Etch/Ash/Strip | 4";5";6" |
| 20000034 | LAM | 590 Oxide Auto Etcher | Etch/Ash/Strip | 4";5";6" |
| 20000034 | LAM | 590 Oxide Auto Etcher | Etch/Ash/Strip | 4";5";6" |
| 20000034 | LAM | 590 Oxide Auto Etcher | Etch/Ash/Strip | 4";5";6" |
| 20000971 | LAM | 590 Oxide Auto Etcher | Etch/Ash/Strip | |
| 20000972 | LAM | 590 oxide etcher | Etch/Ash/Strip | |
| 20000928 | LAM | 590 plasma etch system | Etch/Ash/Strip | |
| 20000035 | LAM | 690 Metal Auto Etcher | Etch/Ash/Strip | 4";5";6" |
| 20000877 | LAM | 9400 Alliance TCP (A6) PTX etcher poly | Etch/Ash/Strip | 8" |
| 20000973 | LAM | 9400SE Alliance (A4) Oxide etcher | Etch/Ash/Strip | |
| 20000875 | LAM | 9408 Alliance A4 3 chamber | Etch/Ash/Strip | 8" |
| 20000691 | LAM | 9408 SE TCP Poly Etch System | Etch/Ash/Strip | 8" |
| 20000691 | LAM | 9408 SE TCP Poly Etch System | Etch/Ash/Strip | 8" |
| 20000691 | LAM | 9408 SE TCP Poly Etch System | Etch/Ash/Strip | 8" |
| 20000929 | LAM | 9600 Alliance | Etch/Ash/Strip | |
| 20000088 | LAM | 9600 SE TCP Metal Etch System | Etch/Ash/Strip | 6";8" |
| 20000088 | LAM | 9600 SE TCP Metal Etch System | Etch/Ash/Strip | 6";8" |
| 20000088 | LAM | 9600 SE TCP Metal Etch System | Etch/Ash/Strip | 6";8" |
| 20000088 | LAM | 9600 SE TCP Metal Etch System | Etch/Ash/Strip | 6";8" |
| 20000930 | LAM | 9600 Series etcher | Etch/Ash/Strip | |
| 20000974 | LAM | 9600 TCP Metal etcher | Etch/Ash/Strip | |
| 20000975 | LAM | 9600CFE TCP Metal etcher | Etch/Ash/Strip | |
| 20000088 | LAM | 9608 SE TCP Metal Etch System | Etch/Ash/Strip | 8" |
| 20000810 | LAM | Alliance (A4) 9408SE Poly Etch System w/ 2 X 9408SE Etch Chambers | Etch/Ash/Strip | 8" |
| 20000846 | LAM | Alliance (A6) Exelan Oxide Etch System | Etch/Ash/Strip | 8" |
| 20000847 | LAM | Alliance 4 Dry Etch, A4 transport Module | Etch/Ash/Strip | 8" |
| 20000878 | LAM | Alliance A4 etcher (ox, Poly) | Etch/Ash/Strip | |
| 20000879 | LAM | Alliance non-metal | Etch/Ash/Strip | |
| 20000818 | LAM | ASIQ Ashing System | Etch/Ash/Strip | 6" |
| 20000848 | LAM | Autoetch 490 Poly Etch | Etch/Ash/Strip | 6" |
| 20000931 | LAM | DRIE 384T | Etch/Ash/Strip | |
| 30000560 | LAM | DSM 9800 deep submicron CVD system | CVD & Epi | |
| 27000273 | LAM | DSS-200 Series I | Wet Etch & Clean SRD | |
| 27000274 | LAM | DSS-200 Series II Double Sided Wafer Scrubbing System | Wet Etch & Clean SRD | |
| 20000746 | LAM | Exelan Version 2 Etch System w/ 4 X Exelan 2300 Process Chambers | Etch/Ash/Strip | 8" |
| 28000151 | LAM | Ontrak 200 series 0 DSS Poly post CMP wafer cleaner | CMP | 8" |
| 28000152 | LAM | Ontrak 200 series 2 DSS oxide/ILD post CMP wafer cleaner | CMP | 8" |
| 28000153 | LAM | Ontrak 200 series 2 DSS Poly post CMO wafer cleaner | CMP | 8" |
| 28000154 | LAM | Ontrak DS Pre-CMP clean Post cleaner | CMP | 8" |
| 28000155 | LAM | Ontrak DSS-200 double sided scrubber | CMP | 8" |
| 28000156 | LAM | Ontrak Synergy double sided post-CMP scrubber | CMP | 8" |
| 20000880 | LAM | Rainbow 4428 | Etch/Ash/Strip | |
| 20000932 | LAM | Rainbow 4528 oxide etch system | Etch/Ash/Strip | |
| 20000881 | LAM | Rainbow 4528XL SAS etch nonmetal | Etch/Ash/Strip | |
| 20000933 | LAM | Synergy | Etch/Ash/Strip | |
| 28000140 | LAM | Synergy wafer scrubber post CMP | CMP | 8" |
| 20000934 | LAM | TCP 9400 poly nitride etch | Etch/Ash/Strip | |
| 20000935 | LAM | TCP 9400 SE etcher | Etch/Ash/Strip | 8" |
| 20000936 | LAM | TCP 9408 etch system | Etch/Ash/Strip | |
| 20000851 | LAM | TCP 9408 Poly Etch System w SMIF | Etch/Ash/Strip | 8" |
| 20000976 | LAM | TCP 9600 metal etcher ESC Envision software | Etch/Ash/Strip | |

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|----------|-----------------------|--|-------------------------|---------------------|
| 20000937 | LAM | TCP 9600 PTX Alliance | Etch/Ash/Strip | 8" |
| 20000852 | LAM | TCP 9608SE Metal Etch System w SMIF | Etch/Ash/Strip | 8" |
| 28000137 | LAM | Teres ILD oxide CMP | CMP | 8" |
| 20000977 | LAM RESEARCH | TCP 9400 SE | Etch/Ash/Strip | |
| 20000978 | LAM RESEARCH | TCP 9600 PTX | Etch/Ash/Strip | |
| 20000026 | LAM/DRYTEK | 384 T Oxide Triode Etch System | Etch/Ash/Strip | 6" |
| 20000026 | LAM/DRYTEK | 384 T Oxide Triode Etch System | Etch/Ash/Strip | 6" |
| 22000504 | LAM/ONTRAK | DSS 200 series 2 double sided wafer scrubber 200 mm | Tracks | |
| 27000284 | LAM/ONTRAK | DSS 200 Series wafer scrubber | Wet Etch & Clean SRD | |
| 28000070 | LAM/ONTRAK | DSS-200 Series I Wafer Scrubbing System | CMP | 8" |
| 28000049 | LAM/ONTRAK | DSS-200 Series II Double Sided Wafer Scrubbing System | CMP | 8" |
| 28000049 | LAM/ONTRAK | DSS-200 Series II Double Sided Wafer Scrubbing System | CMP | 8" |
| 28000049 | LAM/ONTRAK | DSS-200 Series II Double Sided Wafer Scrubbing System | CMP | 8" |
| 28000049 | LAM/ONTRAK | DSS-200 Series II Double Sided Wafer Scrubbing System | CMP | 8" |
| 13000720 | LAURIER | DS 7000 Pick & Place System | Test & Handling | 8";12" |
| 13000720 | LAURIER | DS 7000 Pick & Place System | Test & Handling | 8";12" |
| 24000082 | LAURIER | HA 225 Plus Hybrid Epoxy Die Bonding System | Wire Bonders | |
| 24000082 | LAURIER | HA 225 Plus Hybrid Epoxy Die Bonding System | Wire Bonders | |
| 24000194 | LAURIER | M-10A Flip Chip Die Bonding System (Never Used) | Wire Bonders | |
| 16000837 | LEICA | CD2 Critical Dimension Measuring Systems | Metrology | |
| 16001017 | LEICA | INS 2000 defect review system | Metrology | |
| 16000884 | LEICA | INS 3000 defect rev opt scope | Metrology | |
| 16001018 | LEICA | INS2000 | Metrology | |
| 16001019 | LEICA | INS3000 | Metrology | |
| 16000757 | LEICA | LDS 3000M Wafer Inspection System | Metrology | 8" |
| 16000800 | LEICA | MIS 200 Wafer Inspection & Review System | Metrology | 6" |
| 16000886 | LEICA | MIS 200 wafer inspection system | Metrology | |
| 25000061 | LEICA | Mue Tec 2030 (LWM 300UV) Optical Mask CD Measurement System | Photomasks | |
| 90000247 | LEICA | S-360 CD/SEM | Microscopes | 6" |
| 16000838 | LEICA | SP Automatic Film Thickness Measuring system | Metrology | 6" |
| 90000285 | LEITZ | Ergolux Inspection Microscopes | Microscopes | |
| 90000286 | LEITZ | Ergolux Microscope | Microscopes | |
| 16000887 | LEO-GEIKEN | Tau LTA-700 crit non-metal | Metrology | |
| 40000061 | LEYBOLD | L 560 Multi-Source Thermal Evaporation Box Coater System | Evaporators | 8" |
| 50000193 | LEYBOLD | LE 301 Plasma reactor, RIE or Microwave Ion etching | PVD Sputter | |
| 40000059 | LEYBOLD | Model 560 E-Beam Evaporator | Evaporators | 6" |
| 60000153 | LOADPOINT | MicroAce Wafer Saw | Dicing, Marking, Taping | 6" |
| 28000016 | LOGITECH | LP 50 Lapping/Polishing System | CMP | 6";8" |
| 28000016 | LOGITECH | LP 50 Lapping/Polishing System | CMP | 6";8" |
| 13000746 | LTX | CX 80 Test System | Test & Handling | |
| 13000743 | LTX | DX 90 Test System | Test & Handling | |
| 13001229 | LTX | Fusion HF Mixed Signal Test System | Test & Handling | |
| 13001050 | LTX | Fusion HT Mixed Signal Test System | Test & Handling | |
| 13001079 | LTX | LX 84 Test System | Test & Handling | |
| 13001080 | LTX | LX 85 Test System | Test & Handling | |
| 13000508 | LTX | TS 80 Test System | Test & Handling | |
| 13000508 | LTX | TS 80 Test System | Test & Handling | |
| 13000892 | LTX | TS 88 Test System | Test & Handling | |
| 12000036 | LUMONICS | SigmaClean laser marker | Laser Repair | |
| 16000577 | MAGNETRON INSTRUMENTS | M 700 4-Point Probe | Metrology | 6";8" |
| 16000578 | MAGNETRON INSTRUMENTS | M 750 4-Point Probe | Metrology | 6";8" |
| 60000132 | MARKEM | 452 T/W Marking System | Dicing, Marking, Taping | 4";5";6" |
| 60000006 | MARKEM | LFA-200DX Auto Marking System | Dicing, Marking, Taping | 4";5";6" |
| 20000046 | MATRIX | 300 Series Photoresist Ashing System | Etch/Ash/Strip | 2";3";4";5";6" |
| 20000979 | MATRIX | 303 Plasma Stripper, 4" to 6" | Etch/Ash/Strip | |
| 20000561 | MATRIX | 400 Series Poly, Nitride or Oxide Isotropic Etching System | Etch/Ash/Strip | 2";3";4";5";6" |
| 20000561 | MATRIX | 400 Series Poly, Nitride or Oxide Isotropic Etching System | Etch/Ash/Strip | 2";3";4";5";6" |
| 23000109 | MATTSON | 2900 RTP | RTA/RTP | |
| 23000104 | MATTSON | 3000 RTP | RTA/RTP | |
| 23000096 | MATTSON | 3000 RTP | RTA/RTP | |
| 20000938 | MATTSON | Aspen II ICP | Etch/Ash/Strip | |
| 20000939 | MATTSON | Aspen II strip | Etch/Ash/Strip | 8" |
| 20000743 | MATTSON | Aspen II System w/ 2 X Dual Wafer ICP & 1 X Cool Down Chambers | Etch/Ash/Strip | 8" |
| 20000797 | MATTSON | Aspen II Systems | Etch/Ash/Strip | 8" |
| 20000807 | MATTSON | Aspen III Highlands System w/ 2 X Process Chambers | Etch/Ash/Strip | 8";12" |
| 20000667 | MATTSON | Aspen III ICP Chamber (Chamber Only) | Etch/Ash/Strip | 8";12" |
| 20000744 | MATTSON | Aspen III System w/ 1 X Dual Strip Chamber | Etch/Ash/Strip | 8";12" |
| 20000807 | MATTSON | Aspen III System w/ 2 X Process Chambers | Etch/Ash/Strip | 8";12" |
| 20000882 | MATTSON/STEAG/AST | Aspen 2 Met and Cu asher | Etch/Ash/Strip | |

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|----------|-------------------|--|-------------------------|---------------------|
| 20000883 | MATTSON/STEAG/AST | Aspen 3 metal / Cu shared | Etch/Ash/Strip | |
| 20000884 | MATTSON/STEAG/AST | Aspen 3 non-metal pre-epi clean | Etch/Ash/Strip | |
| 23000029 | MATTSON/STEAG/AST | SHS-1000G RTP System | RTA/RTP | 4";5";6" |
| 23000057 | MATTSON/STEAG/AST | SHS-100MA RTP System | RTA/RTP | 4";5";6";8" |
| 20000980 | MC ELECTRONICS | LAMBDA 3000 dual chamber ashers | Etch/Ash/Strip | |
| 13000782 | MC SYSTEMS | 8806 Manual Probe System | Test & Handling | 6" |
| 13000031 | MC SYSTEMS | Manual Probe System | Test & Handling | |
| 13000409 | MCT | 2010 Handler | Test & Handling | |
| 13000465 | MCT | 2020 Handler | Test & Handling | |
| 13000466 | MCT | 2030 Handler | Test & Handling | |
| 13000430 | MCT | 3608 AE3 Handler | Test & Handling | |
| 13000429 | MCT | 3608C-3 Extended Black Handler | Test & Handling | |
| 13000983 | MCT | 3608E Test Handler | Test & Handling | |
| 13000428 | MCT | 3608E-3 Extended Black Handler | Test & Handling | |
| 13000427 | MCT | 3608E-6 600 mil DIP Handler | Test & Handling | |
| 13000474 | MCT | 3616E Handler | Test & Handling | |
| 13000984 | MCT | 3616E-3 IC Handler | Test & Handling | |
| 13000432 | MCT | 4610 Single & Dual Site Handlers | Test & Handling | |
| 13000047 | MEGATEST | Genesis G-II Memory Test System | Test & Handling | |
| 13000047 | MEGATEST | Genesis G-II Memory Test System | Test & Handling | |
| 16001020 | METRICON | 2010 Prism Coupler | Metrology | |
| 26000024 | MEYER BURGER | TS-116 Slicing System | Ingot/Wafer Manufacture | 4";5";6" |
| 25000065 | MICRION | 8000 Photomask Repair System | Photomasks | |
| 90000201 | MICRION | 9000 Focused Ion Beam (FIB) System | Microscopes | |
| 60000106 | MICRO AUTOMATION | M 1100 Dicing Saw | Dicing, Marking, Taping | 6" |
| 11000080 | MICROGAS | Gas Double Bottle Cabinet | Miscellaneous | |
| 13000728 | MIRAE | MR 7300 Auto Module Handler | Test & Handling | |
| 13001255 | MOSAID | 3400 tester | Test & Handling | |
| 13001256 | MOSAID | 4105 tester | Test & Handling | |
| 13001214 | MOSAID | 4155 Memory tester | Test & Handling | 8" |
| 13000916 | MOSAID | M 3480 Memory Test System | Test & Handling | |
| 13000970 | MOSAID | M 3490 Memory Test System | Test & Handling | |
| 13000971 | MOSAID | M 3495 Memory Test System | Test & Handling | |
| 13000410 | MOSAID | M 4105 Memory Test System | Test & Handling | |
| 50000006 | MRC | 603 Side Sputtering Batch System | PVD Sputter | 2";3";4";5";6";8" |
| 50000007 | MRC | 603-II Side Sputtering Batch System | PVD Sputter | 2";3";4";5";6";8" |
| 50000007 | MRC | 603-II Side Sputtering Batch System | PVD Sputter | 2";3";4";5";6";8" |
| 50000008 | MRC | 603-III Side Sputtering Batch System | PVD Sputter | 2";3";4";5";6";8" |
| 50000010 | MRC | 662 Side Sputtering Batch System | PVD Sputter | 2";3";4";5";6";8" |
| 50000048 | MRC | 822 Sputtersphere RF PVD System | PVD Sputter | 2";3";4";5";6" |
| 50000205 | MRC | 8667 Sputtering System | PVD Sputter | |
| 50000011 | MRC | 903-M Down Sputtering Batch System | PVD Sputter | 2";3";4";5";6";8" |
| 50000113 | MRC | 943 Down Sputtering Batch System | PVD Sputter | 2";3";4";5";6";8" |
| 50000201 | MRC | Eclipse Mark 2 sputtering system | PVD Sputter | |
| 50000202 | MRC | Eclipse Mark IV | PVD Sputter | |
| 20000981 | MRC | RIE-51 Reactive Ion Etcher | Etch/Ash/Strip | |
| 10000379 | MRL | 1320 Double Stack Horizontal Furnace | Diffusion | 8" |
| 10000425 | MRL INDUSTRIES | Cyclone 4 Tube Horizontal Furnace w/ 3 X POCL and 1 X Gate Oxide Tubes | Diffusion | 6" |
| 10000302 | MRL INDUSTRIES | Model 1024 Three (3) Stack Diffusion Furnace | Diffusion | 6" |
| 10000304 | MRL INDUSTRIES | Model 14TC-45 SMD IR Conveyor Furnace w/ 5 Zones | Diffusion | 6";8" |
| 24000083 | MRSI | 501 Vision Guided Automated Die Placement System | Wire Bonders | |
| 13001131 | MRSI | 505 Pick & Place System | Test & Handling | |
| 30000561 | MSP CORPORATION | 2300D wafer deposition polystyrene (PSL)/particle | CVD & Epi | |
| 22000183 | MTI | FlexiFab Photoresist Coater Track | Tracks | 4";5";6";8" |
| 22000338 | MTI | FlexiFab Photoresist Coater/Bake Track | Tracks | 4";5";6";8" |
| 22000184 | MTI | FlexiFab Photoresist Developer Track | Tracks | 4";5";6";8" |
| 22000339 | MTI | FlexiFab Photoresist Dual Coater/Bake Track | Tracks | 4";5";6";8" |
| 28000051 | MTI | Flexifab Scrubber | CMP | 4";5";6" |
| 28000036 | MTI | S3 Wafer Scrubbing System | CMP | 8" |
| 13000323 | MULTITEST | G6AS Manipulator System | Test & Handling | |
| 13000324 | MULTITEST | MT 8305 L Test Handler System | Test & Handling | |
| 13000324 | MULTITEST | MT 8305 L Test Handler System | Test & Handling | |
| 13000302 | MULTITEST | MT 8501 H Test Handler System | Test & Handling | |
| 13000939 | MULTITEST | MT 8503 Test Handler System | Test & Handling | |
| 13000321 | MULTITEST | MT 8609 Test Handler System | Test & Handling | |
| 13000322 | MULTITEST | MT 8804 Test Handler System | Test & Handling | |
| 13001113 | MULTITEST | MT 9308 HT Test Handler System | Test & Handling | |
| 13001093 | MULTITEST | MT 9320 HS Test Handler System | Test & Handling | |
| 16000465 | NANOMETRICS | AFT 180 Film Thickness Measurement System | Metrology | 3";4";5";6" |
| 16000466 | NANOMETRICS | AFT 181 Film Thickness Measurement System | Metrology | 3";4";5";6" |

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| 16000466 | NANOMETRICS | AFT 181 Film Thickness Measurement System | Metrology | 3";4";5";6" |
| 16000279 | NANOMETRICS | AFT 200 Film Thickness Measurement System | Metrology | 4";5";6" |
| 16000279 | NANOMETRICS | AFT 200 Film Thickness Measurement System | Metrology | 4";5";6" |
| 16000018 | NANOMETRICS | AFT 210 Film Thickness Measurement System | Metrology | 3";4";5";6" |
| 16000018 | NANOMETRICS | AFT 210 Film Thickness Measurement System | Metrology | 3";4";5";6" |
| 16000291 | NANOMETRICS | AFT 210 UV Film Thickness Measurement System | Metrology | 3";4";5";6" |
| 16000291 | NANOMETRICS | AFT 210 UV Film Thickness Measurement System | Metrology | 3";4";5";6" |
| 16000300 | NANOMETRICS | AFT 2100 Film Thickness Measurement System w/ Wafer Loader | Metrology | 3";4";5";6" |
| 16001021 | NANOMETRICS | AFT 2100 Nanospec UV film thickness measurement | Metrology | |
| 16000394 | NANOMETRICS | AFT 210XP Film Thickness Measurement System | Metrology | 8" |
| 16000728 | NANOMETRICS | AFT 212 Film Thickness Measurement System | Metrology | 3";4";5";6" |
| 16000783 | NANOMETRICS | AFT 4000 Scanning Film Thickness & Reflectivity Measurement System | Metrology | 4";5";6";8" |
| 16000021 | NANOMETRICS | AFT 4000 UV Scanning Film Thickness & Reflectivity Measurement System | Metrology | 4";5";6";8" |
| 16000969 | NANOMETRICS | Atlas CD film thickness | Metrology | |
| 16000888 | NANOMETRICS | Atlas SEM CD (critical dimension) | Metrology | |
| 16000579 | NANOMETRICS | CD-50 CD Measurement System | Metrology | 6";8" |
| 16000579 | NANOMETRICS | CD-50 CD Measurement System | Metrology | 6";8" |
| 16000285 | NANOMETRICS | CD-50-2 CD Measurement System | Metrology | 6" |
| 16000285 | NANOMETRICS | CD-50-2 CD Measurement System | Metrology | 6" |
| 16000285 | NANOMETRICS | CD-50-2 CD Measurement System | Metrology | 6" |
| 16000913 | NANOMETRICS | IVS 130 Overlay measurement system | Metrology | |
| 16000839 | NANOMETRICS | M216S film thickness measurement | Metrology | 8" |
| 16000840 | NANOMETRICS | M216UV film thickness measurement | Metrology | 8" |
| 16001022 | NANOMETRICS | Magna IR 860 FTIR Spectrometer with Magna IR mode | Metrology | |
| 16000220 | NANOMETRICS | Metra 200 Line Width Measurement System | Metrology | 8" |
| 16000427 | NANOMETRICS | Metra 2100 Overlay & CD Measurement System | Metrology | 3";4";5";6";8" |
| 16000528 | NANOMETRICS | Nanoline CRD III CD Measurement System | Metrology | 4";5";6";8" |
| 16000529 | NANOMETRICS | Nanoline IV CD Measurement System | Metrology | 4";5";6";8" |
| 16000530 | NANOMETRICS | Nanoline V CD Measurement System | Metrology | 4";5";6";8" |
| 16000842 | NANOMETRICS | Nanospec 8000 | Metrology | 8" |
| 16000970 | NANOMETRICS | Nanospec 8000 thin film measurement | Metrology | |
| 16000654 | NANOMETRICS | Nanospec 8300XSE Automated Film Thickness Measurement System | Metrology | 8";12" |
| 16000654 | NANOMETRICS | Nanospec 8300XSE Automated Film Thickness Measurement System | Metrology | 8";12" |
| 16000654 | NANOMETRICS | Nanospec 8300XSE Automated Film Thickness Measurement System | Metrology | 8";12" |
| 16000402 | NANOMETRICS | Nanospec 9000i Automated Film Thickness Measurement System | Metrology | 4";5";6";8" |
| 16000402 | NANOMETRICS | Nanospec 9000i Automated Film Thickness Measurement System | Metrology | 4";5";6";8" |
| 16000402 | NANOMETRICS | Nanospec 9000i Automated Film Thickness Measurement System | Metrology | 4";5";6";8" |
| 16000796 | NANOMETRICS | Nanospec 9300 Automated Film Thickness Measurement System | Metrology | 8";12" |
| 16000971 | NANOMETRICS | Nanospec AFT | Metrology | |
| 16001023 | NANOMETRICS | NanoSpec AFT 200 | Metrology | |
| 14000199 | NEC | EXCEED 2000AH Medium current Ion implant | Ion Implant | |
| 13000897 | NEXTEST | Maverick II GT Test System | Test & Handling | |
| 16000788 | NICOLET | 205 FTIR EPI Thickness Measurement System | Metrology | 8" |
| 16000889 | NICOLET | ECO 1000S metal FTIR | Metrology | |
| 16000738 | NICOLET | ECO-1000 FTIR EPI Thickness Measurement System | Metrology | 8" |
| 16000738 | NICOLET | ECO-1000 FTIR EPI Thickness Measurement System | Metrology | 8" |
| 16001024 | NICOLET | ECO-8S FTIR | Metrology | |
| 16000130 | NICOLET | IR µs Scanning Infrared Microprobe Molecular Microanalysis System | Metrology | |
| 16001025 | NICOLET | Magna 560 | Metrology | |
| 90000287 | NIDEK | IM7 Auto Inspection Microscopes 4" to 6" | Microscopes | |
| 90000288 | NIKON | ECLIPSE L200D Inspection Microscope | Microscopes | |
| 16001026 | NIKON | Measurescope UM-2 | Metrology | |
| 90000289 | NIKON | Normaski Microscope | Microscopes | |
| 19000021 | NIKON | NSR 1505 G4C g-Line Stepper | Steppers | 5";6" |
| 19000022 | NIKON | NSR 1505 G4D g-Line Stepper | Steppers | 6" |
| 19000131 | NIKON | NSR 1505 G6D g-Line Stepper | Steppers | 6" |
| 19000131 | NIKON | NSR 1505 G6D g-Line Stepper | Steppers | 6" |
| 19000194 | NIKON | NSR 1505 i 6A-Body i-Line Stepper | Steppers | 6" |
| 19000025 | NIKON | NSR 1755 i 7B-Body i-Line Stepper | Steppers | 6" |
| 19000226 | NIKON | NSR 2005 i 10C-Body i-Line Stepper | Steppers | 8" |

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| Item No. | OEM | Model/Description | Type | Wafer Size (Inches) |
|----------|-------------|--|-------------------------|---------------------|
| 19000226 | NIKON | NSR 2005 i 10C-Body i-Line Stepper | Steppers | 8" |
| 19000226 | NIKON | NSR 2005 i 10C-Body i-Line Stepper | Steppers | 8" |
| 19000226 | NIKON | NSR 2005 i 10C-Body i-Line Stepper | Steppers | 8" |
| 19000192 | NIKON | NSR 2005 i 8A-Body i-Line Stepper | Steppers | 6" |
| 19000233 | NIKON | NSR 2005 i 9C-Body i-Line Stepper | Steppers | 6";8" |
| 19000027 | NIKON | NSR 2205 EX 12B DUV 248nm Stepper | Steppers | 8" |
| 19000240 | NIKON | NSR 2205 i 11D-Body i-Line Stepper (6" reticles) | Steppers | 6" |
| 19000222 | NIKON | NSR 2205 i 14E-Body i-Line Stepper | Steppers | 8" |
| 19000304 | NIKON | NSR 2205 I 9C | Steppers | 8" |
| 19000307 | NIKON | NSR 4425 I wide field stepper | Steppers | |
| 19000308 | NIKON | NSR S 101 A | Steppers | |
| 19000309 | NIKON | NSR S 103 B stepper | Steppers | |
| 19000029 | NIKON | NSR S 202 A KrF 248nm Step & Scan System | Steppers | 6" |
| 19000029 | NIKON | NSR S 202 A KrF 248nm Step & Scan System | Steppers | 8" |
| 19000029 | NIKON | NSR S 202 A KrF 248nm Step & Scan System | Steppers | 8" |
| 19000275 | NIKON | NSR S 203 B DUV scanner | Steppers | |
| 19000105 | NIKON | NSR S 203 B KrF Excimer 248nm Scan Exposure System | Steppers | 8" |
| 19000105 | NIKON | NSR S 203 B KrF Excimer 248nm Scan Exposure System | Steppers | 8" |
| 19000105 | NIKON | NSR S 203 B KrF Excimer 248nm Scan Exposure System | Steppers | 8" |
| 19000105 | NIKON | NSR S 203 B KrF Excimer 248nm Scan Exposure System | Steppers | 8" |
| 19000310 | NIKON | NSR S 204 B 248 nm KrF scanner | Steppers | |
| 19000276 | NIKON | NSR S 204 B DUV Scanner | Steppers | |
| 19000311 | NIKON | NSR S 205 C KrF scanner | Steppers | |
| 19000312 | NIKON | NSR S 206 D KrF scanner | Steppers | |
| 19000277 | NIKON | NSR S 305 A 193nm DUV scanner | Steppers | |
| 19000313 | NIKON | NSR S 305 B 193nm DUV scanner | Steppers | |
| 19000196 | NIKON | NSR S 305 B ArF Scanning Exposure System | Steppers | 8";12" |
| 19000195 | NIKON | NSR S 306 C ArF 193nm Scanning Exposure System | Steppers | 8" |
| 19000314 | NIKON | NSR SF 100 I line scan field stepper | Steppers | |
| 19000267 | NIKON | NSR-1505 I 7A stepper I line | Steppers | |
| 19000268 | NIKON | NSR-1755 I 7A stepper I line | Steppers | |
| 19000025 | NIKON | NSR-1755 i 7B-Body i-Line Stepper | Steppers | 6" |
| 19000269 | NIKON | NSR-2005 I 8A stepper i-line | Steppers | |
| 19000270 | NIKON | NSR-2005 I 9C stepper i-line | Steppers | |
| 19000301 | NIKON | NSR-203 B scanner KrF | Steppers | |
| 19000302 | NIKON | NSR-204B scanner KrF | Steppers | |
| 19000303 | NIKON | NSR-206D scanner KrF | Steppers | |
| 19000271 | NIKON | NSR-2205 I 11D stepper i-line | Steppers | |
| 19000222 | NIKON | NSR-2205 I 14E-Body i-Line Stepper | Steppers | 8" |
| 19000326 | NIKON | NSR-2205EX12B, KrF Excimer Laser Wafer Stepper | Steppers | |
| 19000305 | NIKON | NSR-306C scanner ArF | Steppers | |
| 19000306 | NIKON | NSR-307E scanner Arf | Steppers | |
| 19000273 | NIKON | NSR-4425i stepper i-line | Steppers | |
| 19000029 | NIKON | NSR-S 202 A KrF 248nm Step & Scan System | Steppers | 8" |
| 11000187 | NIKON | NWL 851 Wafer Loader | Miscellaneous | 6";8" |
| 11000187 | NIKON | NWL 851 Wafer Loader | Miscellaneous | 6";8" |
| 19000280 | NIKON | Optiphot 20 auto handler | Steppers | |
| 16000972 | NIKON | Optiphot 200 | Metrology | |
| 16001027 | NIKON | Optiphot 200 microscope | Metrology | |
| 90000290 | NIKON | OPTIPHOT 200 microscope | Microscopes | |
| 90000291 | NIKON | OPTIPHOT 66 microscope | Microscopes | |
| 16001028 | NIKON | Optisation-V Automated Inspection Station | Metrology | |
| 16000340 | NIKON | Optistation 2A Wafer Inspection System | Metrology | 3";4";5";6" |
| 16000276 | NIKON | Optistation 3 and 5 Wafer Inspection System | Metrology | 6";8" |
| 16000973 | NIKON | Optistation 3 automatic wafer inspection | Metrology | 6" |
| 16000739 | NIKON | Optistation 3100 | Metrology | 12" |
| 16000974 | NIKON | Optistation 3A Wafer Inspection System | Metrology | 8" |
| 16000276 | NIKON | Optistation 3A Wafer Inspection System | Metrology | 8" |
| 16000975 | NIKON | Optistation 3A Wafer Inspection System | Metrology | |
| 16001029 | NIKON | OPTISTATION V wafer inspection system | Metrology | |
| 60000187 | NITTO DENKO | D-304 Automatic Wafer Taping System | Dicing, Marking, Taping | 6" |
| 60000161 | NITTO DENKO | H-304 Automatic Wafer De-Taping System | Dicing, Marking, Taping | 6" |
| 50000013 | NORDIKO | 8550 RF & DC Sputtering System w/ Loadlock & Ion Mill | PVD Sputter | 6" |
| 90000234 | NOVA | NovaScan 3060CD SA In-Line CD Process Control System | Microscopes | 8" |
| 30000496 | NOVELLUS | Concept II Triple speed | CVD & Epi | |
| 30000534 | NOVELLUS | Concept 1 Cu Nitride ES | CVD & Epi | |
| 30000406 | NOVELLUS | Concept 2 Altus/Prism System w/ 1 X Altus (W) CVD Shrink Chamber & 1 X Prism (TiN) Shrink Chamber | CVD & Epi | 8" |
| 30000300 | NOVELLUS | Concept 2 CVD System w/ 1 X Sequel Shrink & 1 X Speed Shrink Chambers (Previously Used for Copper Process) | CVD & Epi | 8" |

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| Item No. | OEM | Model/Description | Type | Wafer Size (Inches) |
|----------|----------------------------|--|----------------|---------------------|
| 30000365 | NOVELLUS | Concept 2 Dual Altus System w/ Non-Shrink Chambers (Fully Refurbished) | CVD & Epi | 8" |
| 30000309 | NOVELLUS | Concept 2 PECVD System w/ 1 X Sequel Express Shrink Chamber (Used for Copper Interconnect Process) | CVD & Epi | 8" |
| 30000377 | NOVELLUS | Concept 2 Single Sequel System w/ Standard Chamber | CVD & Epi | 8" |
| 30000535 | NOVELLUS | Concept 2 Triple speed CVD | CVD & Epi | |
| 30000502 | NOVELLUS | Concept I CVD System | CVD & Epi | |
| 30000503 | NOVELLUS | Concept II Dual Speed System w/ 2x Non-Shrink Chambers | CVD & Epi | |
| 30000504 | NOVELLUS | Concept II Sequel Metal/Copper shared Copper/Nitride ES | CVD & Epi | |
| 30000505 | NOVELLUS | Concept II Sequel metal/Copper shared Cu Nitride dep | CVD & Epi | |
| 30000506 | NOVELLUS | Concept II Sequel metal/Copper shared Nitride dep | CVD & Epi | |
| 30000507 | NOVELLUS | Concept II Sequel Metal/Copper shared Nitride dep | CVD & Epi | |
| 30000508 | NOVELLUS | Concept II Sequel metal/Copper shared OSG dep | CVD & Epi | |
| 30000509 | NOVELLUS | Concept II Sequel metal/Copper shared TEOS dep | CVD & Epi | |
| 30000510 | NOVELLUS | Concept II Speed / Sequel OSG dep Metal/Copper shared | CVD & Epi | |
| 30000511 | NOVELLUS | Concept II Speed / Sequel PMD dep HDP all wafers | CVD & Epi | |
| 30000512 | NOVELLUS | Concept II Speed Metal/Copper shared FSG dep | CVD & Epi | |
| 30000513 | NOVELLUS | Concept II Speed Metal/Copper shared STI HDP dep | CVD & Epi | |
| 30000514 | NOVELLUS | Concept II Speed/Sequel System | CVD & Epi | |
| 30000497 | NOVELLUS | Concept One CVD TEOS | CVD & Epi | 8" |
| 30000498 | NOVELLUS | Concept One CVD Tungsten | CVD & Epi | 8" |
| 30000461 | NOVELLUS | Concept One Oxide/Nitride CVD System | CVD & Epi | 6" |
| 30000407 | NOVELLUS | Concept One Tungsten CVD System | CVD & Epi | 8" |
| 30000407 | NOVELLUS | Concept One Tungsten CVD System | CVD & Epi | 8" |
| 30000562 | NOVELLUS | Concept Three UV cure thermal processing system | CVD & Epi | |
| 30000563 | NOVELLUS | CONCEPT THREE-DUAL ALTUS CVD Tungsten | CVD & Epi | |
| 30000475 | NOVELLUS | Concept Two Dual Altus System w/ Non-Shrink Chambers | CVD & Epi | 8" |
| 30000424 | NOVELLUS | Concept Two Dual Altus System w/ Shrink Chambers | CVD & Epi | 8" |
| 30000380 | NOVELLUS | Concept Two Dual Sequel PECVD System w/ Shrink Chambers | CVD & Epi | 8" |
| 30000473 | NOVELLUS | Concept Two Dual Speed Shrink | CVD & Epi | 8" |
| 30000375 | NOVELLUS | Concept Two Prism System w/ 1 Chamber | CVD & Epi | 8" |
| 30000336 | NOVELLUS | Concept Two Single Altus System w/ Shrink Chamber | CVD & Epi | 8" |
| 30000377 | NOVELLUS | Concept Two Single Sequel System w/ Standard Chamber | CVD & Epi | 8" |
| 30000536 | NOVELLUS | Concept Two Single Speed Shrink | CVD & Epi | 8" |
| 30000476 | NOVELLUS | Concept Two Triple Speed system w/ Non-Shrink Chambers | CVD & Epi | 8" |
| 30000424 | NOVELLUS | Concept Two-Dual Altus (Tungsten) w/ Shrink | CVD & Epi | 8" |
| 30000523 | NOVELLUS | Concept Two-Dual Altus-S(Tungsten) | CVD & Epi | |
| 30000564 | NOVELLUS | Concept Two-Dual Sequel-S CVD PECVD | CVD & Epi | |
| 30000500 | NOVELLUS | Concept Two-Dual Speed CVD HDP | CVD & Epi | |
| 30000501 | NOVELLUS | Concept Two-Dual Speed Sequel CVD | CVD & Epi | |
| 30000425 | NOVELLUS | Concept Two-Triple Speed PECVD System w/ Shrink Chambers | CVD & Epi | 8" |
| 30000537 | NOVELLUS | Gamma 2100 300mm model 2130 | CVD & Epi | |
| 50000184 | NOVELLUS | Inova PVD 2 Cu chambers & 1 Dama Clean chamber | PVD Sputter | 8" |
| 50000109 | NOVELLUS | Inova PVD System | PVD Sputter | 8" |
| 50000109 | NOVELLUS | Inova PVD System | PVD Sputter | 8" |
| 50000109 | NOVELLUS | Inova PVD System w/ 3 X TiN/Al & 1 Etch Chambers | PVD Sputter | 8" |
| 28000171 | NOVELLUS | MOMENTUM | CMP | |
| 20000895 | NOVELLUS | PEP IRIDIA asher | Etch/Ash/Strip | |
| 20000982 | NOVELLUS | PEP Iridia DL Asher Multi chamber | Etch/Ash/Strip | |
| 28000157 | NOVELLUS | Sabre Next | CMP | |
| 28000158 | NOVELLUS | Sabre xT | CMP | |
| 29000017 | NOVELLUS | Sabre XT Copper ECD plater | Copper Plating | |
| 29000018 | NOVELLUS | Sabre XT Copper ECD plater | Copper Plating | |
| 11000267 | NOVELLUS | SOLA UV cure | Miscellaneous | |
| 28000106 | NOVELLUS / SPEEDFAM / IPEC | 372 Avanti CMP System | CMP | 8" |
| 28000010 | NOVELLUS / SPEEDFAM / IPEC | 472 Avanti CMP System | CMP | 6",8" |
| 28000113 | NOVELLUS / SPEEDFAM / IPEC | 472 Avanti CMP System (metal CMP) | CMP | 6" |
| 28000012 | NOVELLUS / SPEEDFAM / IPEC | 676 Avantgaard CMP System - One Tungsten, one ILD | CMP | 8" |
| 28000172 | NOVELLUS / SPEEDFAM / IPEC | AURIGA CMP Poly/oxide | CMP | |
| 28000173 | NOVELLUS / SPEEDFAM / IPEC | AURIGA CMP Tungsten | CMP | |
| 28000018 | NOVELLUS / SPEEDFAM / IPEC | Auriga-C CMP System (5 Oxide and 3 Poly) | CMP | 8" |
| 28000143 | NOVELLUS / SPEEDFAM / IPEC | Avanti 372 CMP oxide System | CMP | |
| 28000159 | NOVELLUS / SPEEDFAM / IPEC | Avanti 372 ILD | CMP | |
| 28000144 | NOVELLUS / SPEEDFAM / IPEC | Avanti 472 CMP Copper | CMP | |
| 28000160 | NOVELLUS / SPEEDFAM / IPEC | Avanti 472, one Copper and one ILD | CMP | |
| 28000145 | NOVELLUS / SPEEDFAM / IPEC | AvantiGaard 776 | CMP | |
| 28000019 | NOVELLUS / SPEEDFAM / IPEC | CMP V Oxide Wafer Polisher | CMP | 8" |
| 28000105 | NOVELLUS / SPEEDFAM / IPEC | Momentum 200 CMP System (Refurbished) | CMP | 8" |

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|----------|------------------------|---|-------------------------|---------------------|
| 28000161 | NOVELLUS/SPEEDFAM/IPEC | Auriga oxide CMP | CMP | |
| 17000076 | OAI | 5000-063419 Deep UV C-to-C Proximity/Contact Mask Aligner | Mask Aligners | 6" |
| 17000110 | OAI | 5008 Mask Aligner | Mask Aligners | 4";5";6";8" |
| 17000065 | OAI | Hybralign 500 Mask Aligner | Mask Aligners | 4" |
| 60000226 | OKAMOTO | ALG-8F Edge Grinding System | Dicing, Marking, Taping | 8" |
| 11000256 | OLYMPUS | AL100-LB Wafer Loader | Miscellaneous | 8" |
| 11000256 | OLYMPUS | AL100-LB Wafer Loader | Miscellaneous | 8" |
| 90000271 | OLYMPUS | BH2 transmitted light microscope with 10x to 100x PLL | Microscopes | |
| 90000292 | OLYMPUS | Microscope | Microscopes | |
| 27000321 | ONTRAK | DSS-200 Double-Sided Scrubber | Wet Processing | |
| 28000174 | ONTRAK | Synergy Double-Sided Post CMP Scrubber | CMP | |
| 30000264 | OXFORD | Plasmalab 800+ PECVD System | CVD & Epi | 6" |
| 20000741 | OXFORD | Plasmalab RIE μ P Dual Chamber Etch System | Etch/Ash/Strip | 6";8" |
| 20000396 | OXFORD | Plasmalab RIE 100 Dual Chamber Etch System | Etch/Ash/Strip | 6";8" |
| 20000647 | OXFORD | Plasmalab RIE 100 Single Chamber Etch System | Etch/Ash/Strip | 6" |
| 20000673 | OXFORD | Plasmalab RIE 100+ Reactive Ion Etch System w/ Load Lock | Etch/Ash/Strip | 6" |
| 20000289 | OXFORD | Plasmalab RIE 80+ Reactive Ion Etch System | Etch/Ash/Strip | 6" |
| 20000289 | OXFORD | Plasmalab RIE 80+ Reactive Ion Etch System | Etch/Ash/Strip | 6" |
| 24000241 | PANASONIC | 60M-H wire bonder | Wire Bonders | |
| 13001282 | PANASONIC | KXF-4X3C (CM401-M SERIES) chip placement - high speed | Test & Handling | |
| 13001283 | PANASONIC | KXF-4Z4C (CM402-L A) chip placement - high speed | Test & Handling | |
| 24000214 | PANASONIC | Panasert STB-W Flip-Chip Bonding System | Wire Bonders | |
| 16001030 | PERKIN ELMER | 1600 FTIR Spectrophotometer | Metrology | |
| 50000121 | PERKIN ELMER | 2400 Sputtering System | PVD Sputter | 2";3";4";5";6" |
| 50000089 | PERKIN ELMER | 2400 Sputtering System w/ 3 Targets & Etch or 4 Targets & No Etch | PVD Sputter | 2";3";4";5";6" |
| 17000084 | PERKIN ELMER | 300 Mask Aligner | Mask Aligners | 4" |
| 17000085 | PERKIN ELMER | 340 Mask Aligner | Mask Aligners | 4" |
| 17000086 | PERKIN ELMER | 341 Mask Aligner | Mask Aligners | 4" |
| 50000122 | PERKIN ELMER | 4400 Sputtering System | PVD Sputter | 2";3";4";5";6" |
| 50000136 | PERKIN ELMER | 4410 Sputtering System | PVD Sputter | 2";3";4";5";6" |
| 50000124 | PERKIN ELMER | 4450 Sputtering System | PVD Sputter | 2";3";4";5";6" |
| 50000124 | PERKIN ELMER | 4450 Sputtering System | PVD Sputter | 2";3";4";5";6" |
| 19000315 | PERKIN ELMER | 544 HT Projection Aligner | Steppers | |
| 17000093 | PERKIN ELMER | Microalign 552 HT Projection Aligner | Mask Aligners | 4";5" |
| 17000094 | PERKIN ELMER | Microalign 660 HT Projection Aligner | Mask Aligners | 4" |
| 16000890 | PHI-EVANS | XPS non metal film thickness | Metrology | |
| 16001031 | PHILIPS | FEI, XL 30S FEG Digital Highresolution Cross Section SEM | Metrology | |
| 16000658 | PHILIPS | SPW 2800 X-Ray Fluorescence (XRF) Analysis System | Metrology | 8" |
| 16000658 | PHILIPS | SPW 2800 X-Ray Fluorescence (XRF) Analysis System | Metrology | 8" |
| 16001032 | PHILIPS | Technos TREX 620 | Metrology | |
| 16000892 | PHILIPS | TREX 610T reflection X-ray fluorescence analyzing system | Metrology | |
| 90000203 | PHILIPS | XL 40 FEG Cross Section FESEM | Microscopes | |
| 90000074 | PHILIPS | XL 810 SEM | Microscopes | 6";8" |
| 16000894 | PHILLIPS | PW2100/00 metal/copper shared XRF sys XRAY | Metrology | |
| 20000814 | PLASMATHERM | SLR 730 RIE Etch System w/ Load Lock | Etch/Ash/Strip | 4";5";6";8" |
| 20000787 | PLASMATHERM | Wafer Batch 74 RIE Parallel Plasma Etch System | Etch/Ash/Strip | 4";5";6" |
| 40000033 | PLASMATRON | E-Beam Evaporator w/ 4 Pocket Gun | Evaporators | 4";6" |
| 16000442 | PLASMOS | SD 4000 Ellipsometer | Metrology | 2";3";4";5";6";8" |
| 16000442 | PLASMOS | SD 4000 Ellipsometer | Metrology | 2";3";4";5";6";8" |
| 27000275 | POLYFLOW | Custom Quartz Clean Hood | Wet Etch & Clean SRD | |
| 11000258 | POLYFLOW | Model S-412 Quartz Cleaning System | Miscellaneous | |
| 11000257 | POLYFLOW | Model S-417 Quartz Cleaning System | Miscellaneous | |
| 11000079 | POLYFLOW | Model S-620 Quartz Cleaning System | Miscellaneous | |
| 16001033 | PROMETRIX | FT-750 patterned wafer mapping | Metrology | |
| 16001034 | PROMETRIX | OmniMap RS35c | Metrology | |
| 16001035 | PROMETRIX | UV-1050 thin film measurement system | Metrology | |
| 25000067 | QC OPTICS | API 3000 Reticle/Mask Inspection System | Photomasks | 8" |
| 17000095 | QUINTEL | Mask Aligner System | Mask Aligners | 4" |
| 20000676 | RAMCO | RAM 8500 Z Dual Chamber Ashing System | Etch/Ash/Strip | 8" |
| 24000207 | RD AUTOMATION | M-10A Semi-Automatic Flip Chip/Die Bonding System | Wire Bonders | |
| 16000801 | RECIF | BPP8 Wafer Mapping System | Metrology | 8" |
| 16000718 | RECIF | SPP8 Wafer Mapping System | Metrology | 8" |
| 16000717 | RECIF | VMT8 Wafer Mapping System | Metrology | 8" |
| 16000773 | RECIF | VMT8 Wafer Mapping System | Metrology | 8" |
| 90000293 | REICHERT-JUNG | Polyvar MET Microscope | Microscopes | |
| 90000294 | REICHERT-JUNG | Ultrastar Microscope | Microscopes | |
| 27000322 | REYNOLDSTECH PLASTIC | Etch/P-Strip Wet Bench | Wet Processing | |
| 27000323 | REYNOLDSTECH PLASTIC | General Acid Wet Bench | Wet Processing | |
| 27000324 | REYNOLDSTECH PLASTIC | Metal-Etch Wet Bench | Wet Processing | |

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|----------|---------------------------|---|----------------------|---------------------|
| 27000325 | REYNOLDSTECH PLASTIC | Ni-Plating Wet Bench | Wet Processing | |
| 27000326 | REYNOLDSTECH PLASTIC | Slop Sink | Wet Processing | |
| 27000327 | REYNOLDSTECH PLASTIC | Stainless Steel Pouroous Silicon Etch Wet Bench | Wet Processing | |
| 27000328 | REYNOLDSTECH PLASTIC | TMAH Wet Bench | Wet Processing | |
| 16000679 | RIGAKU | 3620 X-Ray Fluorescence (XRF) Analysis System | Metrology | 6" |
| 16000679 | RIGAKU | 3620 X-Ray Fluorescence (XRF) Analysis System | Metrology | 6" |
| 16000459 | RIGAKU | 3630 X-Ray Fluorescence (XRF) Analysis System | Metrology | 8" |
| 16000895 | RIGAKU | 3640 metal/copper shared XRF | Metrology | |
| 16001036 | RIGAKU | 3640 spectrometer XRF | Metrology | |
| 16000624 | RIGAKU | 3700H X-Ray Fluorescence (XRF) Analysis System | Metrology | 8" |
| 16000624 | RIGAKU | 3700H X-Ray Fluorescence (XRF) Analysis System | Metrology | 8" |
| 16000606 | RIGAKU | 3750 X-Ray Fluorescence (XRF) Analysis System | Metrology | 8" |
| 16000356 | RIGAKU | DPGS X-Ray Diffractometer | Metrology | 6" |
| 16000356 | RIGAKU | DPGS X-Ray Diffractometer | Metrology | 6" |
| 16001037 | RIGAKU | TXRF 3750 inspection / contamination | Metrology | |
| 16000790 | RIGAKU | X-300 X-Ray Fluorescence (XRF) Analysis System | Metrology | 8";12" |
| 24000107 | ROYCE | 550 Bond Test System | Wire Bonders | |
| 13000733 | RUCKER & KOLLS | 260 Wafer Probe System | Test & Handling | 4" |
| 13000734 | RUCKER & KOLLS | 300 Wafer Probe System | Test & Handling | 6" |
| 13000735 | RUCKER & KOLLS | 670 Wafer Probe System | Test & Handling | 6" |
| 13000438 | RUCKER & KOLLS | 680 A Wafer Probe System | Test & Handling | 6" |
| 13000972 | RUCKER & KOLLS | 681 A Wafer Probe System | Test & Handling | 6" |
| 16001038 | RUDOLPH | AutoEL Ellipsometer | Metrology | |
| 16001039 | RUDOLPH | AXI 930 inspection / defect analysis | Metrology | |
| 16000323 | RUDOLPH | EL-III Manual Ellipsometer | Metrology | 4";5";6" |
| 16000323 | RUDOLPH | EL-III Manual Ellipsometer | Metrology | 4";5";6" |
| 16000122 | RUDOLPH | EL-IV Automatic Ellipsometer | Metrology | 6" |
| 16000122 | RUDOLPH | EL-IV Automatic Ellipsometer | Metrology | 6" |
| 16000915 | RUDOLPH | FE III thickness measurement | Metrology | 6" |
| 16000844 | RUDOLPH | FE-7 film thickness measurement | Metrology | 6" |
| 16000195 | RUDOLPH | FE-IIIID Ellipsometer | Metrology | 8" |
| 16000195 | RUDOLPH | FE-IIIID Ellipsometer | Metrology | 8" |
| 16000896 | RUDOLPH | Focus FE III ellipsometer | Metrology | |
| 16000919 | RUDOLPH | Focus FE IV-D ellipsometer | Metrology | |
| 16001040 | RUDOLPH | Focus FE VII ellipsometer | Metrology | |
| 16000576 | RUDOLPH | FTM Automatic Thickness Measurement System | Metrology | 6";8" |
| 16000307 | RUDOLPH | Metapulse 200 Film Thickness Measurement System | Metrology | 8" |
| 16000307 | RUDOLPH | Metapulse 200 Film Thickness Measurement System | Metrology | 8" |
| 16000759 | RUDOLPH | Metapulse 200 Film Thickness Measurement System (Cu) | Metrology | 8" |
| 16000778 | RUDOLPH | Metapulse 300 Film Thickness Measurement System | Metrology | 8";12" |
| 16001041 | RUDOLPH | VANGUARD SPECTRALASER 200XL thickness measure | Metrology | |
| 13000968 | RVSI | GS 7100 Lead Scanner | Test & Handling | |
| 13000777 | RVSI | LS 3700 DB Laser Scanner | Test & Handling | |
| 13000625 | RVSI | LS 3700 Lead Scanner | Test & Handling | |
| 13000969 | RVSI | LS 6000 Lead Scanner | Test & Handling | |
| 13000974 | RVSI | LS 7100 Lead Scanner | Test & Handling | |
| 13000776 | RVSI | LS 7700 Laser Scanner Inspection System | Test & Handling | |
| 13000776 | RVSI | LS 7700 Laser Scanner Inspection System | Test & Handling | |
| 27000329 | SC FLUIDS | CPD1100 Supercritical CO2 Cleaner/Dryer | Wet Processing | |
| 13000578 | SCHLUMBERGER | IDS 10000 Plus Voltage Contrast Test System | Test & Handling | |
| 13000221 | SCHLUMBERGER | IDS 5000 HX Optical Probing System | Test & Handling | |
| 13000973 | SCHLUMBERGER | ITS 9000 KX Digital VLSI Test System | Test & Handling | |
| 13000328 | SCHLUMBERGER | ITS 9000 MX Digital VLSI Test System | Test & Handling | |
| 13000622 | SCHLUMBERGER | S 15 Digital VLSI Test System | Test & Handling | |
| 13000416 | SCHLUMBERGER | S 1650 VLSI Test System | Test & Handling | |
| 13000416 | SCHLUMBERGER | S 1650 VLSI Test System | Test & Handling | |
| 24000161 | SEC | Model 410 Flip Chip Bonder | Wire Bonders | |
| 90000147 | SEIKO | SMI 9800 FIB | Microscopes | 6" |
| 90000147 | SEIKO | SMI 9800 FIB | Microscopes | 6" |
| 13000839 | SEIKO EPSON | NS 5000 Test Handler | Test & Handling | |
| 13001083 | SEIKO EPSON | NS 5040 Test Handler | Test & Handling | |
| 22000013 | SEMI SYSTEMS | 150-33-BCDBC-85 Track System | Tracks | 6" |
| 22000014 | SEMI SYSTEMS | 33-PCSBBC-85 Model 150 Track | Tracks | 6" |
| 16000572 | SEMICONDUCTOR DIAGNOSTICS | FAast 330 COCOS Dielectric Characterization System | Metrology | 8";12" |
| 16000572 | SEMICONDUCTOR DIAGNOSTICS | FAast 330 COCOS Dielectric Characterization System | Metrology | 8";12" |
| 16000571 | SEMICONDUCTOR DIAGNOSTICS | SPV 300 Surface Photo Voltage Measurement System | Metrology | 8";12" |
| 16000785 | SEMITEST | SCA-2500 Real-Time Surface Charge Analyzer w/ Auto Loader | Metrology | 4";5";6";8" |
| 10000620 | SEMITHERM | VTP 1500 LH LPCVD Reactor (SiN) | CVD & Epi | |
| 10000621 | SEMITHERM | VTP 1500 LH LPCVD Reactor (SiO2/PolySi) | CVD & Epi | |
| 27000120 | SEMITOOL | 260-F SRD | Wet Etch & Clean SRD | 5" |

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| Item No. | OEM | Model/Description | Type | Wafer Size (Inches) |
|----------|----------|--|----------------------|---------------------|
| 27000121 | SEMITOOL | 270-F SRD | Wet Etch & Clean SRD | 6" |
| 27000156 | SEMITOOL | 270-S SRD | Wet Etch & Clean SRD | 6" |
| 27000238 | SEMITOOL | 280-S SRD | Wet Etch & Clean SRD | 6";8" |
| 27000048 | SEMITOOL | 4300-S SRD | Wet Etch & Clean SRD | 5";6";8" |
| 27000048 | SEMITOOL | 4300-S SRD | Wet Etch & Clean SRD | 8" |
| 27000239 | SEMITOOL | 440-S SRD | Wet Etch & Clean SRD | 2" |
| 27000330 | SEMITOOL | 470S Spin Rinser/Dryer (SRD) | Wet Processing | |
| 27000127 | SEMITOOL | 470-S SRD | Wet Etch & Clean SRD | 4"; 6" |
| 27000158 | SEMITOOL | 480-F SRD | Wet Etch & Clean SRD | 6";8" |
| 27000331 | SEMITOOL | 480S Spin Rinser/Dryer (SRD) | Wet Processing | |
| 27000126 | SEMITOOL | 480-S SRD | Wet Etch & Clean SRD | 6";8" |
| 27000123 | SEMITOOL | 8300-F SRD | Wet Etch & Clean SRD | 8" |
| 27000125 | SEMITOOL | 8300-S SRD | Wet Etch & Clean SRD | 8" |
| 27000124 | SEMITOOL | 840-S SRD | Wet Etch & Clean SRD | 4" |
| 27000154 | SEMITOOL | 860-S SRD | Wet Etch & Clean SRD | 4";5" |
| 27000226 | SEMITOOL | 870-D Double Stack SRD | Wet Etch & Clean SRD | 4";5";6" |
| 27000051 | SEMITOOL | 870-F Double Stack SRD w/ P-328 Controller | Wet Etch & Clean SRD | 6" |
| 27000052 | SEMITOOL | 870-S SRD | Wet Etch & Clean SRD | 4";5";6" |
| 27000157 | SEMITOOL | 880-S SRD | Wet Etch & Clean SRD | 6";8" |
| 29000002 | SEMITOOL | EC 334 PRECS Plating System | Copper Plating | 8" |
| 27000297 | SEMITOOL | Equinox | Wet Etch & Clean SRD | |
| 29000010 | SEMITOOL | Equinox Plating System | Copper Plating | 4" |
| 29000014 | SEMITOOL | LT 206M Plating System | Copper Plating | 8" |
| 29000013 | SEMITOOL | LT 210C Copper Electroplating System | Copper Plating | 6" |
| 27000285 | SEMITOOL | LT 210c Electrochemical deposition | Wet Etch & Clean SRD | 8" |
| 29000013 | SEMITOOL | LT 210C Electroplating System | Copper Plating | 8" |
| 27000054 | SEMITOOL | Magnum Solvent Cleaning System | Wet Etch & Clean SRD | 8" |
| 27000231 | SEMITOOL | Magnum Solvent Cleaning System | Wet Etch & Clean SRD | 8" |
| 27000167 | SEMITOOL | Millenium Photoresist Stripping System (Used for Copper Process) | Wet Etch & Clean SRD | 8" |
| 29000016 | SEMITOOL | Paragon P501P08S Electroplating System | Copper Plating | 8" |
| 27000298 | SEMITOOL | Paragon plating resist tool | Wet Etch & Clean SRD | |
| 27000299 | SEMITOOL | PSC 101 SRD | Wet Etch & Clean SRD | |
| 27000300 | SEMITOOL | PSC 102 SRD | Wet Etch & Clean SRD | |
| 27000240 | SEMITOOL | SAT 106 Spray Acid Cleaning System | Wet Etch & Clean SRD | 6" |
| 27000053 | SEMITOOL | SAT 4060D Spray Acid Cleaning System | Wet Etch & Clean SRD | 6" |
| 27000145 | SEMITOOL | SAT 40812(4P)CDJ Spray Acid Cleaning System | Wet Etch & Clean SRD | 8" |
| 10000529 | SEMITOOL | Semitherm VTP Express Vertical Furnace | Diffusion | 8" |
| 27000286 | SEMITOOL | Spectrum acid/solvent spray tool | Wet Etch & Clean SRD | |
| 27000162 | SEMITOOL | Spectrum Wafer Cleaning System | Wet Etch & Clean SRD | 8" |
| 27000092 | SEMITOOL | SST Metal Lift-Off System | Wet Etch & Clean SRD | 6" |
| 27000276 | SEMITOOL | SSTF201280F 3 phase, 5 wire 1997 | Wet Etch & Clean SRD | |
| 27000118 | SEMITOOL | ST 240 SRD | Wet Etch & Clean SRD | 4" |
| 27000116 | SEMITOOL | ST 260 SRD | Wet Etch & Clean SRD | 6" |
| 27000116 | SEMITOOL | ST 260 SRD | Wet Etch & Clean SRD | 6" |
| 27000058 | SEMITOOL | ST 260D SRD | Wet Etch & Clean SRD | 6" |
| 27000176 | SEMITOOL | ST 260F SRD | Wet Etch & Clean SRD | 6" |
| 27000060 | SEMITOOL | ST 270 SRD (Fully Refurbished) | Wet Etch & Clean SRD | 6" |
| 27000061 | SEMITOOL | ST 280 SRD | Wet Etch & Clean SRD | 5" |
| 27000153 | SEMITOOL | ST 440 SRD | Wet Etch & Clean SRD | 4" |
| 27000063 | SEMITOOL | ST 460 SRD | Wet Etch & Clean SRD | 8" |
| 27000095 | SEMITOOL | ST 470 SRD | Wet Etch & Clean SRD | 6" |
| 27000119 | SEMITOOL | ST 840 SRD | Wet Etch & Clean SRD | 6" |
| 27000130 | SEMITOOL | ST 860 Dual Stack SRD | Wet Etch & Clean SRD | 3";4";5" |
| 27000064 | SEMITOOL | ST 860 SRD (Fully Refurbished) | Wet Etch & Clean SRD | 6" |
| 27000067 | SEMITOOL | ST 870 SRD | Wet Etch & Clean SRD | 3";4";5";6";7" |
| 27000067 | SEMITOOL | ST 870 SRD | Wet Etch & Clean SRD | 3";4";5";6";7" |
| 27000159 | SEMITOOL | ST 880 Double Stack SRD | Wet Etch & Clean SRD | 8" |
| 27000230 | SEMITOOL | ST 880S Double Stack SRD | Wet Etch & Clean SRD | 8" |
| 27000072 | SEMITOOL | ST 880S Double Stack SRD (Refurbished) | Wet Etch & Clean SRD | 8" |
| 27000228 | SEMITOOL | Storm 2 Cassette Cleaning System | Wet Etch & Clean SRD | 8" |
| 27000079 | SEMITOOL | WSST 705 MG Photoresist Stripper System | Wet Etch & Clean SRD | 6" |
| 27000301 | SEMITOOL | WST 306 MI Photoresist Stripper System | Wet Etch & Clean SRD | |
| 27000229 | SEMITOOL | WST 3081 AC Wet Strip Processor System | Wet Etch & Clean SRD | 8" |
| 27000165 | SEMITOOL | WST 618A Photoresist Stripper System | Wet Etch & Clean SRD | 6" |
| 22000443 | SEMIX | 6132/TR SOG Coat System | Tracks | 6" |
| 22000444 | SEMIX | 6133UD SOG Coat System, 3 hot plates, 500 deg Max | Tracks | 6" |
| 22000336 | SEMIX | TR 6132-U SOG Coat System | Tracks | 6" |
| 22000169 | SEMIX | TR 8171-UD-TM SOG Spin/Coat/Bake System (SMIF) | Tracks | 8" |
| 13000414 | SENTRY | 90 Memory Test System | Test & Handling | |
| 13000412 | SENTRY | S 10 or S 10B VLSI Test System | Test & Handling | |

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|----------|------------------------|--|----------------------|---------------------|
| 13000411 | SENTRY | S21/S20 20 MHz Digital Test System | Test & Handling | |
| 13000413 | SENTRY | Sentinel Test System | Test & Handling | |
| 27000249 | SEZ | 201 Backside Spin Etch System | Etch/Ash/Strip | 8" |
| 27000302 | SEZ | 201 spin processor | Wet Etch & Clean SRD | |
| 27000303 | SEZ | 203 spin processor | Wet Etch & Clean SRD | |
| 27000227 | SEZ | 223 Dual Chamber Backside Spin Etch System | Wet Etch & Clean SRD | 8" |
| 27000227 | SEZ | 223 Dual Chamber Backside Spin Etch System | Wet Etch & Clean SRD | 8" |
| 27000236 | SEZ | 304 Backside Spin Etch System | Wet Etch & Clean SRD | 12" |
| 27000236 | SEZ | 304 Backside Spin Etch System | Wet Etch & Clean SRD | 12" |
| 27000332 | SEZ | 323 Spin Processor | Wet Etch & Clean SRD | |
| 27000287 | SEZ | 4200 spin processor | Wet Etch & Clean SRD | |
| 27000333 | SEZ | DV-24BF wafer cleaner | Wet Etch & Clean SRD | |
| 27000278 | SEZ | RST 201 all wafers Backside etch | Wet Etch & Clean SRD | |
| 27000279 | SEZ | RST 203 all wafers front and backside etch | Wet Etch & Clean SRD | |
| 16000976 | SHIBARA | CDE 463-OC resistivity mapper/ 4 point probe | Metrology | |
| 20000902 | SHIBAURA | CDE 80 microwave utilized chemical dry etch | Etch/Ash/Strip | 8" |
| 20000940 | SHIBAURA | CDE 80 NH | Etch/Ash/Strip | |
| 20000941 | SHIBAURA | CFS 8EP 55 | Etch/Ash/Strip | |
| 20000942 | SHIBAURA | ILS 3000 DPS | Etch/Ash/Strip | |
| 24000053 | SHINKAWA | SWB-FA-US-30 Automatic Wire Bonder | Wire Bonders | |
| 24000242 | SHINKAWA | UTC 200 wire bonders | Wire Bonders | |
| 24000226 | SHINKAWA | UTC250 wire bonder | Wire Bonders | |
| 13001284 | SIEMENS | SIPLACE HS-60 chip placement system - high speed | Test & Handling | |
| 22000346 | SIGMAMELTEC | CTS 5000 Coating System | Tracks | 8" |
| 13000736 | SIGNATONE | S-450 Wafer Probe System | Test & Handling | 6" |
| 28000052 | SOLITEC | 1100 Wafer Scrubbing System | CMP | 4";5";6" |
| 28000053 | SOLITEC | 5110 SJ Wafer Scrubbing System | CMP | 4";5";6" |
| 27000334 | SOLITEC | 5110-CD Singe Spindle Spin/Spray Combination Coater-Developer | Wet Processing | |
| 16000377 | SOPRA | ES-4G Spectroscopic Ellipsometer | Metrology | 6" |
| 28000162 | SPEEDFAM/IPEC | Avanti 372 CMP polish / Planarization | CMP | 8" |
| 28000163 | SPEEDFAM/IPEC | Avanti 676 W polish | CMP | 8" |
| 19000327 | SPEEDLINE TECHNOLOGIES | MPM AP EXCEL screen printer | Steppers | |
| 21000173 | SSEC | Evergreen 10/50 Mask/Wafer Cleaning System | Mask Cleaners | 6" |
| 27000288 | STEAG | AWP wet bench | Wet Etch & Clean SRD | |
| 27000208 | STEAG | AWP Wet Station | Wet Etch & Clean SRD | 8" |
| 27000304 | STEAG | STT | Wet Etch & Clean SRD | |
| 28000114 | STRASBAUGH | 6DS-SP Metal CMP System | CMP | 8" |
| 28000091 | STRASBAUGH | 6DS-SP/6 CMP System | CMP | 6" |
| 20000983 | STS | ASPECT Cluster Etcher | Etch/Ash/Strip | |
| 20000771 | STS | Multiplex Deep Trench Silicon Etch System w/ 2 X Multiplex ICP ASE Standard Rate Etch Chambers | Etch/Ash/Strip | 6";8" |
| 30000083 | STS | Multiplex PECVD System | CVD & Epi | 4";6";8" |
| 30000083 | STS | Multiplex PECVD System | CVD & Epi | 4";6";8" |
| 20000675 | STS | Multiplex RIE System | Etch/Ash/Strip | 3";4";5";6";8" |
| 20000943 | SUMITOMO | NV GSD III LE | Etch/Ash/Strip | |
| 20000783 | SUMITOMO | OZ 4000 Oxide Etch System | Etch/Ash/Strip | 8" |
| 22000469 | SVG | 90S Track | Tracks | |
| 10000591 | SVG/AVIZA | AVP 8000 vertical furnace (2 doped poly) | Diffusion | |
| 10000592 | SVG/AVIZA | AVP 8200 vertical furnace | Diffusion | |
| 10000593 | SVG/AVIZA | AVP 9200 vertical furnace | Diffusion | |
| 10000565 | SVG/AVIZA | VTR 7000 vertical furnaces (Nitride/HTO and/or Poly) | Diffusion | |
| 22000488 | SVG/THERMCO | 761 track | Tracks | |
| 22000489 | SVG/THERMCO | 8600 track | Tracks | |
| 10000602 | SVG/THERMCO | AVP 8000 Oxide | Diffusion | |
| 10000531 | SVG/THERMCO | VTR 7000 Anneal Furnace | Diffusion | 8" |
| 10000603 | SVG/THERMCO | VTR 7000 LPCVD | Diffusion | |
| 10000495 | SVG/THERMCO | VTR 7000 Oxide Furnace (TEOS) | Diffusion | 8" |
| 10000495 | SVG/THERMCO | VTR 7000 Oxide Furnace (TEOS) | Diffusion | 8" |
| 10000388 | SVG/THERMCO | VTR 7000+ Nitride Deposition Furnace | Diffusion | 6" |
| 10000530 | SVG/THERMCO | VTR 8000 AVP Vertical Diffusion Furnace | Diffusion | 6" |
| 10000604 | SVG/THERMCO | VTR Nitride | Diffusion | |
| 22000341 | SVGL | 8100 Dual Coat Track | Tracks | 6" |
| 22000194 | SVGL | 8326/8836 Track Develop System | Tracks | 6" |
| 22000342 | SVGL | 8600 Coat Track | Tracks | 6" |
| 28000041 | SVGL | 8620 Track Wafer Scrubbing System | CMP | 4";5";6" |
| 22000305 | SVGL | 8626PC Single Track Coating System | Tracks | 4" |
| 22000200 | SVGL | 8626PC/8636 HPO Dual Polyimide Coat Track | Tracks | 6" |
| 22000309 | SVGL | 8632CTD/8636HPO Single Track Develop System | Tracks | 4" |
| 22000310 | SVGL | 8632CTD/8636HPO Single Track Develop System | Tracks | 4" |
| 22000201 | SVGL | 8636 HPO/8632/3636 HPO 3 Track Positive Developer System | Tracks | 6" |

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|----------|---------------------|---|-----------------|---------------------|
| 22000198 | SVGL | 8638VP/8826PC/8836HPO/8638VP Track Coat System | Tracks | 4" |
| 22000313 | SVGL | 8800 Coat/Develop Track | Tracks | 6" |
| 22000253 | SVGL | 8826PC/8836 HPO 3 Track Coat System | Tracks | 6" |
| 22000340 | SVGL | 8832 Dual Develop Track | Tracks | 6" |
| 22000181 | SVGL | 8832/8826PC Coat/Develop Track Developer System (Refurbished) | Tracks | 4";5";6" |
| 19000328 | SVGL | MICRASCAN MPT 193nm Scanner | Steppers | |
| 19000193 | SVGL | Microscan 2 DUV Scanner | Steppers | 8" |
| 22000020 | SVGL | Series 90 Coat (3)/Develop(2) Two Track System | Tracks | 8" |
| 22000370 | SVGL | Series 90 Coat/Develop Track System | Tracks | 8" |
| 22000490 | SVGL | Series 90 PR 3 coat / 2 develop | Tracks | |
| 22000365 | SVGL | Series 90 UV Coat (2)/Develop(3) Two Track System | Tracks | 8" |
| 22000470 | SVGL | WJ1500 STI fill | Tracks | |
| 13000434 | SYMTEK | Various Model Handlers Available | Test & Handling | |
| 13000658 | SYNTAX | 1201 Handler | Test & Handling | |
| 13000911 | SYNTAX | 121 H Handler | Test & Handling | |
| 13000911 | SYNTAX | 121 H Handler | Test & Handling | |
| 13000771 | SYNTAX | 1601 C Handler | Test & Handling | |
| 13001104 | SYNTAX | SX 1211 Pick & Place Handler | Test & Handling | |
| 13001103 | SYNTAX | SX 141 Pick & Place Handler | Test & Handling | |
| 13001058 | SYNTAX | SX 141V & 141C Pick & Place Handlers | Test & Handling | |
| 16001042 | SYNTEC | Yamada 250 Bright Light Inspection Tool\ | Metrology | |
| 17000113 | TAMARACK SCIENTIFIC | 165 Mask Aligner | Mask Aligners | |
| 20000627 | TECHNICS | 500 II Low Temperature Strip/Clean System | Etch/Ash/Strip | 4";5";6" |
| 50000206 | TECHNICS | Hummer II Coater | PVD Sputter | |
| 20000517 | TECHNICS | Micro RIE 220 Stripping System | Etch/Ash/Strip | 6" |
| 20000473 | TECHNICS | Micro RIE 800 Benchtop Reactive Ion Etching/Stripping System | Etch/Ash/Strip | 6" |
| 20000984 | TECHNICS | Micro RIE Series 800 | Etch/Ash/Strip | |
| 20000985 | TECHNICS | Micro Stripper Series 220 Plasma System | Etch/Ash/Strip | |
| 20000569 | TECHNICS | PE II Etch/Strip System | Etch/Ash/Strip | 4";5";6" |
| 20000986 | TECHNICS | PE II-A Plasma Etcher | Etch/Ash/Strip | |
| 20000570 | TECHNICS | RIE 80 Etch/Strip System | Etch/Ash/Strip | 4";5";6" |
| 20000571 | TECHNICS | RIE 8000 Etch/Strip System | Etch/Ash/Strip | 4";5";6" |
| 20000564 | TEGAL | 1511e Etching System | Etch/Ash/Strip | 3";4";5";6" |
| 20000628 | TEGAL | 400 Plasma Barrel Stripping System | Etch/Ash/Strip | 6" |
| 20000944 | TEGAL | 411 plasma barrel stripper | Etch/Ash/Strip | |
| 20000557 | TEGAL | 415 Plasma Barrel Stripping System | Etch/Ash/Strip | 4";5";6" |
| 20000557 | TEGAL | 415 Plasma Barrel Stripping System | Etch/Ash/Strip | 4";5";6" |
| 20000562 | TEGAL | 421 Plasmaline Stripping System | Etch/Ash/Strip | 6" |
| 20000563 | TEGAL | 515 Plasma Ashing System | Etch/Ash/Strip | 2";3";4";5";6" |
| 20000566 | TEGAL | 703 Oxide Etch System | Etch/Ash/Strip | 4" |
| 20000567 | TEGAL | 801 Etch System | Etch/Ash/Strip | 4";5";6" |
| 20000567 | TEGAL | 801 Etch System | Etch/Ash/Strip | 4";5";6" |
| 20000568 | TEGAL | 803 Poly Etch System | Etch/Ash/Strip | 4";5";6" |
| 20000568 | TEGAL | 803 Poly Etch System | Etch/Ash/Strip | 4";5";6" |
| 20000568 | TEGAL | 803 Poly Etch System | Etch/Ash/Strip | 5" |
| 2000062 | TEGAL | 900e Photoresist Strip System | Etch/Ash/Strip | 4" |
| 2000062 | TEGAL | 900e Photoresist Strip System | Etch/Ash/Strip | 6" |
| 2000063 | TEGAL | 901e Poly/Nitride Etch System | Etch/Ash/Strip | 3" |
| 2000063 | TEGAL | 901e Poly/Nitride Etch System | Etch/Ash/Strip | 6" |
| 20000228 | TEGAL | 903 Oxide Etch System | Etch/Ash/Strip | 3";4";5";6" |
| 2000064 | TEGAL | 903e Oxide Etch System | Etch/Ash/Strip | 5" |
| 2000064 | TEGAL | 903e Oxide Etch System | Etch/Ash/Strip | 5";6" |
| 2000064 | TEGAL | 903e Oxide Etch System | Etch/Ash/Strip | 6" |
| 2000066 | TEGAL | 915 Batch Photoresist Ashing System | Etch/Ash/Strip | 6" |
| 20000319 | TEGAL | 965 Resist Stripping System | Etch/Ash/Strip | 4";5";6" |
| 13000039 | TEL | 19 S Wafer Probe System | Test & Handling | 6" |
| 13000039 | TEL | 19 S Wafer Probe System | Test & Handling | 6" |
| 13000997 | TEL | 20 SR Wafer Probe System | Test & Handling | 6" |
| 13001257 | TEL | 80W test prober | Test & Handling | |
| 22000471 | TEL | ACT 12 clean track | Tracks | |
| 22000410 | TEL | Act 12 Coat(2)/Develop(2) Track | Tracks | 12" |
| 22000335 | TEL | Act 12 Coat(2)/Develop(4) DUV Track | Tracks | 12" |
| 22000211 | TEL | Act 12 Coat/Develop DUV Coat(2)/Develop(2) Track | Tracks | 12" |
| 22000301 | TEL | Act 12 Coat/Develop DUV Coat(4)/Develop(4) Track | Tracks | 12" |
| 22000361 | TEL | Act 12 Coat/Develop i-Line Coat(1)/Develop(1) PIQ Track | Tracks | 12" |
| 22000376 | TEL | Act 12 Coat/Develop i-Line Coat(1)/Develop(1) Polyimide | Tracks | 12" |
| 22000049 | TEL | Act 12 Coat/Develop i-Line Coat(1)/Develop(2) Track | Tracks | 12" |
| 22000455 | TEL | Act 12 Coat/Develop Polyimide Coat(1)/Develop(2)/IFB(1) | Tracks | 12" |
| 22000247 | TEL | Act 12 SOD Coat Track | Tracks | 8" |

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|----------|-----|---|-----------|---------------------|
| 22000247 | TEL | Act 12 SOD Coat Track | Tracks | 8" |
| 22000475 | TEL | Act 8 BARC coat all wafers | Tracks | |
| 22000476 | TEL | Act 8 BARC coater | Tracks | |
| 22000491 | TEL | Act 8 clean track | Tracks | 8" |
| 22000481 | TEL | Act 8 clean track coat/developer | Tracks | 8" |
| 22000456 | TEL | Act 8 Coat(2)/Develop(2) Track | Tracks | 8" |
| 22000374 | TEL | Act 8 Coat(3)/Develop(4) Track | Tracks | 8" |
| 22000457 | TEL | Act 8 Coat(4)/Develop(4) Track | Tracks | 8" |
| 22000458 | TEL | Act 8 Coat/Develop Track | Tracks | 8" |
| 22000430 | TEL | Act 8 Mega DUV Track | Tracks | 8" |
| 22000459 | TEL | Act 8 SOD Coat Track | Tracks | 8" |
| 22000414 | TEL | Act 8 SOG Coat Single Block Track | Tracks | 8" |
| 22000415 | TEL | Act 8 SOG Coat(2) 1 & a half Block Track | Tracks | 8" |
| 22000353 | TEL | Act 8 tracks | Tracks | 8" |
| 10000605 | TEL | Alpha 303i oxide | Diffusion | |
| 10000482 | TEL | Alpha 303i Vertical Furnace | Diffusion | 12" |
| 10000510 | TEL | Alpha 601 D Diffusion Furnace | Diffusion | 6" |
| 10000510 | TEL | Alpha 601 D Diffusion Furnace | Diffusion | 8" |
| 10000505 | TEL | Alpha 801 Vertical Diffusion Furnace | Diffusion | 8" |
| 10000606 | TEL | Alpha 803C Oxide | Diffusion | 8" |
| 10000434 | TEL | Alpha 805 (85ZA) Gate Oxide Pyro Furnace | Diffusion | 8" |
| 10000607 | TEL | Alpha 805 D Oxide | Diffusion | 8" |
| 10000608 | TEL | Alpha 805 DN Oxide | Diffusion | 8" |
| 10000609 | TEL | Alpha 808 SC (Poly) furnace | Diffusion | 8" |
| 10000610 | TEL | Alpha 808 SC (SiN) furnace | Diffusion | 8" |
| 10000611 | TEL | Alpha 808 SC (TEOS) furnace | Diffusion | 8" |
| 10000514 | TEL | Alpha 808 SC LPCVD Nitride Furnace | Diffusion | 8" |
| 10000515 | TEL | Alpha 808 SC LPCVD Oxide TEOS Furnace | Diffusion | 8" |
| 10000516 | TEL | Alpha 808 SC LPCVD Poly Furnace | Diffusion | 8" |
| 10000517 | TEL | Alpha 808-SDF Vertical Furnace | Diffusion | 6" |
| 10000476 | TEL | Alpha 808-S-ZAFW LPCVD Nitride Furnace | Diffusion | 8" |
| 10000612 | TEL | Alpha 855 oxide | Diffusion | |
| 10000503 | TEL | Alpha 858 LPCVD Nitride Furnace | Diffusion | 8" |
| 10000504 | TEL | Alpha 858 LPCVD TEOS/Nitride Furnace | Diffusion | 8" |
| 10000491 | TEL | Alpha 858 SC Poly Furnace (Detachable SMIF) | Diffusion | 8" |
| 10000432 | TEL | Alpha 858 SCF Metal Anneal Furnace | Diffusion | 8" |
| 10000454 | TEL | Alpha 8S Copper Anneal Vertical Furnace | Diffusion | 8" |
| 10000456 | TEL | Alpha 8S HT Anneal Vertical Furnace (SMIF) | Diffusion | 8" |
| 30000538 | TEL | Alpha 8S LPCVD Poly/Si/SiN/HTO reactor | CVD & Epi | 8" |
| 10000622 | TEL | Alpha 8S LPCVD Reactor | CVD & Epi | |
| 10000438 | TEL | Alpha 8S LPCVD Vertical Poly Furnace | Diffusion | 8" |
| 30000539 | TEL | Alpha 8S Vacuum Metal Anneal Furnace | Diffusion | 8" |
| 10000441 | TEL | Alpha 8S Vertical Anneal Furnace | Diffusion | 8" |
| 10000440 | TEL | Alpha 8S Vertical Nitride Furnace | Diffusion | 8" |
| 10000439 | TEL | Alpha 8S Vertical Oxidation Furnace | Diffusion | 8" |
| 10000431 | TEL | Alpha 8S Vertical SiN-HTO Furnace | Diffusion | 8" |
| 10000566 | TEL | Alpha 8SCN LPCVD BTBAS furnace | Diffusion | |
| 10000567 | TEL | Alpha 8SCN LPCVD Poly furnace | Diffusion | |
| 10000613 | TEL | Alpha 8SE aneal | Diffusion | |
| 10000509 | TEL | Alpha 8SE ATPF Vertical Nitride LPCVD Furnace | Diffusion | 8" |
| 10000447 | TEL | Alpha 8SE Vertical Furnace | Diffusion | 8" |
| 10000428 | TEL | Alpha 8SE Vertical Furnace LPCVD SiN | Diffusion | 8" |
| 10000427 | TEL | Alpha 8SE Vertical LPCVD Furnace | Diffusion | 8" |
| 10000427 | TEL | Alpha 8SE Vertical LPCVD Furnace | Diffusion | 8" |
| 10000568 | TEL | Alpha 8SE ZV As doped LP TEOS | Diffusion | 8" |
| 10000569 | TEL | Alpha 8SE ZV As doped poly | Diffusion | 8" |
| 10000549 | TEL | Alpha 8SE-CN Vertical Poly Furnace | Diffusion | 8" |
| 10000507 | TEL | Alpha 8SE-E Vertical D-Poly Furnace | Diffusion | 8" |
| 10000525 | TEL | Alpha 8SE-E Vertical FTP Nitride Furnace | Diffusion | 8" |
| 10000414 | TEL | Alpha 8SE-E Vertical Oxidation Furnace | Diffusion | 8" |
| 10000414 | TEL | Alpha 8SE-E Vertical Oxidation Furnace | Diffusion | 8" |
| 10000437 | TEL | Alpha 8SE-E Vertical Ta2O5 LPCVD Furnace | Diffusion | 8" |
| 10000508 | TEL | Alpha 8SE-E Vertical TiN Furnace | Diffusion | 8" |
| 10000506 | TEL | Alpha 8SE-E-EVAFGN Nitride LPCVD Furnace | Diffusion | 8" |
| 10000532 | TEL | Alpha 8SE-ZABF Vertical Diffusion Furnace | Diffusion | 8" |
| 10000457 | TEL | Alpha 8S-Z Oxide Vertical Furnace | Diffusion | 8" |
| 10000387 | TEL | Alpha 8S-ZA Vertical H2 Sinter Furnace | Diffusion | 8" |
| 10000395 | TEL | Alpha 8S-ZA Vertical Pyro Furnace | Diffusion | 8" |
| 10000396 | TEL | Alpha 8S-ZAN Vertical Pyro Furnace | Diffusion | 8" |
| 10000533 | TEL | Alpha 8S-ZAN W/D Oxide Vertical Furnace | Diffusion | 8" |
| 10000572 | TEL | Alpha 8S-ZANW Copper sinter furnace | Diffusion | |

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| Item No. | OEM | Model/Description | Type | Wafer Size (Inches) |
|----------|-----|---|------------------|---------------------|
| 10000573 | TEL | Alpha 8S-ZANW doped poly ox/anneal | Diffusion | |
| 10000574 | TEL | Alpha 8S-ZANW Metal PMD dens | Diffusion | |
| 10000575 | TEL | Alpha 8S-ZANW undoped oxide furnace | Diffusion | |
| 10000576 | TEL | Alpha 8S-ZARNW Copper sinter anneal | Diffusion | |
| 10000577 | TEL | Alpha 8S-ZARNW Metal/Copper shared Low K anneal | Diffusion | |
| 10000578 | TEL | Alpha 8S-ZAW doped oxide/anneal furnace | Diffusion | |
| 10000579 | TEL | Alpha 8S-ZAW Metal/Copper shared PBO anneal furnace | Diffusion | |
| 10000580 | TEL | Alpha 8S-ZAW undoped STI liner/Densify | Diffusion | |
| 10000398 | TEL | Alpha 8S-ZV Vertical BPSG Furnace | Diffusion | 8" |
| 10000397 | TEL | Alpha 8S-ZV Vertical SiN Furnace | Diffusion | 8" |
| 10000399 | TEL | Alpha 8S-ZV Vertical TEOS Furnace | Diffusion | 8" |
| 10000400 | TEL | Alpha 8S-ZVFN Vertical TISI Furnace | Diffusion | 8" |
| 10000614 | TEL | Alpha 8S-ZVFNW FTFS (Poly) | Diffusion (Poly) | 8" |
| 10000480 | TEL | Alpha 8S-ZVFW (FTFS) Vertical LPCVD D-Poly Furnace | Diffusion | 8" |
| 10000401 | TEL | Alpha 8S-ZVN Vertical Poly Furnace | Diffusion | 8" |
| 10000623 | TEL | Alpha-303I-H vertical poly furnace | Diffusion | |
| 10000585 | TEL | Alpha-8 vertical furnace | Diffusion | |
| 10000624 | TEL | ALPHA-808 | Diffusion | |
| 10000625 | TEL | ALPHA-858D vertical furnace - alloy | Diffusion | |
| 10000626 | TEL | ALPHA-8S vertical furnace | Diffusion | |
| 10000627 | TEL | ALPHA-8S vertical furnace - doped Poly | Diffusion | |
| 10000628 | TEL | ALPHA-8S vertical furnace LPCVD | Diffusion | |
| 10000629 | TEL | ALPHA-8S vertical furnace Nitride | Diffusion | |
| 10000630 | TEL | ALPHA-8S vertical furnace Poly | Diffusion | |
| 10000631 | TEL | ALPHA-8S vertical furnace TEOS | Diffusion | |
| 10000632 | TEL | ALPHA-8SE vertical furnace | Diffusion | |
| 10000633 | TEL | ALPHA-8SE vertical furnace LPCVD | Diffusion | |
| 10000634 | TEL | ALPHA-8SEZ vertical furnace TEOS | Diffusion | |
| 10000635 | TEL | ALPHA-8S-Z vertical furnace | Diffusion | |
| 10000636 | TEL | ALPHA-8S-Z vertical furnace Gate oxide | Diffusion | |
| 10000637 | TEL | ALPHA-8S-ZV vertical furnace | Diffusion | |
| 22000492 | TEL | Cellesta clean tool | Tracks | |
| 22000505 | TEL | Clean Track Act 8 | Tracks | |
| 22000506 | TEL | CLEAN TRACK ACT 8 coat / developer track | Tracks | |
| 22000507 | TEL | CLEAN TRACK ACT 8 SOD spin on dielectric | Tracks | |
| 22000508 | TEL | Clean Track Mark 7 coater / developer | Tracks | |
| 22000509 | TEL | Clean Track Mark 8 | Tracks | |
| 22000510 | TEL | Clean Track Mark 8 coater | Tracks | |
| 22000511 | TEL | Clean Track Mark 8 coater/developer | Tracks | |
| 22000512 | TEL | Clean Track Mark 8 developer | Tracks | |
| 22000493 | TEL | Lithius | Tracks | |
| 22000369 | TEL | Mark 2 Coat(1)/Develop(1) Track | Tracks | 6" |
| 22000032 | TEL | Mark 2 Develop Track | Tracks | 6" |
| 22000460 | TEL | Mark 2 Develop(2) Track | Tracks | 6" |
| 22000494 | TEL | Mark 7 | Tracks | |
| 22000513 | TEL | Mark 7 clean track coat develop | Tracks | |
| 22000495 | TEL | Mark 8 | Tracks | |
| 22000496 | TEL | Mark 8 clean track | Tracks | 8" |
| 22000482 | TEL | Mark 8 clean track coat/developer and coat only | Tracks | 8" |
| 22000368 | TEL | Mark 8 Coat(1)/Develop(1) Polyimide Track | Tracks | 8" |
| 22000367 | TEL | Mark 8 Coat(2)/Develop(1) Track | Tracks | 6";8" |
| 22000195 | TEL | Mark 8 Coat(2)/Develop(2) Track | Tracks | 6";8" |
| 22000366 | TEL | Mark 8 Coat(2)/Develop(3) Track | Tracks | 6";8" |
| 22000417 | TEL | Mark 8 SOG Coat Track | Tracks | 8" |
| 22000418 | TEL | Mark Vz Coat Track | Tracks | 6" |
| 30000540 | TEL | MB2 730 WSi CVD System w/ 3 CVD Chambers | CVD & Epi | 8" |
| 30000366 | TEL | MB2 730 WSi CVD System w/ 3 CVD Chambers | CVD & Epi | 8" |
| 10000550 | TEL | MBF-8C LPCVD (LOCOS), Cs, Poly Si, TEOS | Diffusion | 6" |
| 13001258 | TEL | P12 XL tester | Test & Handling | |
| 13001285 | TEL | P-12XLn+ wafer prober | Test & Handling | |
| 13001148 | TEL | P8 and P8XL Wafer Probe Systems | Test & Handling | |
| 13000260 | TEL | P8 Wafer Probe System | Test & Handling | 8" |
| 13000260 | TEL | P8 Wafer Probe System | Test & Handling | 8" |
| 13000260 | TEL | P8 Wafer Probe System | Test & Handling | 8" |
| 13000260 | TEL | P8 Wafer Probe System | Test & Handling | 8" |
| 13000260 | TEL | P8 Wafer Probe System | Test & Handling | 8" |
| 13000260 | TEL | P8 Wafer Probe System | Test & Handling | 8" |
| 13000260 | TEL | P8 Wafer Probe System | Test & Handling | 8" |
| 13000769 | TEL | P8 XL Wafer Probe System | Test & Handling | 8" |
| 13000769 | TEL | P8 XL Wafer Probe System | Test & Handling | 8" |
| 13000769 | TEL | P8 XL Wafer Probe System | Test & Handling | 8" |

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|----------|----------|--|-------------------------|---------------------|
| 13000769 | TEL | P8 XL Wafer Probe System | Test & Handling | 8" |
| 13000805 | TEL | P8i Wafer Probe System | Test & Handling | 8" |
| 13001127 | TEL | P-8LC Wafer Probe System | Test & Handling | 8" |
| 13001259 | TEL | P8XL Wafer Probe System | Test & Handling | 8" |
| 13001286 | TEL | P-8XL wafer prober | Test & Handling | 8" |
| 28000164 | TEL | SS-2 double sided wafer scrubber | CMP | 8" |
| 28000175 | TEL | SS-2/4 Double-Sided Wafer Scrubber | Wet Processing | 8" |
| 22000514 | TEL | SS-4 wafer scrubber | Tracks | 8" |
| 20000853 | TEL | TE-5000 Oxide Etch System | Etch/Ash/Strip | 8" |
| 20000119 | TEL | TE-580 LC Oxide Etch System | Etch/Ash/Strip | 6" |
| 20000773 | TEL | TE-8500 Oxide Etch System | Etch/Ash/Strip | 8" |
| 20000773 | TEL | TE-8500 Oxide Etch System | Etch/Ash/Strip | 8" |
| 20000854 | TEL | TE8500PE ATC Oxide etcher, clamp type | Etch/Ash/Strip | 8" |
| 20000855 | TEL | TEL 580 Oxide etch | Etch/Ash/Strip | 6" |
| 20000668 | TEL | Telius DRM Chamber (Chamber Only Position A) | Etch/Ash/Strip | 12" |
| 20000885 | TEL | Telius SP 3 chamber SCCM DT | Etch/Ash/Strip | 8" |
| 20000945 | TEL | Telius SP plasma etcher | Etch/Ash/Strip | 8" |
| 10000486 | TEL | Trias LPCVD System | Diffusion | 12" |
| 18000031 | TEL | Trias-SPA 1-CH Nitridation Gate Hardening System | Photorealist Cure/Prime | 12" |
| 20000946 | TEL | Unity 84DS Si/REI | Etch/Ash/Strip | 8" |
| 20000947 | TEL | Unity 85 DD (DRM) oxide etcher (1B/1C Hole) 2 chamber | Etch/Ash/Strip | 8" |
| 20000948 | TEL | Unity 85 DD (DRM) oxide etcher (BS SAC) | Etch/Ash/Strip | 8" |
| 20000949 | TEL | Unity 85DM SiO2/REI | Etch/Ash/Strip | 8" |
| 20000950 | TEL | Unity 85DP SiO2/REI | Etch/Ash/Strip | 8" |
| 30000398 | TEL | Unity CVD Ti/TiN System w/ 1 X Ti & 1 X TiN CVD Chambers | CVD & Epi | 8" |
| 20000886 | TEL | Unity DRM Metal Copper shared etcher MF | Etch/Ash/Strip | 8" |
| 20000887 | TEL | Unity DRM Metal Copper shared oxide etcher | Etch/Ash/Strip | 8" |
| 10000581 | TEL | Unity DRM Metal oxide etcher | Diffusion | 8" |
| 20000888 | TEL | Unity DRM metal oxide etcher | Etch/Ash/Strip | 8" |
| 10000582 | TEL | Unity DRM metal/Copper shared oxide etch | Diffusion | 8" |
| 20000987 | TEL | UNITY II 84DS Poly etcher | Etch/Ash/Strip | 8" |
| 20000988 | TEL | UNITY II 85DD Dielectric etcher | Etch/Ash/Strip | 8" |
| 20000989 | TEL | UNITY II e 88DS deep trench etcher | Etch/Ash/Strip | 8" |
| 20000800 | TEL | Unity Iie 85 DRM Dual Chamber Etch System | Etch/Ash/Strip | 8" |
| 20000951 | TEL | Unity Iie 85 DRM etcher | Etch/Ash/Strip | 8" |
| 20000778 | TEL | Unity Iie 85DD DRM Dual Chamber Etch System | Etch/Ash/Strip | 8" |
| 20000713 | TEL | Unity Iie 88 DRM Dual Chamber Etch System | Etch/Ash/Strip | 8" |
| 20000725 | TEL | Unity Iie 88 SCCM Etch System | Etch/Ash/Strip | 8" |
| 20000952 | TEL | Unity M 85 DRM etcher | Etch/Ash/Strip | 8" |
| 20000990 | TEL | UNITY M 85 TD Reactive ion etcher | Etch/Ash/Strip | 8" |
| 20000799 | TEL | Unity ME 85 DD 3 Chamber Etch System | Etch/Ash/Strip | 8" |
| 20000953 | TEL | Unity ME 85 SCCM etcher | Etch/Ash/Strip | 8" |
| 10000583 | TEL | Unity ME Metal/Copper shared etcher | Diffusion | 8" |
| 20000377 | TEL | Unity SCCM 8500 Dielectric Etch Chamber (Chamber Only) | Etch/Ash/Strip | 8" |
| 27000215 | TEL | UW 200-Z Auto Carrier-Less Wet Station | Wet Etch & Clean SRD | 8" |
| 27000235 | TEL | UW 8000 Auto Wet Station | Wet Etch & Clean SRD | 8" |
| 22000515 | TEL | UW200Z wet bench | Tracks | 8" |
| 22000516 | TEL | UW8000 wet bench | Tracks | 8" |
| 10000501 | TEL | VCF-615 HTO Vertical Furnace | Diffusion | 6" |
| 10000500 | TEL | VDF-615 POCl3 Vertical Furnace | Diffusion | 6" |
| 22000477 | TEL | Act 8 DUJ coat / Dev all wafers | Tracks | 8" |
| 10000584 | TEL | Alpha 858 D Alloy furnace | Diffusion | 8" |
| 13000917 | TELEDYNE | TAC PR-100 Automatic Wafer Probing System | Test & Handling | 2";3";4";5";6" |
| 40000012 | TEMESCAL | 2550 E-Beam Evaporator | Evaporators | 4";5";6" |
| 40000010 | TEMESCAL | BJD-1800 E-Beam Evaporator | Evaporators | 2";3";4";5";6" |
| 40000010 | TEMESCAL | BJD-1800 E-Beam Evaporator | Evaporators | 2";3";4";5";6" |
| 40000010 | TEMESCAL | BJD-1800 E-Beam Evaporator | Evaporators | 2";3";4";5";6" |
| 40000047 | TEMESCAL | BJE-2400 Filament Evaporator | Evaporators | 2";3";4";5";6" |
| 40000007 | TEMESCAL | FC-1800 E-Beam Evaporator | Evaporators | 2";3";4";5";6" |
| 40000007 | TEMESCAL | FC-1800 E-Beam Evaporator | Evaporators | 2";3";4";5";6" |
| 40000007 | TEMESCAL | FC-1800 E-Beam Evaporator | Evaporators | 2";3";4";5";6" |
| 40000037 | TEMESCAL | FCE-4000 E-Beam Evaporator | Evaporators | 4";5";6" |
| 60000175 | TEMPRESS | 602 Dicing Saw | Dicing, Marking, Taping | 3" |
| 16001043 | TENCOR | Flexus FLX 2320 | Metrology | 8" |
| 16001044 | TENCOR | Surfscan 6200 | Metrology | 8" |
| 16001045 | TENCOR | TF2, Film Thickness Measuring System, 4" to 8" | Metrology | 8" |
| 20000671 | TEPLA | Auto 3000 Barrel Ashing System | Etch/Ash/Strip | 4";5";6";8" |
| 20000629 | TEPLA | Plasma 300M Etching/Stripping System | Etch/Ash/Strip | 6" |
| 13001053 | TERADYNE | 1820 Board Tester | Test & Handling | 8" |
| 13000960 | TERADYNE | 8852 Board Tester | Test & Handling | 8" |
| 13000334 | TERADYNE | A 312 Analog Test System | Test & Handling | 8" |

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|----------|------------|--|-----------------|---------------------|
| 13000061 | TERADYNE | A 360 Analog Test System | Test & Handling | |
| 13000061 | TERADYNE | A 360 Analog Test System | Test & Handling | |
| 13000061 | TERADYNE | A 360 Analog Test System | Test & Handling | |
| 13000618 | TERADYNE | A 500 Analog Test System | Test & Handling | |
| 13001105 | TERADYNE | A 520 Mixed Signal Test System | Test & Handling | |
| 13000042 | TERADYNE | A 540 Mixed Signal Test System | Test & Handling | |
| 13000042 | TERADYNE | A 540 Mixed Signal Test System | Test & Handling | |
| 13000042 | TERADYNE | A 540 Mixed Signal Test System | Test & Handling | |
| 13000461 | TERADYNE | A 550 Mixed Signal Test System | Test & Handling | |
| 13001081 | TERADYNE | A 565 Mixed Signal Test System | Test & Handling | |
| 13000959 | TERADYNE | A 567 Mixed Signal Test System | Test & Handling | |
| 13000588 | TERADYNE | A 575 Mixed Signal Test System | Test & Handling | |
| 13000588 | TERADYNE | A 575 Mixed Signal Test System | Test & Handling | |
| 13000064 | TERADYNE | A 585 Mixed Signal Test System | Test & Handling | |
| 13000064 | TERADYNE | A 585 Mixed Signal Test System | Test & Handling | |
| 13001106 | TERADYNE | A 588 Mixed Signal Test System | Test & Handling | |
| 13001054 | TERADYNE | A1805 Board Tester | Test & Handling | |
| 13001055 | TERADYNE | A1850 VP Board Tester | Test & Handling | |
| 13001260 | TERADYNE | A540 tester | Test & Handling | |
| 13001261 | TERADYNE | A585 tester | Test & Handling | |
| 13001262 | TERADYNE | Catalyst | Test & Handling | |
| 13001130 | TERADYNE | Catalyst Test System | Test & Handling | |
| 13001130 | TERADYNE | Catalyst Test System | Test & Handling | |
| 13001068 | TERADYNE | Catalyst Test System | Test & Handling | |
| 13001068 | TERADYNE | Catalyst Test System | Test & Handling | |
| 13001149 | TERADYNE | Catalyst Test System | Test & Handling | |
| 13001223 | TERADYNE | FLEX tester | Test & Handling | |
| 13001263 | TERADYNE | Integra FLEX | Test & Handling | |
| 13000419 | TERADYNE | J 921 SP 120 MHz VLSI Test System | Test & Handling | |
| 13000043 | TERADYNE | J 937 Memory Test System | Test & Handling | |
| 13000043 | TERADYNE | J 937 Memory Test System | Test & Handling | |
| 13000043 | TERADYNE | J 937 Memory Test System | Test & Handling | |
| 13000043 | TERADYNE | J 937 Memory Test System 50 and 100MHz Available | Test & Handling | |
| 13001264 | TERADYNE | J 937 tester | Test & Handling | |
| 13000619 | TERADYNE | J 941 Digital VLSI Test System | Test & Handling | |
| 13000337 | TERADYNE | J 971 VLSI Test System | Test & Handling | |
| 13000337 | TERADYNE | J 971 VLSI Test System | Test & Handling | |
| 13000337 | TERADYNE | J 971 VLSI Test System | Test & Handling | |
| 13000337 | TERADYNE | J 971 VLSI Test System | Test & Handling | |
| 13001128 | TERADYNE | J 973 AP VLSI Test System | Test & Handling | 8" |
| 13001082 | TERADYNE | J 973 VLSI Test System | Test & Handling | |
| 13001082 | TERADYNE | J 973 VLSI Test System | Test & Handling | |
| 13001082 | TERADYNE | J 973 VLSI Test System | Test & Handling | |
| 13000778 | TERADYNE | J 993 Memory Test System | Test & Handling | |
| 13000780 | TERADYNE | J 995 Memory Test System | Test & Handling | |
| 13000219 | TERADYNE | J 997 Memory Test System | Test & Handling | |
| 13001265 | Teradyne | J750 digital tester | Test & Handling | |
| 13001266 | TERADYNE | J750 test system | Test & Handling | |
| 13001224 | TERADYNE | J750 tester | Test & Handling | |
| 13001231 | TERADYNE | J971 test systems | Test & Handling | |
| 13001287 | TERADYNE | J973 auto test system | Test & Handling | |
| 13001150 | TERADYNE | J994 (low cost sale) | Test & Handling | |
| 13001056 | TERADYNE | Javelin 1004 Flying Prober Board Tester | Test & Handling | |
| 13000962 | TERADYNE | L393 Functional Tester | Test & Handling | |
| 13001267 | TERADYNE | MicroFLEX | Test & Handling | |
| 13000498 | TERADYNE | OM 971FF Handler System for J 971 Test System | Test & Handling | |
| 13001215 | Teradyne | T666 static tester | Test & Handling | |
| 13001151 | TERADYNE | Tiger Test System | Test & Handling | |
| 13000669 | TERADYNE | Z1860 VP Board Tester | Test & Handling | |
| 13000671 | TERADYNE | Z1880-1 Board Tester | Test & Handling | |
| 13000674 | TERADYNE | Z1884 Board Tester | Test & Handling | |
| 13000967 | TESAM | 8653 Handler | Test & Handling | |
| 13000992 | TESAM | 8991 Handler | Test & Handling | |
| 16000898 | THERMAWAVE | 2600 all wafers Optiprobe | Metrology | |
| 16000899 | THERMAWAVE | 2600 non-metal wafers Optiprobe | Metrology | |
| 16000900 | THERMAWAVE | 5240 critical non metal thickness | Metrology | |
| 16000901 | THERMAWAVE | 5240D Critical non metal thickness Unit | Metrology | |
| 16000902 | THERMAWAVE | 7341 Critical non-metal thickness meas | Metrology | |
| 16000845 | THERMAWAVE | OP-2600B film thickness measurement system | Metrology | 6" |
| 16000663 | THERMAWAVE | Optiprobe 2500 Film Thickness Measurement System | Metrology | 6";8" |

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| 16000663 | THERMAWAVE | Optiprobe 2500 Film Thickness Measurement System | Metrology | 6",8" |
| 16001046 | THERMAWAVE | OptiProbe 2600 DUV | Metrology | |
| 16000720 | THERMAWAVE | Optiprobe 2600 DUV Film Thickness Measurement System | Metrology | 8" |
| 16000695 | THERMAWAVE | Optiprobe 2600 Film Thickness Measurement System | Metrology | 8" |
| 16001047 | THERMAWAVE | Opti-Probe 2600 thin film measurement | Metrology | |
| 16000762 | THERMAWAVE | Optiprobe 3260 DUV Film Thickness Measurement System | Metrology | 8" |
| 16000762 | THERMAWAVE | Optiprobe 3260 DUV Film Thickness Measurement System | Metrology | 8" |
| 16001048 | THERMAWAVE | OPTI-PROBE 3290 | Metrology | |
| 16000765 | THERMAWAVE | Optiprobe 5205 Film Thickness Measurement System | Metrology | 8" |
| 16000766 | THERMAWAVE | Optiprobe 5220 Film Thickness Measurement System | Metrology | 8" |
| 16000764 | THERMAWAVE | Optiprobe 5230 Film Thickness Measurement System | Metrology | 8" |
| 16001049 | THERMAWAVE | OptiProbe 5240 DUV | Metrology | |
| 16000719 | THERMAWAVE | Optiprobe 5240 Film Thickness Measurement System | Metrology | 8" |
| 16000760 | THERMAWAVE | Optiprobe 5240 Film Thickness Measurement System | Metrology | 8" |
| 16000761 | THERMAWAVE | Optiprobe 7341 Film Thickness Measurement System | Metrology | 8" |
| 16000761 | THERMAWAVE | Optiprobe 7341 Film Thickness Measurement System | Metrology | 8" |
| 16000903 | THERMAWAVE | Therma Probe 320S implant monitor | Metrology | |
| 16001050 | THERMAWAVE | Therma-Probe 500 metrology tool - Ion Implant | Metrology | |
| 16000846 | THERMAWAVE | TP-400XP dose measurement system | Metrology | 8" |
| 16000114 | THERMAWAVE | TP-420 Ion Implant Dose Measurement System | Metrology | 6" |
| 16000905 | THERMAWAVE | TP500 Non-metal Optiprobe | Metrology | |
| 10000346 | THERMCO | Mini-Brute MB-71 Furnace | Diffusion | 4";5";6" |
| 10000347 | THERMCO | Mini-Brute MB-80 Furnace | Diffusion | 4";5";6" |
| 10000348 | THERMCO | Mini-Brute MB-81 Furnace | Diffusion | 4";5";6" |
| 11000249 | THERMONICS | 2420 Temperature Forcing System | Miscellaneous | 6" |
| 20000954 | TOK | TEC 3822 (2ch) plasma etcher (1B, 2B) | Etch/Ash/Strip | 8" |
| 22000497 | TOK | TR 8171 UD TM SOG coat | Tracks | 8" |
| 22000158 | TOKYO OHKA KOGYO | TR-8171UD-TM SOG Coater Track | Tracks | 8" |
| 25000060 | TOSHIBA | EBM 3000B Electron Beam 110nm Mask Pattern Generating System | Photomasks | 6";7";8";9" |
| 20000588 | TRION | Minilock Single Wafer RIE System w/ Loadlock | Etch/Ash/Strip | 8" |
| 13000342 | TSK | APM 6000A Wafer Probe System | Test & Handling | 6" |
| 13000050 | TSK | APM 88 Wafer Probe System | Test & Handling | 4";5";6";8" |
| 13000050 | TSK | APM 88 Wafer Probe System | Test & Handling | 4";5";6";8" |
| 13000050 | TSK | APM 88 Wafer Probe System | Test & Handling | 4";5";6";8" |
| 13000913 | TSK | APM 90A Wafer Probe System | Test & Handling | 6";8" |
| 13000913 | TSK | APM 90A Wafer Probe System | Test & Handling | 6";8" |
| 13000913 | TSK | APM 90A Wafer Probe System | Test & Handling | 6";8" |
| 13000913 | TSK | APM 90A Wafer Probe System | Test & Handling | 6";8" |
| 13000913 | TSK | APM 90A Wafer Probe System | Test & Handling | 6";8" |
| 13000913 | TSK | APM 90A Wafer Probe System | Test & Handling | 6";8" |
| 13000913 | TSK | APM 90A Wafer Probe System | Test & Handling | 6";8" |
| 13001201 | TSK | APM 90A Wafer Probe System | Test & Handling | |
| 13001152 | TSK | APM 90A Wafer Probe System | Test & Handling | |
| 13001268 | TSK | PG 300 RM | Test & Handling | |
| 13001269 | TSK | PG 300 RM wafer prober | Test & Handling | |
| 26000027 | TSK | S-LM-116G Vertical Slicing System w/ ID Diamond Blade | Ingot/Wafer Manufacture | 4" |
| 13000282 | TSK | UF 190 Wafer Probe System | Test & Handling | 6" |
| 13000282 | TSK | UF 190 Wafer Probe System | Test & Handling | 6" |
| 13000282 | TSK | UF 190 Wafer Probe System | Test & Handling | 6" |
| 13001096 | TSK | UF 200 S Wafer Probe System | Test & Handling | 8" |
| 13001096 | TSK | UF 200 S Wafer Probe System | Test & Handling | 8" |
| 13001096 | TSK | UF 200 S Wafer Probe System | Test & Handling | 8" |
| 13000067 | TSK | UF 200 Wafer Probe System | Test & Handling | 8" |
| 13000067 | TSK | UF 200 Wafer Probe System | Test & Handling | 8" |
| 13000067 | TSK | UF 200 Wafer Probe System | Test & Handling | 8" |
| 13000067 | TSK | UF 200 Wafer Probe System | Test & Handling | 8" |
| 13000067 | TSK | UF 200 Wafer Probe System | Test & Handling | 8" |
| 13000067 | TSK | UF 200 Wafer Probe System | Test & Handling | 8" |
| 13000067 | TSK | UF 200 Wafer Probe System | Test & Handling | 8" |
| 13001271 | TSK | UF 2000 Wafer Probe System | Test & Handling | |
| 13000762 | TSK | UF 300 Wafer Probe System | Test & Handling | 8";12" |
| 13000762 | TSK | UF 300 Wafer Probe System | Test & Handling | 8";12" |
| 13001273 | TSK | UF200 EDS wafer prober | Test & Handling | |
| 13000067 | TSK | UF200 Wafer Probe System | Test & Handling | 8" |
| 13001288 | TSK | UF200A wafer prober | Test & Handling | |
| 13001124 | TSK | UF200AL Wafer Probe System | Test & Handling | 8" |
| 13000934 | TSK | UF200FL Wafer Probe System | Test & Handling | 8" |
| 13001096 | TSK | UF200S Wafer Probe System | Test & Handling | 8" |
| 13001270 | TSK | UF200SA wafer probe system | Test & Handling | 8" |
| 13001272 | TSK | UF300 Wafer Probe System | Test & Handling | 8" |

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|----------|--------------------|---|-------------------------|---------------------|
| 13000762 | TSK | UF3000 Wafer Probe System | Test & Handling | 8",12" |
| 16000914 | TSK | Win Win 50 1400 wafer inspection system | Metrology | |
| 13000458 | ULTRACISION | Model 880 Semi Automatic Production Analytical Prober | Test & Handling | 8" |
| 19000200 | ULTRATECH | 1000 Wide Field Stepper | Steppers | 6" |
| 19000200 | ULTRATECH | 1000 Wide Field Stepper | Steppers | 6" |
| 19000033 | ULTRATECH | 1100 Stepper | Steppers | 4",5",6",8" |
| 19000224 | ULTRATECH | 1100 Wide Field Stepper | Steppers | 6" |
| 19000247 | ULTRATECH | 1500 Stepper | Steppers | 6" |
| 19000282 | ULTRATECH | 1500 stepper | Steppers | 6" |
| 19000316 | ULTRATECH | 4700 Stepper | Steppers | |
| 19000081 | ULTRATECH | 4700 Stepper (2244 i-Line Titan) | Steppers | 5",6" |
| 19000081 | ULTRATECH | 4700 Stepper (2244 i-Line Titan) | Steppers | 6" |
| 19000256 | ULTRATECH | 4700 Stepper (2244 i-Line Titan) | Steppers | 8" |
| 19000210 | ULTRATECH | 601 g-Line Stepper | Steppers | 6" |
| 19000211 | ULTRATECH | 607 g-Line Stepper | Steppers | 6" |
| 19000176 | ULTRATECH | 6700 Stepper (Saturn) | Steppers | 5",6",8" |
| 19000202 | ULTRATECH | 900 Stepper | Steppers | 4",5",6",8" |
| 19000317 | ULTRATECH | LSA 100 | Steppers | |
| 21000060 | ULTRATECH | Model 1014 Mask/Wafer Scrubber (7" X 7") | Mask Cleaners | 4",5",6" |
| 21000175 | ULTRATECH | Model 2066 Mask/Wafer Scrubber | Mask Cleaners | 4",5",6" |
| 21000176 | ULTRATECH | Model 602 Mask/Wafer Scrubber | Mask Cleaners | 4",5",6" |
| 19000281 | ULTRATECH | Saturn i-line stepper | Steppers | |
| 21000163 | ULTRATECH | SCS 124 Mask/Wafer Scrubber | Mask Cleaners | 8" |
| 19000318 | ULTRATECH | Titan | Steppers | |
| 60000164 | ULTRON | UH 14-8 Wafer Taping System | Dicing, Marking, Taping | 8" |
| 30000566 | ULVAC | CERAUS CVD metal dep | CVD & Epi | |
| 14000200 | ULVAC | IW-630 ion implant | Ion Implant | |
| 30000541 | UNAXIS/BALZERS | Clusterline | CVD & Epi | |
| 30000265 | UNAXIS/PLASMATHERM | 700 Versalock Dual Chamber PECVD System | CVD & Epi | 6" |
| 20000630 | UNAXIS/PLASMATHERM | 720/730 RIE System | Etch/Ash/Strip | 6" |
| 30000324 | UNAXIS/PLASMATHERM | 730 SL PECVD System | CVD & Epi | 4" |
| 30000095 | UNAXIS/PLASMATHERM | 730 SLR PECVD System | CVD & Epi | 4" |
| 20000631 | UNAXIS/PLASMATHERM | 770/740-MF RIE System | Etch/Ash/Strip | 6" |
| 50000194 | UNAXIS/PLASMATHERM | BPS Clusterline 200 PVD Sputtering system | PVD Sputter | |
| 14000118 | VARIAN | 300 XP Mid Current Ion Implanter | Ion Implant | 6" |
| 40000013 | VARIAN | 3118 E-Beam Evaporator | Evaporators | 6" |
| 40000051 | VARIAN | 3118 Filament Evaporator | Evaporators | 6" |
| 40000053 | VARIAN | 3120 E-Beam Evaporator | Evaporators | 2",3",4" |
| 40000052 | VARIAN | 3125 E-Beam Evaporator | Evaporators | 2",3",4" |
| 40000041 | VARIAN | 3125 E-Beam Evaporator w/ 4 Pockets (Horizontal 25" Diameter Chamber) | Evaporators | 2",3",4" |
| 50000207 | VARIAN | 3180 Sputtering System | PVD Sputter | |
| 50000019 | VARIAN | 3290 Sputtering System | PVD Sputter | 6" |
| 14000011 | VARIAN | 350 D Mid Current Ion Implanter | Ion Implant | 6" |
| 14000061 | VARIAN | E 220 Mid-Current Ion Implanter | Ion Implant | 8" |
| 14000167 | VARIAN | E220 Ion Implanter medium current | Ion Implant | |
| 14000168 | VARIAN | E220 mid current implanter | Ion Implant | |
| 14000169 | VARIAN | E220HP Ion implanter medium current | Ion Implant | |
| 14000152 | VARIAN | E220HP Mid Current Implanter | Ion Implant | 8" |
| 14000160 | VARIAN | E500 Mid-Current Ion Implanter | Ion Implant | 8" |
| 14000136 | VARIAN | E500HP Mid-Current Ion Implanter | Ion Implant | 6",8" |
| 14000136 | VARIAN | E500HP Mid-Current Ion Implanter | Ion Implant | 6",8" |
| 14000150 | VARIAN | E500HPi Mid-Current Ion Implanter | Ion Implant | 8" |
| 40000042 | VARIAN | E-Beam Evaporator w/ 25" X 32" SS Chamber | Evaporators | 3",4",5",6" |
| 14000170 | VARIAN | EHP500 Non-metal midcurrent Implanter | Ion Implant | |
| 14000066 | VARIAN | HV 80-10 High Current Ion Implanter | Ion Implant | 6",8" |
| 14000066 | VARIAN | HV 80-10 High Current Ion Implanter | Ion Implant | 6",8" |
| 14000171 | VARIAN | Kestrel 650 Implanter | Ion Implant | |
| 50000185 | VARIAN | M2000 w dual cassette module, 1 etch, 4 dep modules | PVD Sputter | 6" |
| 14000185 | VARIAN | VIIISion 200 | Ion Implant | |
| 14000173 | VARIAN | VIIISion 80 High current implant | Ion Implant | |
| 14000186 | VARIAN | VIIISta 80 | Ion Implant | |
| 14000172 | VARIAN | VIIISta 80 Ion implant High current | Ion Implant | |
| 14000147 | VARIAN | VIIISta 80 Low Energy/High Current Implant System | Ion Implant | 8" |
| 14000187 | VARIAN | VIIISta 80HP | Ion Implant | |
| 14000201 | VARIAN | VIIISta 80HP High current Ion Implant | Ion Implant | |
| 14000174 | VARIAN | VIIISta 810 medium current implant | Ion Implant | 8" |
| 14000202 | VARIAN | VIIISta HC | Ion Implant | |
| 14000188 | VARIAN | Vision 80 LE Ion Implanter | Ion Implant | 8" |
| 50000208 | VCR | Group IBS TM200S | PVD Sputter | |
| 16000265 | VEECO | BP 2000W Surface Profilometer System | Metrology | 8" |

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|----------|-----------|---|-------------------------|---------------------|
| 9000244 | VEECO | D-3100S-1 Atomic Force Microscope | Microscopes | 8";12" |
| 16001051 | VEECO | Dektak 200-Si Profilometer | Metrology | |
| 16000795 | VEECO | Dektak 2A Surface Profilometer | Metrology | 3";4";5";6" |
| 16000361 | VEECO | Dektak 3 Surface Profilometer | Metrology | 3";4";5";6" |
| 16000977 | VEECO | Dektak 3030 profilometer | Metrology | |
| 16000458 | VEECO | Dektak 3030 Surface Profilometer | Metrology | 6" |
| 16000132 | VEECO | Dektak 3ST Surface Profilometer | Metrology | 3";4";5";6" |
| 16000132 | VEECO | Dektak 3ST Surface Profilometer | Metrology | 3";4";5";6" |
| 16000065 | VEECO | Dektak 8000 Long Scan Surface Profilometer | Metrology | 8" |
| 16000341 | VEECO | Dektak I Surface Profilometer | Metrology | 6" |
| 16000341 | VEECO | Dektak I Surface Profilometer | Metrology | 6" |
| 16000342 | VEECO | Dektak II Surface Profilometer | Metrology | 6" |
| 16000342 | VEECO | Dektak II Surface Profilometer | Metrology | 6" |
| 16000673 | VEECO | Dektak V200 SI Surface Profilometer | Metrology | 8" |
| 16000779 | VEECO | Dektak V300 SL Automated Surface Profile Measurement System | Metrology | 8";12" |
| 16000645 | VEECO | Dektak V320 SL Automated Surface Profile Measurement System | Metrology | 8";12" |
| 90000242 | VEECO | Dimension 3100 Atomic Force Microscope | Microscopes | 6";8" |
| 16001052 | VEECO | Dimension 9000M Atomic force profiler | Metrology | |
| 16001053 | VEECO | DIMENSION VX 210 | Metrology | |
| 40000043 | VEECO | E-Beam Evaporator w/ 18" X 30" Pyrex Bell Jar | Evaporators | 4";5";6" |
| 16000432 | VEECO | FPP-100 Four Point Probe | Metrology | 6" |
| 16000432 | VEECO | FPP-100 Four Point Probe | Metrology | 6" |
| 16000432 | VEECO | FPP-100 Four Point Probe | Metrology | 6" |
| 16000343 | VEECO | FPP-5000 Four Point Probe | Metrology | 6" |
| 50000209 | VEECO | Gen II MBE System | PVD Sputter | |
| 90000212 | VEECO | SXM 320 CD AFM | Microscopes | 8" |
| 90000212 | VEECO | SXM 320 CD AFM | Microscopes | 8" |
| 90000198 | VEECO | SXM Atomic Force Microscope | Microscopes | 6" |
| 90000198 | VEECO | SXM Atomic Force Microscope | Microscopes | 6" |
| 90000241 | VEECO | SXM Atomic Force Microscope | Microscopes | 8" |
| 16000721 | VEECO | Vx210 AFP Atomic Force Profilometer | Metrology | 8" |
| 90000265 | VEECO | VX-210 atomic force microscope | Microscopes | 8" |
| 16001054 | VEECO | Wyko NT3300 Profiling System | Metrology | |
| 27000081 | VERTEQ | 1600 Dual Stack SRD | Wet Etch & Clean SRD | 6" |
| 27000081 | VERTEQ | 1600 Dual Stack SRD | Wet Etch & Clean SRD | 6" |
| 27000082 | VERTEQ | 1600-33 Dual Stack SRD | Wet Etch & Clean SRD | 4";5";6" |
| 27000241 | VERTEQ | 1600-34 Dual Stack SRD | Wet Etch & Clean SRD | 4";5";6" |
| 27000241 | VERTEQ | 1600-34 Dual Stack SRD | Wet Etch & Clean SRD | 4";5";6" |
| 27000083 | VERTEQ | 1600-44 Dual Stack SRD | Wet Etch & Clean SRD | 5" |
| 27000132 | VERTEQ | 1600-55A Dual Stack SRD | Wet Etch & Clean SRD | 6" |
| 27000135 | VERTEQ | 1800 Single Stack SRD | Wet Etch & Clean SRD | 8" |
| 27000335 | VERTEQ | 1800-50 Dual Stack Spin Rinser/Dryer | Wet Processing | |
| 27000336 | VERTEQ | 1800-50 Single Stack Spin Rinser/Dryer | Wet Processing | |
| 27000305 | VERTEQ | 600-42L | Wet Etch & Clean SRD | 6" |
| 27000337 | VERTEQ | Automated Hot Phosphoric Acid Plastic Bench | Wet Processing | |
| 27000338 | VERTEQ | Automated P-Clean Plastic Wet Bench | Wet Processing | |
| 27000280 | VERTEQ | Cobra copper clean | Wet Etch & Clean SRD | |
| 27000031 | VERTEQ | ST600-62T Megasonic Cleaner | Wet Etch & Clean SRD | 6" |
| 27000281 | VERTEQ | VCS CMP SAH non-metal oxide clean | Wet Etch & Clean SRD | |
| 28000165 | VERTEQ | VCS Post metal CMP clean | CMP | 8" |
| 27000282 | VERTEQ | VCS SAH 1800 copper clean | Wet Etch & Clean SRD | |
| 27000283 | VERTEQ | VCS-CMP-SAH clean | Wet Etch & Clean SRD | |
| 13000563 | WENTWORTH | AWP 1050 HS Automatic Wafer Probe System | Test & Handling | 6" |
| 13000562 | WENTWORTH | Manual Probe Station | Test & Handling | 4" |
| 13000542 | WENTWORTH | Model 925 Manual Probe Station | Test & Handling | 6" |
| 13000564 | WENTWORTH | MP 0700 PCH Manual Probe Station | Test & Handling | 4" |
| 24000123 | WEST BOND | 700 C Wire Pull Tester | Wire Bonders | |
| 24000100 | WEST BOND | 7316A Eutectic Die Bonder | Wire Bonders | |
| 24000227 | WESTBOND | 5400B-72B wire bonder | Wire Bonders | |
| 30000270 | WJ | 1000 T APCVD TEOS BPSG System | CVD & Epi | 8" |
| 30000542 | WJ | 1000H Hydride based APCVD tool | CVD & Epi | |
| 30000543 | WJ | 1500 APCVD STI fill | CVD & Epi | |
| 30000417 | WJ | 1500 T APCVD TEOS BPSG System | CVD & Epi | 8" |
| 30000544 | WJ | 1500 T APCVD TEOS BPSG System | CVD & Epi | |
| 30000545 | WJ | 999R | CVD & Epi | |
| 30000546 | WJ | 999R APCVD 4 injectors | CVD & Epi | |
| 30000408 | WJ | 999R APCVD TEOS BPSG System | CVD & Epi | 6" |
| 60000181 | XENON | Tape Removal System | Dicing, Marking, Taping | |
| 11000266 | YES | 450 PB8-2P-CP polyimide bake oven | Miscellaneous | |

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|-----------------|------------|--|----------------|----------------------------|
| 11000202 | YES | HMDS 6112A Vapor Prime Oven | Miscellaneous | 8" |
| 11000206 | YES | LP III Vapor Prime Oven | Miscellaneous | 6";8" |
| 20000674 | YIELD | YES-CV100P Downstream Resist Stripper | Etch/Ash/Strip | 4";5";6";8" |
| 20000384 | YIELD | YES-R1 Plasma Cleaning System | Etch/Ash/Strip | 4";5";6";8" |
| 20000812 | YIELD | YES-R3 Plasma Cleaning System | Etch/Ash/Strip | 4";5";6";8" |
| 90000295 | ZEISS | AXIOMAT Microscope | Microscopes | |
| 16000434 | ZEISS | Axiotron Imaging Inspection Microscope | Metrology | 8" |
| 16000434 | ZEISS | Axiotron Imaging Inspection Microscope | Metrology | 8" |
| 16000434 | ZEISS | Axiotron Imaging Inspection Microscope | Metrology | 8" |